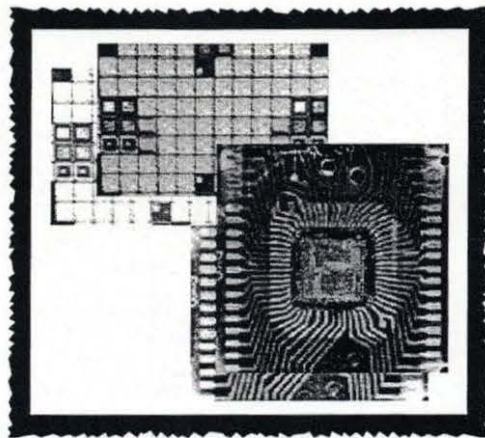


# CMOS

## Digital Circuit Design

Developed by  
R. Jacob Baker  
*University of Idaho*



# *Tutorial Notes*



**IEEE**  
*Networking  
the World™*

Handwritten text in a vertical column on the right side of the page, likely bleed-through from the reverse side. The characters are small and difficult to decipher, but appear to be a continuous line of text.

The following pages contain  
hardcopy of the visuals  
presented in the video  
assignments. You may find it  
helpful to refer to these visuals  
when viewing the video  
segments.

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hardcopy of the visuals  
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# **CMOS Digital Circuit Design**

## **Lesson 2: The Well**

Hardcopy Visuals

# CMOS Digital Circuit Design

## Lesson 2: The Well

Hardcopy Visuals



Si - 4 val.  $e^-$   
 p-type - Boron - 3  $e^-$   
 n-type - phosphorous  
 - 5  $e^-$

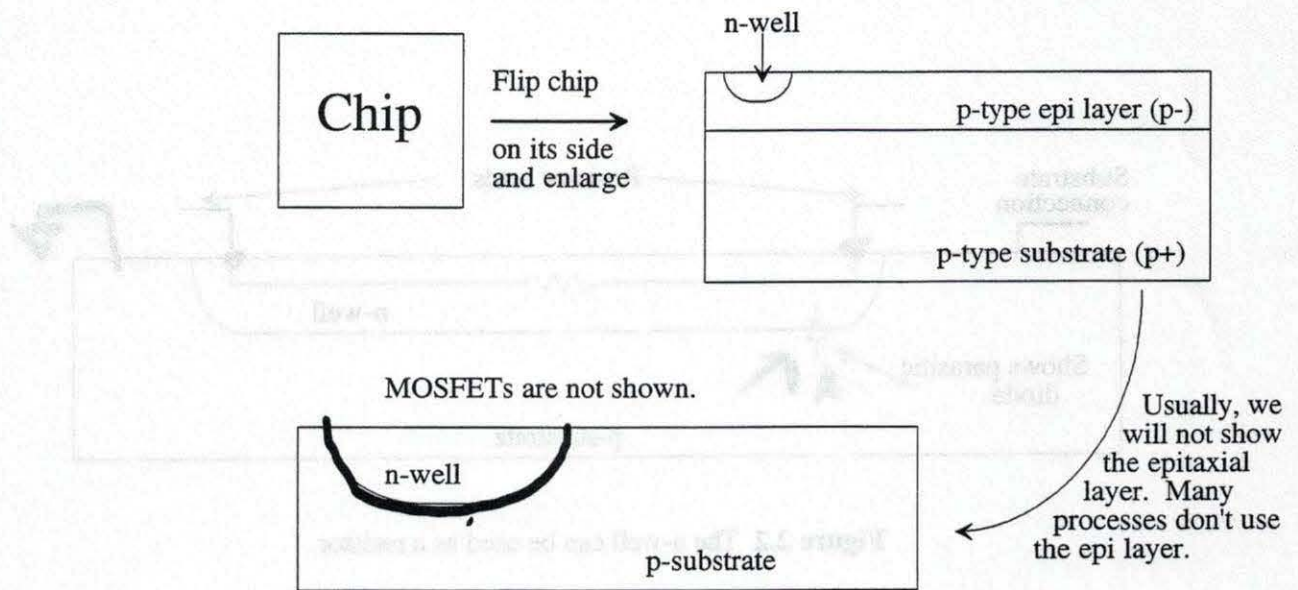
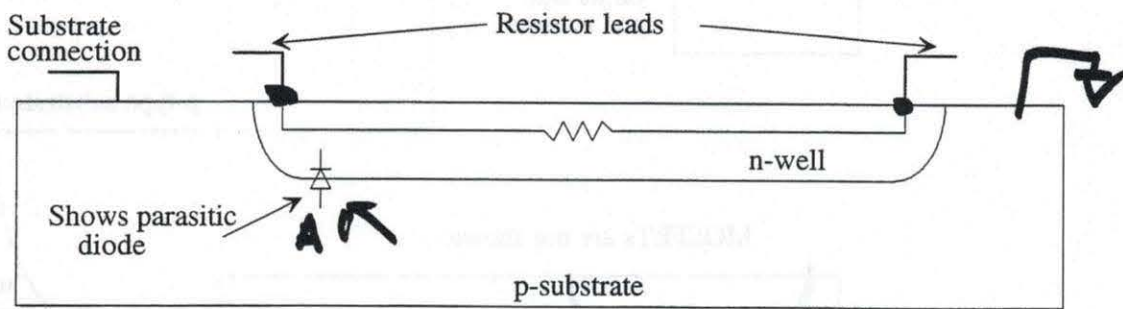


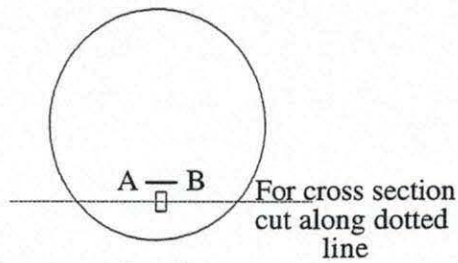
Figure 2.1 Illustration of the top and side view of a die.

Resistor  
 Body p-channel  
 diode

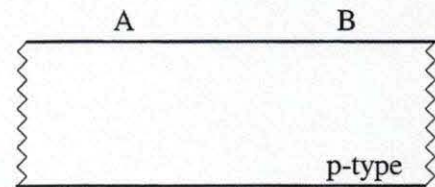


**Figure 2.2** The n-well can be used as a resistor.

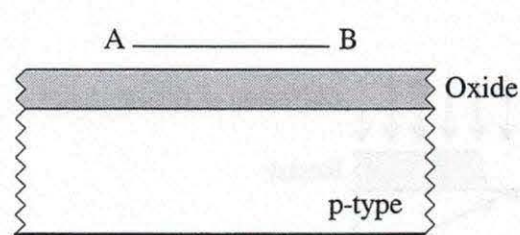




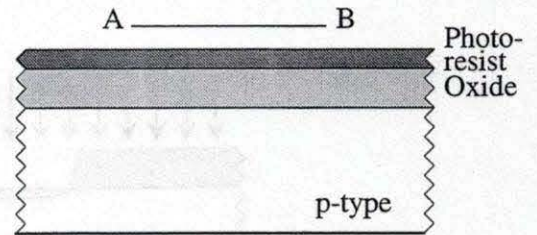
(a) Unprocessed wafer



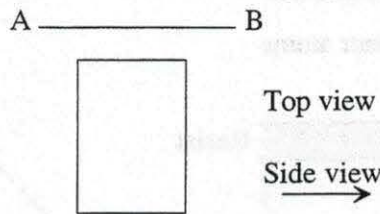
(b) Cross-sectional view of (a)



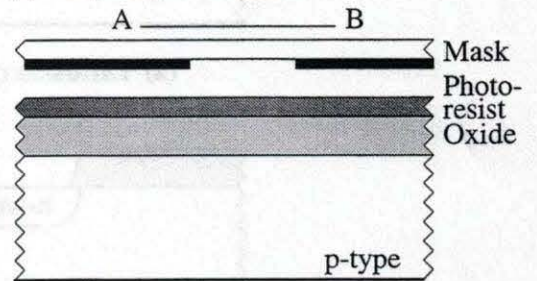
(c) Grow oxide (glass or  $\text{SiO}_2$ ) on wafer.



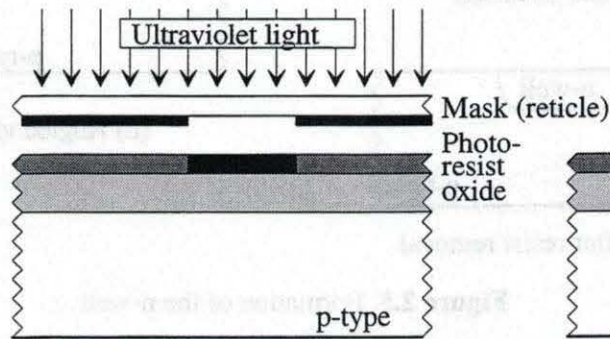
(d) Deposit photoresist



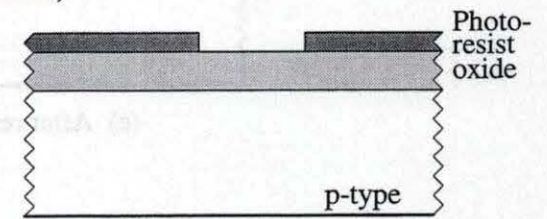
(e) Mask made resulting from LASI layout.



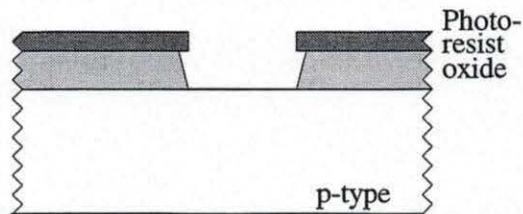
(f) Placement of the mask over the wafer.



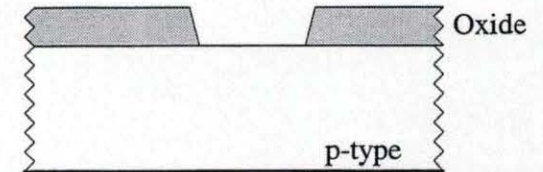
(g) Exposing photoresist.



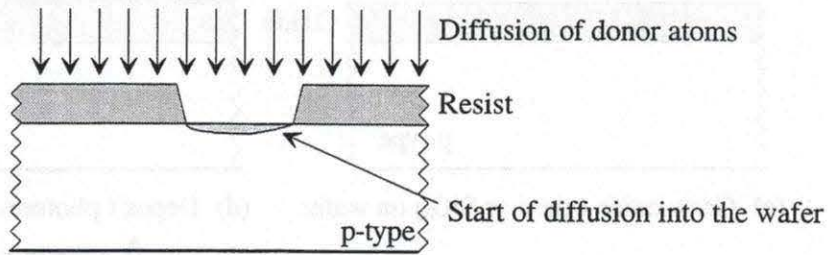
(h) Developing exposed photoresist.



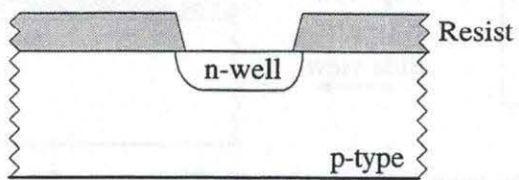
(i) Etching oxide to expose wafer.



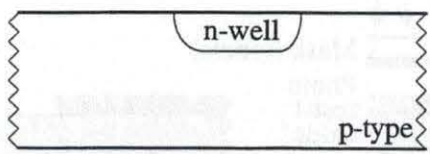
(j) Removal of photoresist.



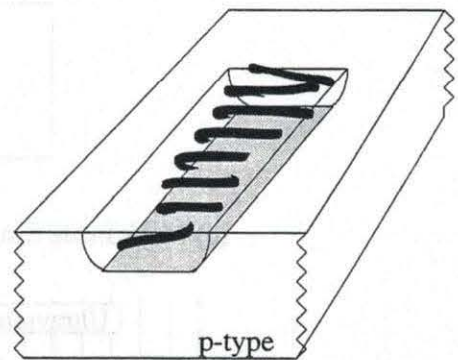
(a) Diffusion of donor atoms



(b) After diffusion



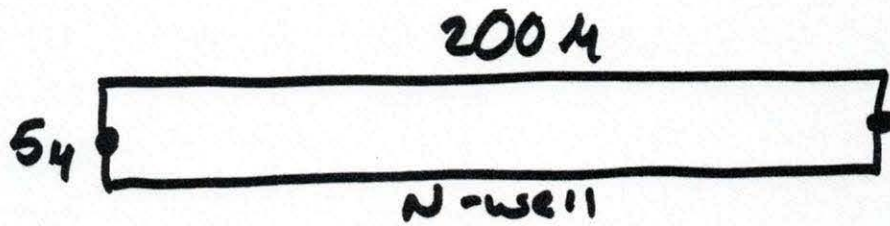
(c) After resist removal



(d) Angled view of n-well

**Figure 2.5** Formation of the n-well.

$$\mu = 10^{-6} \text{ m}$$



$$R = R_{\square} \cdot \frac{200}{5}$$

CN20  
APP. A

$$= 2.5 \text{ K} \cdot 40 = \underline{\underline{100 \text{ K} \Omega}}$$

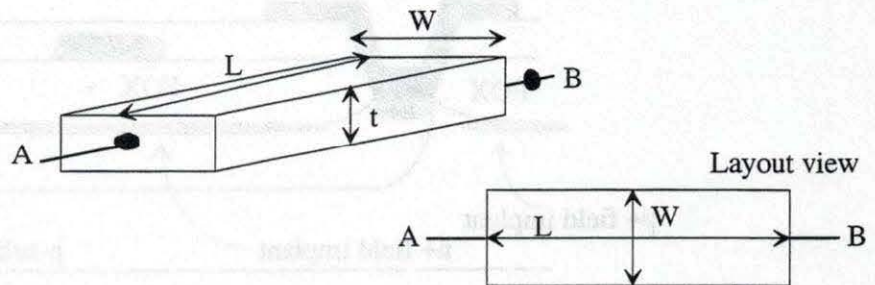
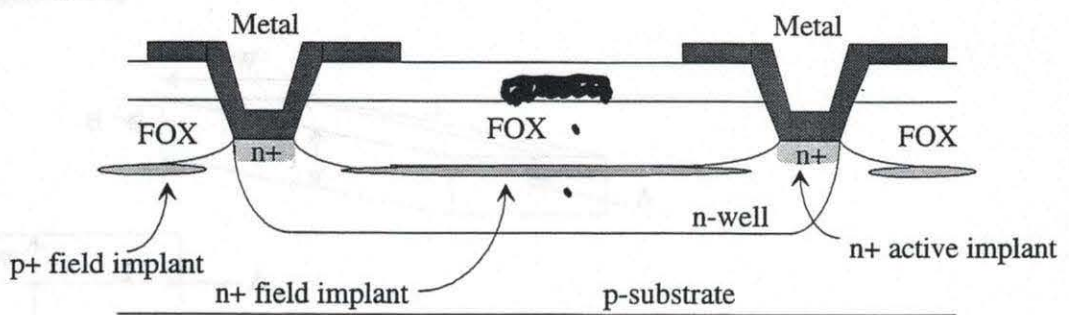
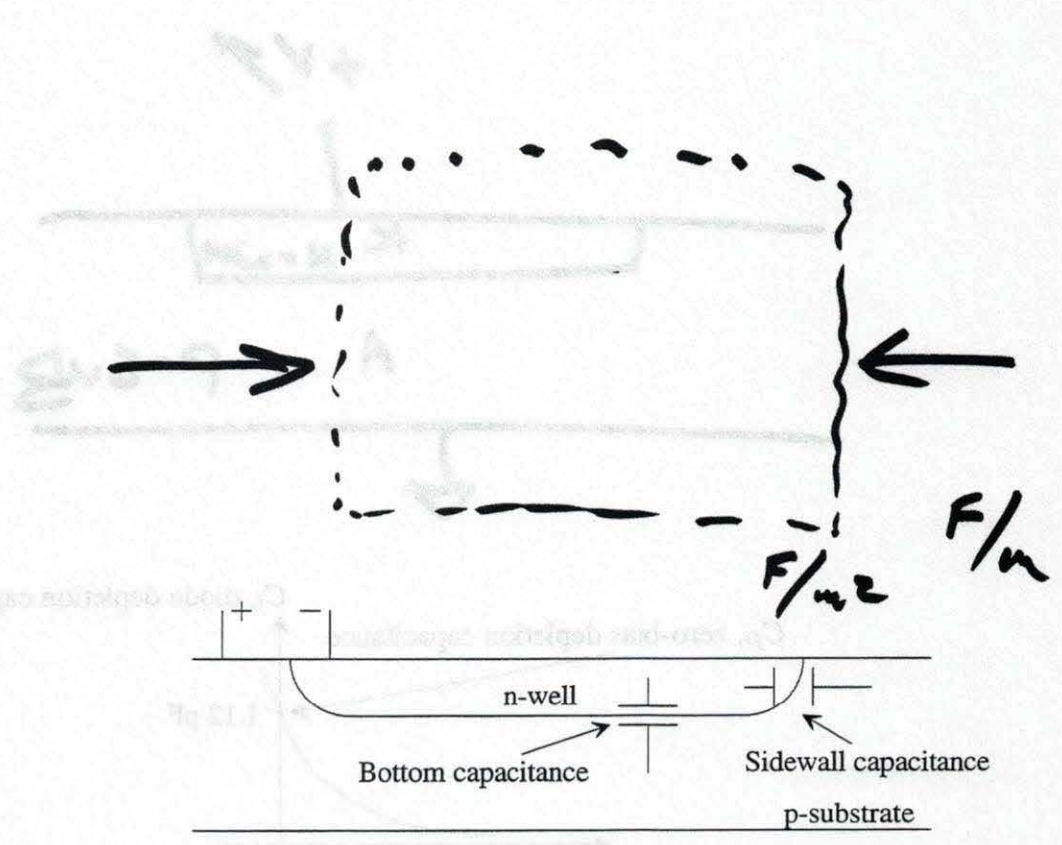


Figure 2.8 Calculation of the resistance of a rectangular block of material.

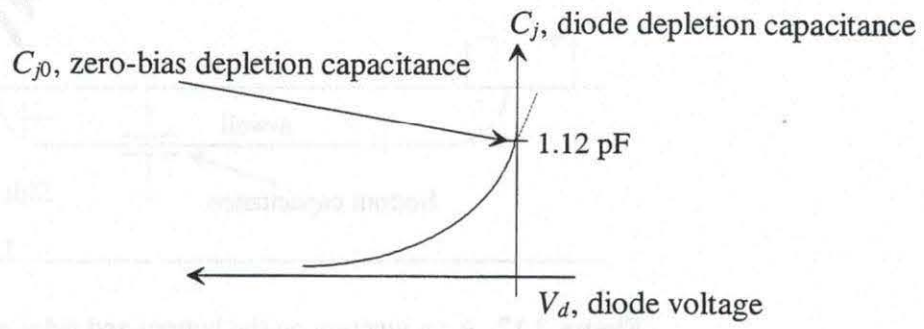
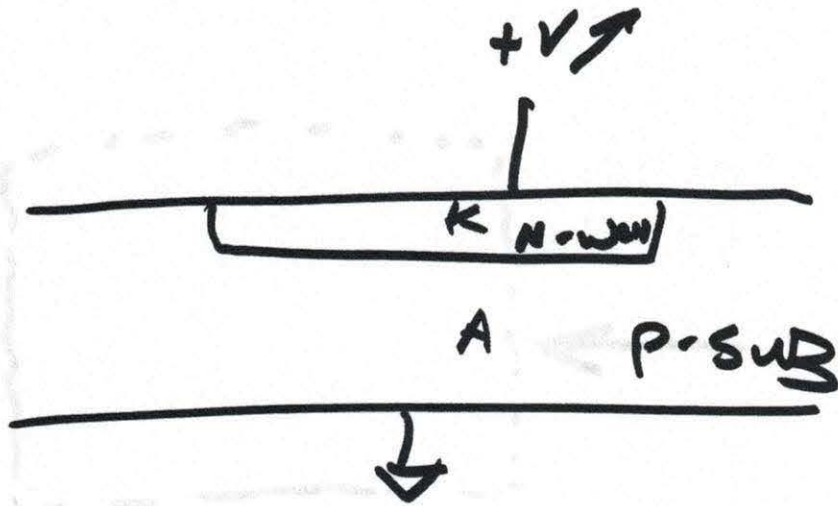
$$R = \frac{\rho}{t} \cdot \frac{L}{W}$$
$$R = R_{\square} \cdot \frac{L}{W}$$



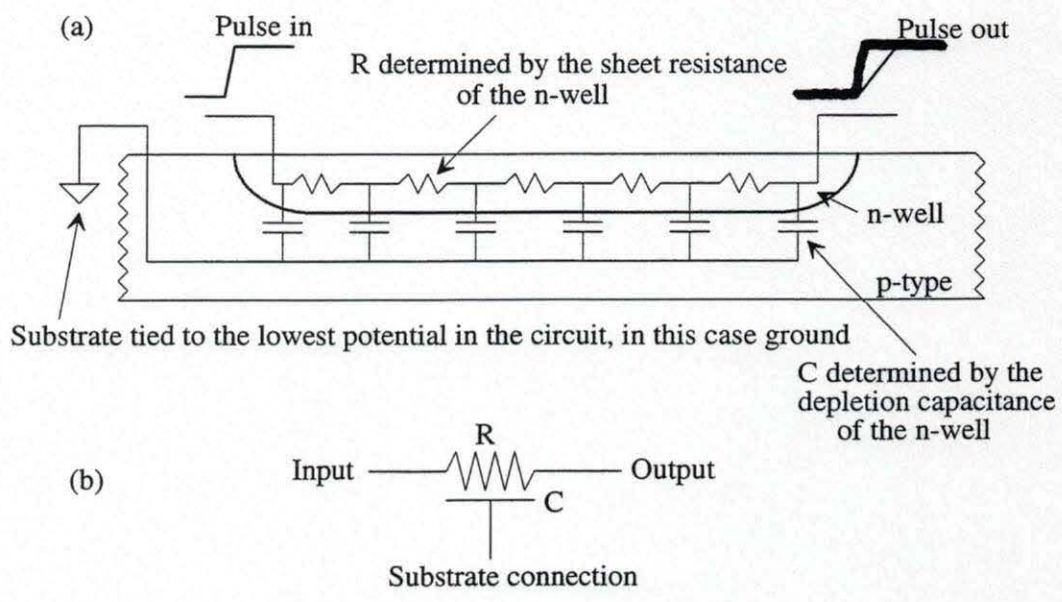
**Figure 2.10** Cross-sectional view of n-well showing field implant. The field implantation is sometimes called the "channel stop implant".



**Figure 2.12** A pn junction on the bottom and sides of the junction.



**Figure 2.13** Sketch of diode depletion capacitance against diode reverse voltage.



**Figure 2.17** (a) Parasitic resistance and capacitance of the n-well and (b) schematic symbol.





# **CMOS Digital Circuit Design**

## **Lesson 3: The Metal Layers**

Hardcopy Visuals

# CMOS Digital Circuit Design

## Lesson 3: The Metal Layers

Hardcopy Visuals

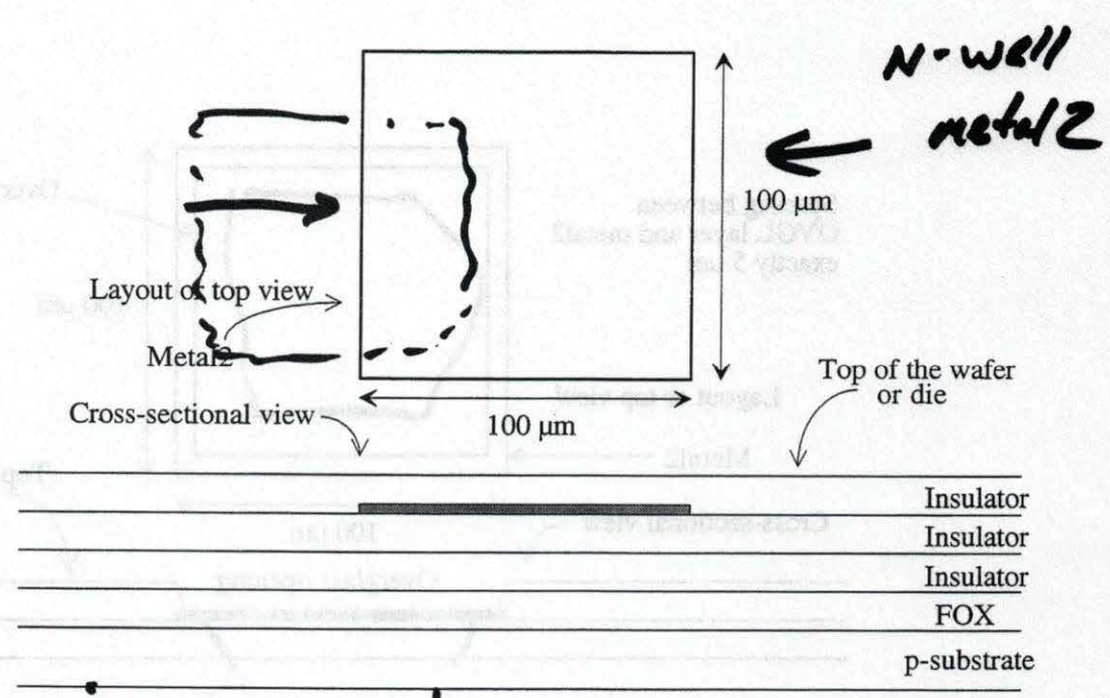
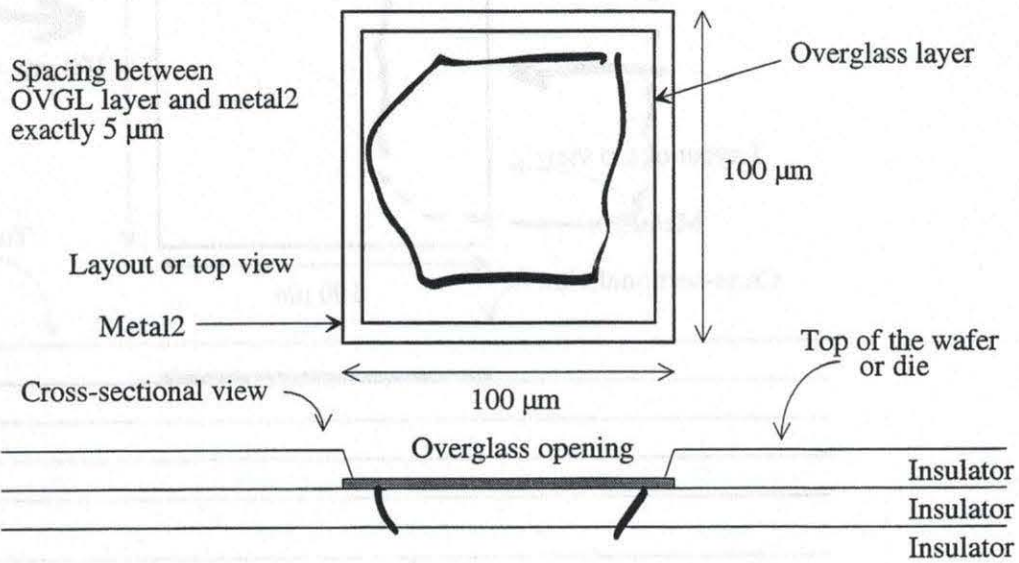


Figure 3.1 Layout of metal2 used for bonding pad with associated cross-sectional view.



**Figure 3.2** Layout of a metal2 pad with pad opening for bonding connection.

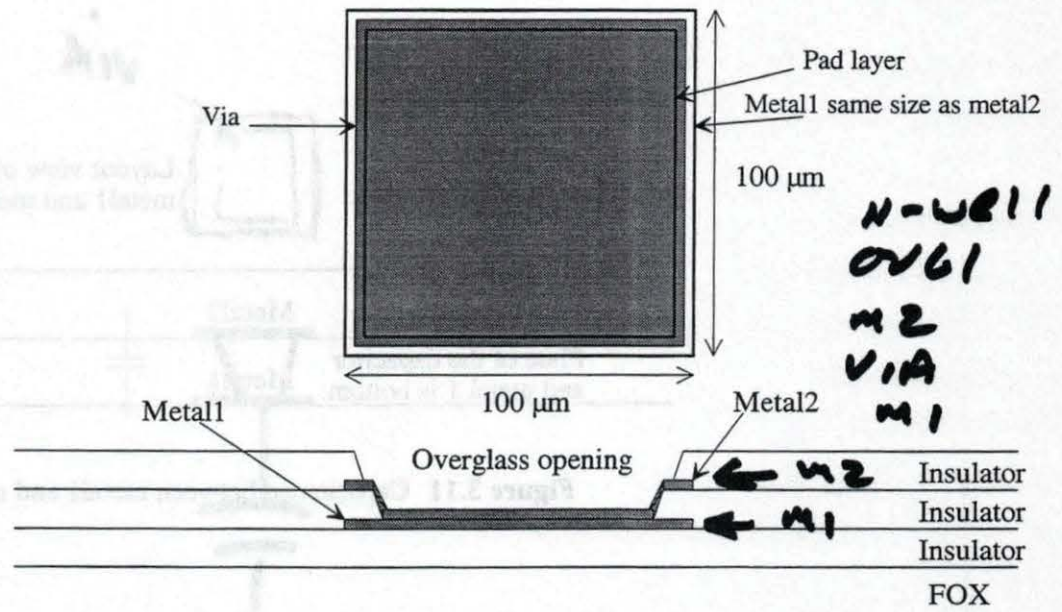
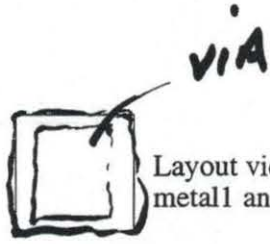
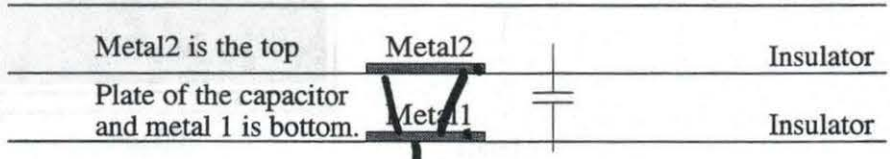


Figure 3.3 A bonding pad using metal1 and metal2.

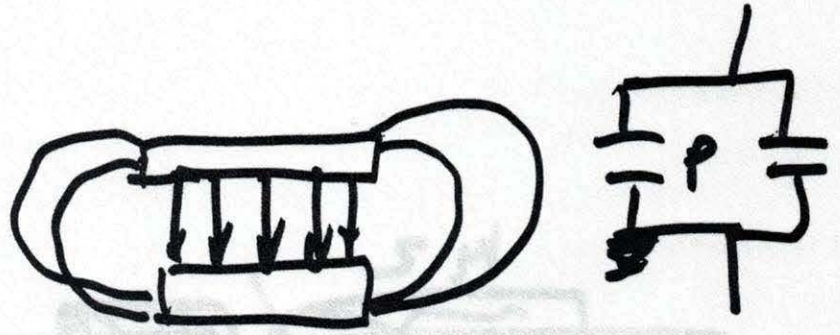


Layout view of 10  $\mu\text{m}$  square metal1 and metal2



**Figure 3.11** Capacitance between metal1 and metal2.





$$F = \frac{F}{M} \cdot \text{Perimeter}$$

Fringe  $M$   $M^2$  A. Plate  $F/M^2$   
 $F$

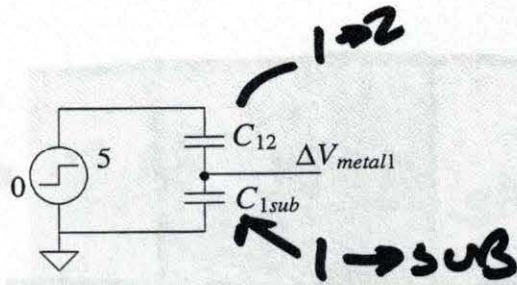
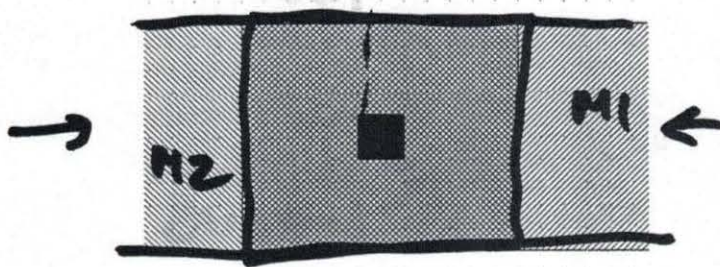
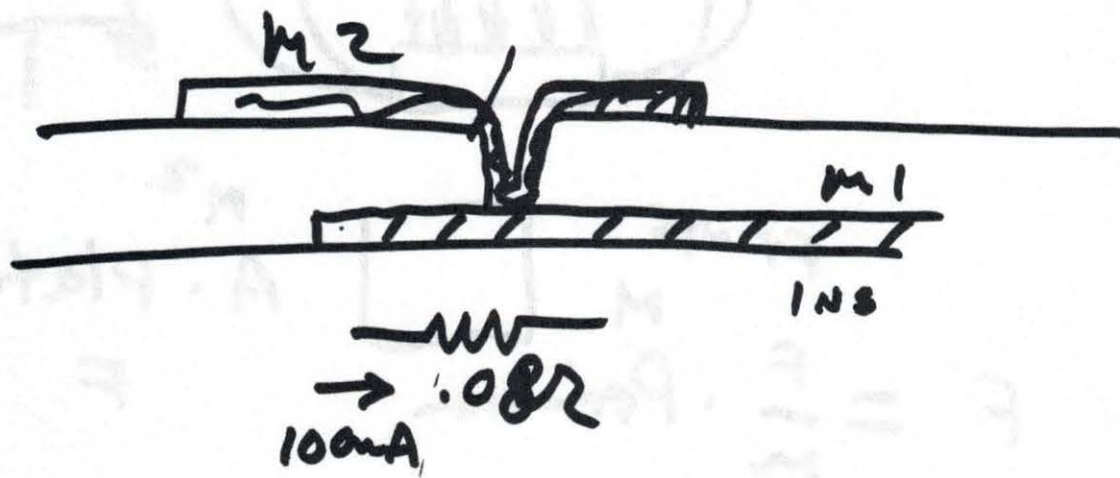
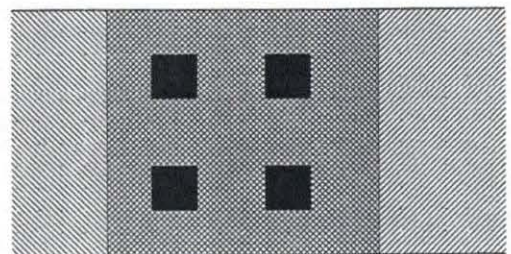


Figure 3.12 Equivalent circuit used to calculate the change in metal voltage.



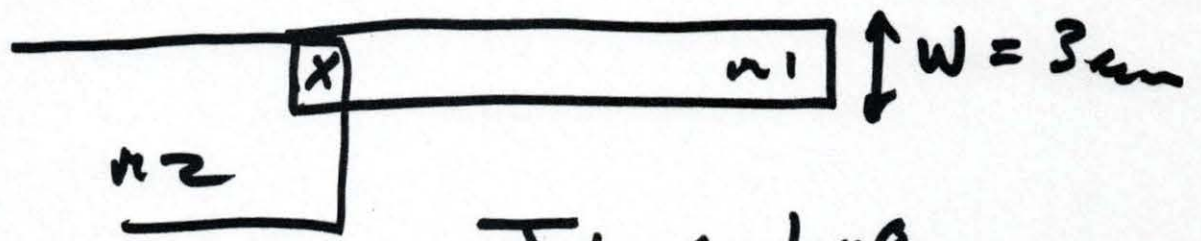
(a)



(b)

Figure 3.13 Layouts used in Example 3.7.

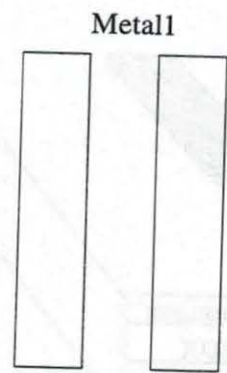




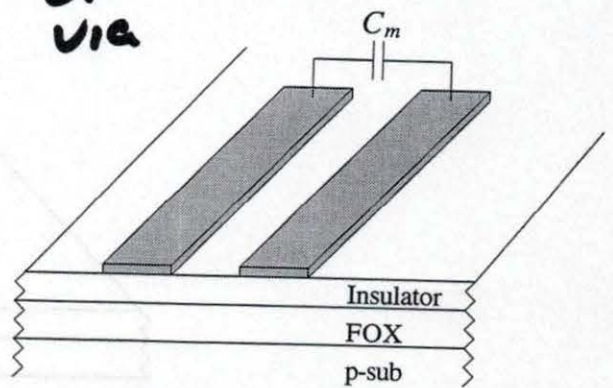
$$J_{el} < \frac{1 \text{ mA}}{4 \mu\text{m}}$$

$$\frac{.04 \text{ mA}}{}$$

contact  
or  
via

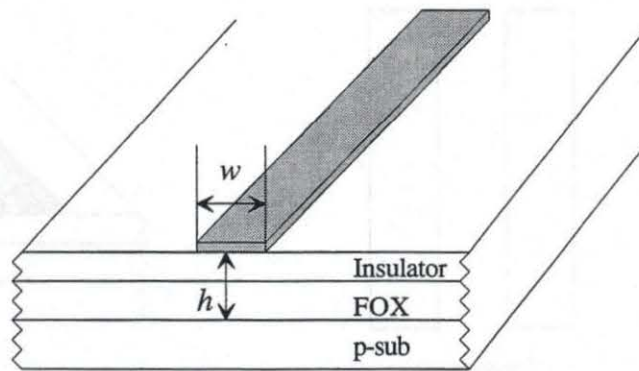


Layout view

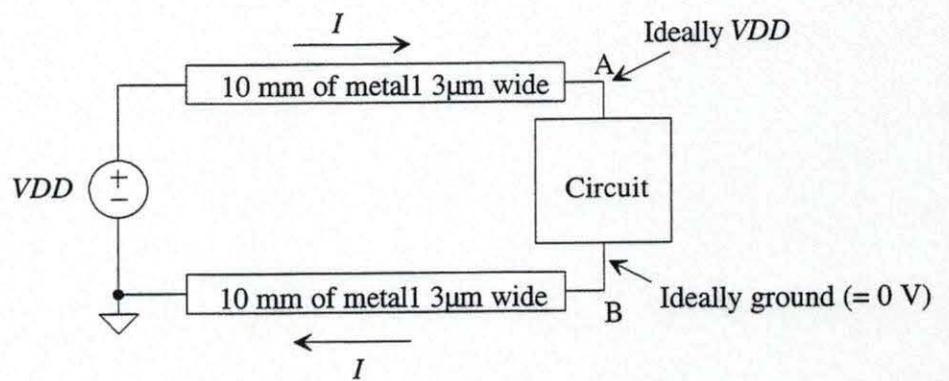


Angled view

Figure 3.14 Conductors used to illustrate crosstalk.



**Figure 3.15** Conductors used in calculation of inductance.



**Figure 3.16** Block diagram used to illustrate ground bounce.



# **CMOS Digital Circuit Design**

## **Lesson 4: The Active and Poly Layers**

Hardcopy Visuals



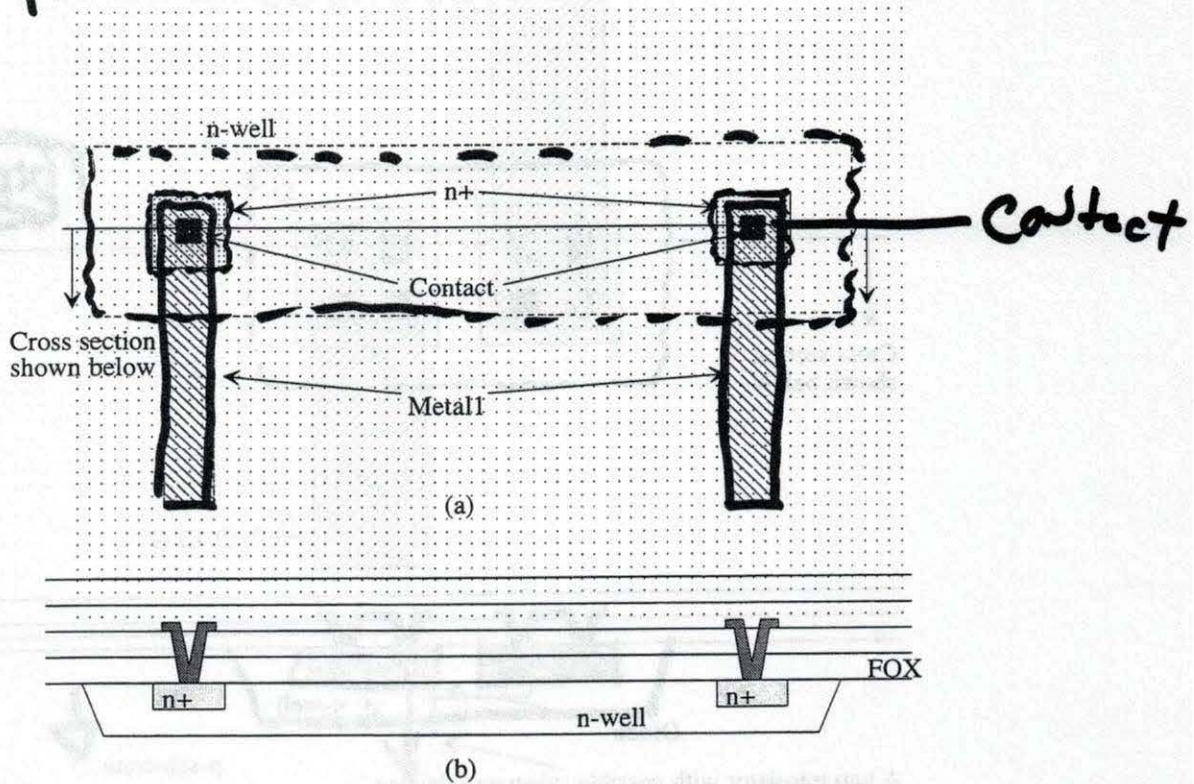
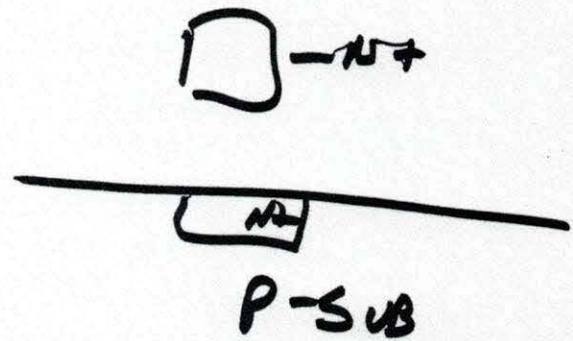
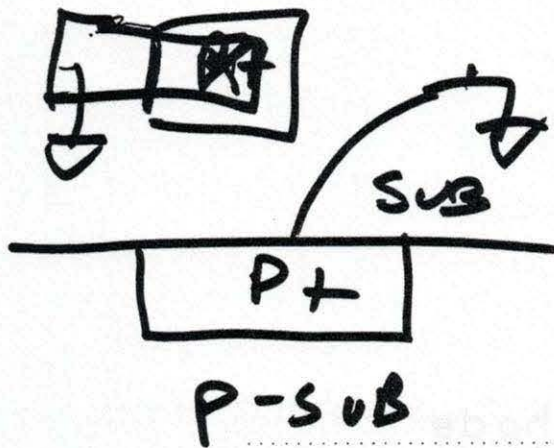


Figure 4.1 Layout of an n-well resistor with active contacts to metal (a) Actual layout using LASI, (b) cross-sectional view across the contacts.

OV6L	P+
M2	N+
VIA	N-well
M1	Poly
Cont	

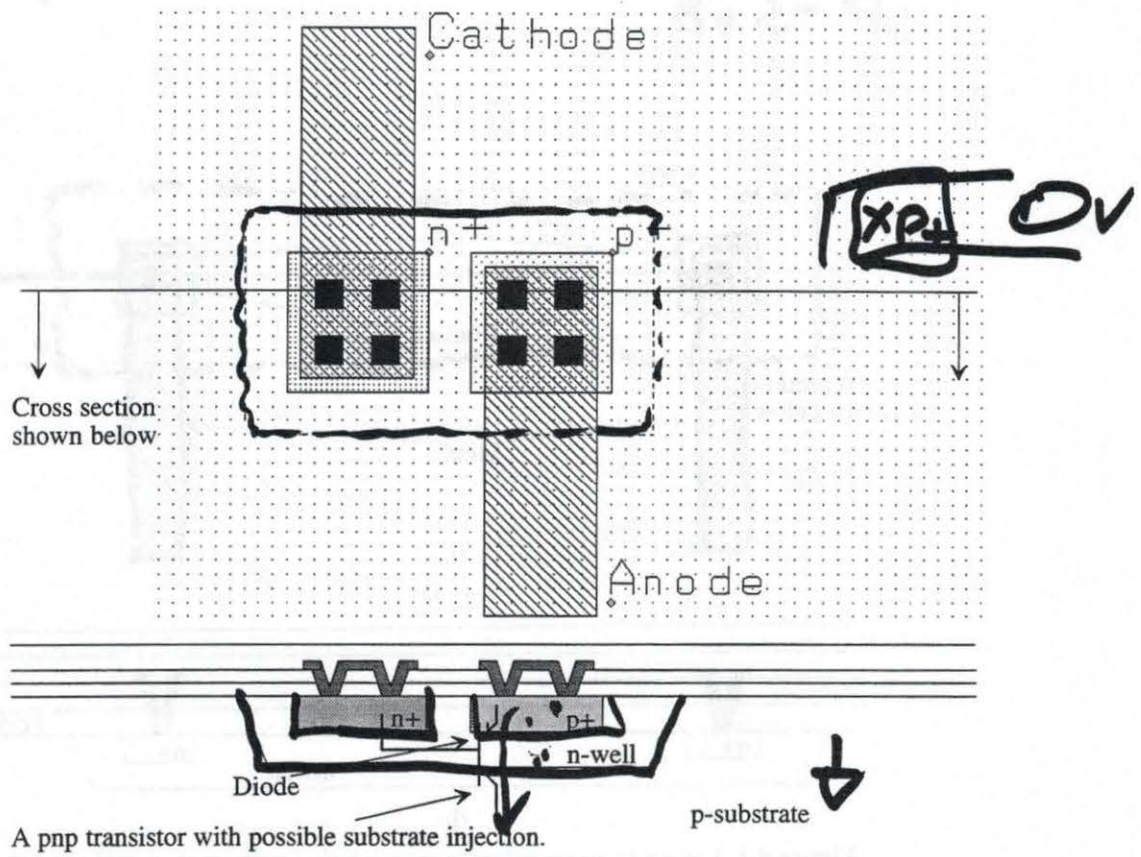


Figure 4.3 Layout of a 10 um by 10 um diode using the n-well as the cathode.



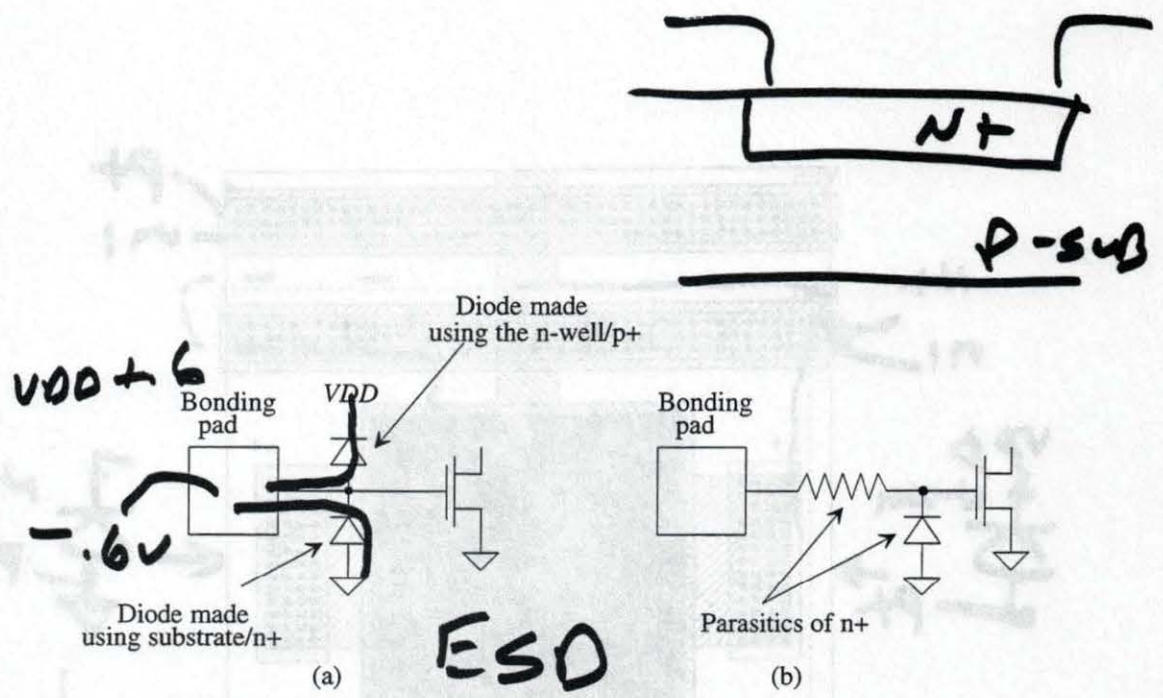


Figure 4.5 Two methods of protecting against ESD damage.

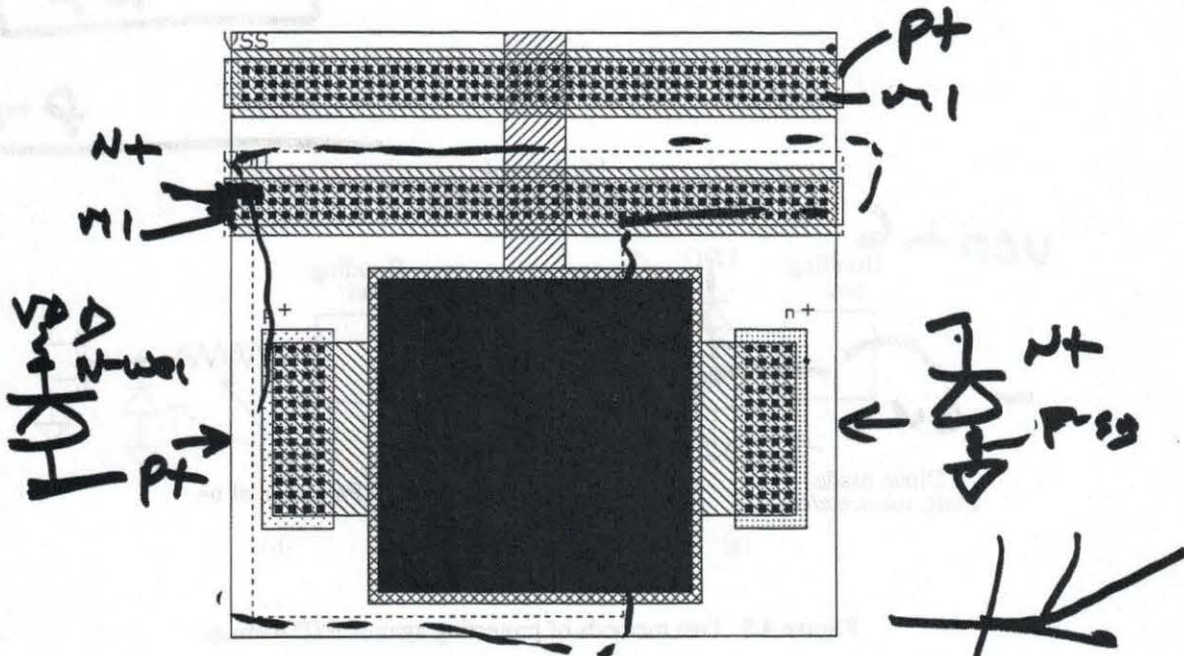
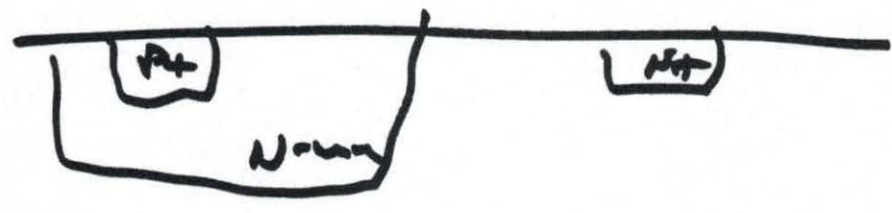
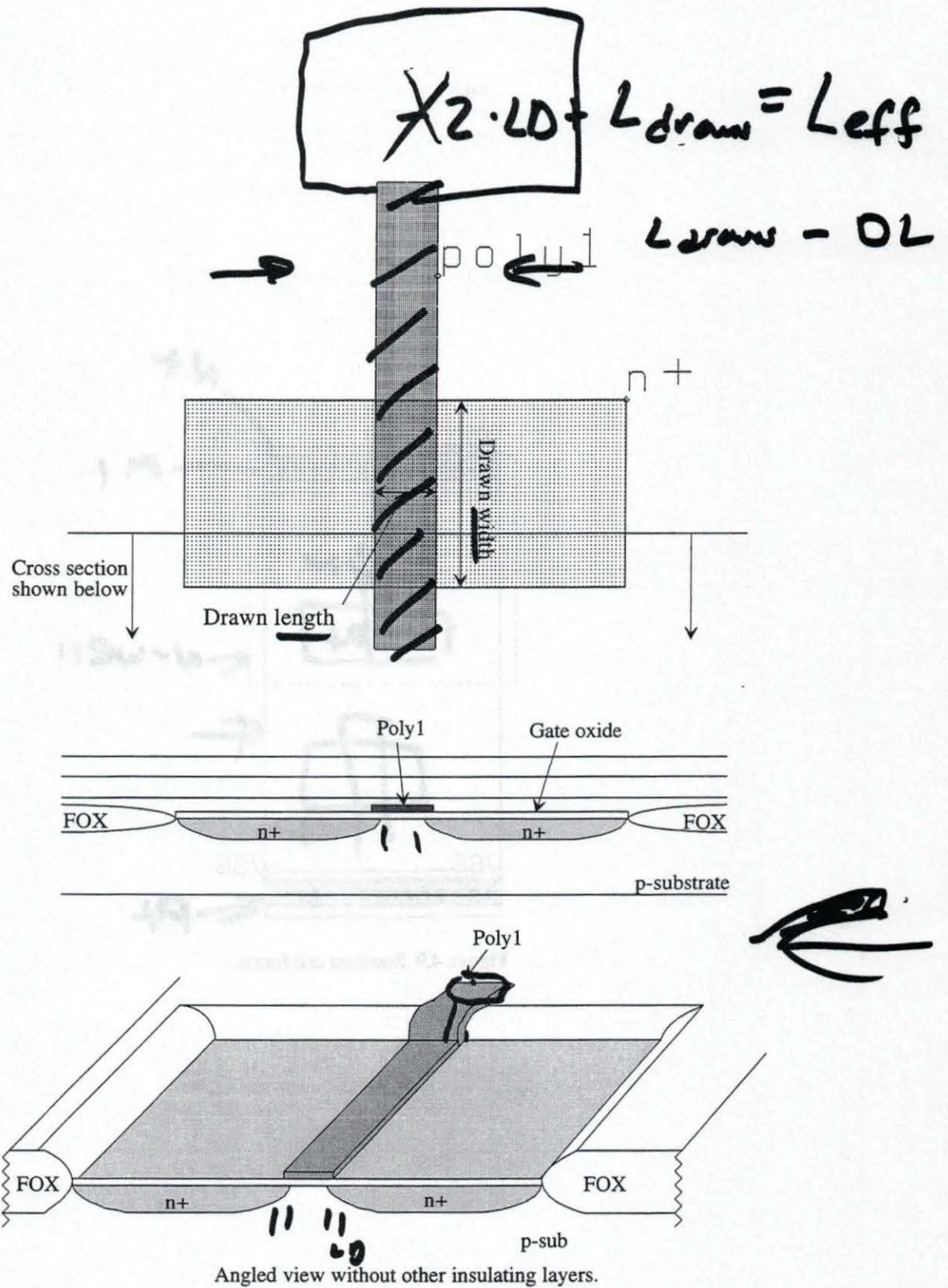


Figure 4.6 Pad with ESD diodes and power busses.





**Figure 4.8** Layout of a MOSFET, cross-sectional and angled view.

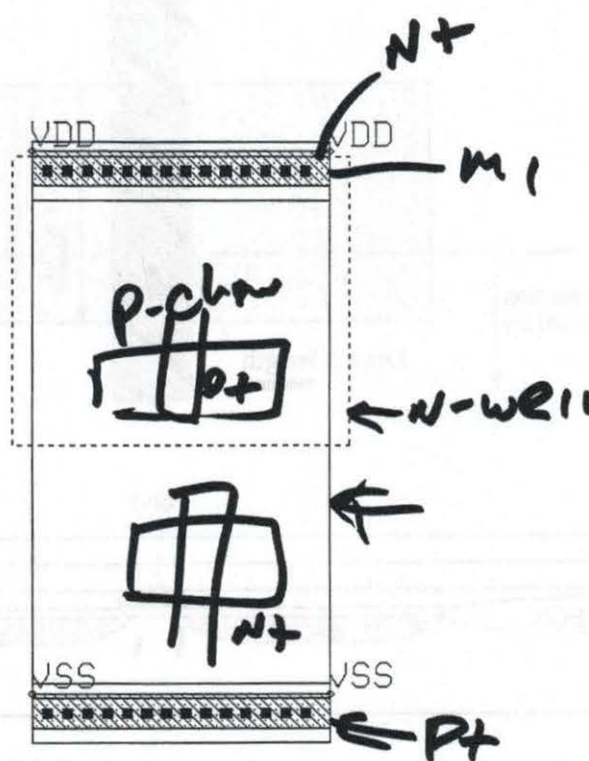


Figure 4.9 Standard cell frame.

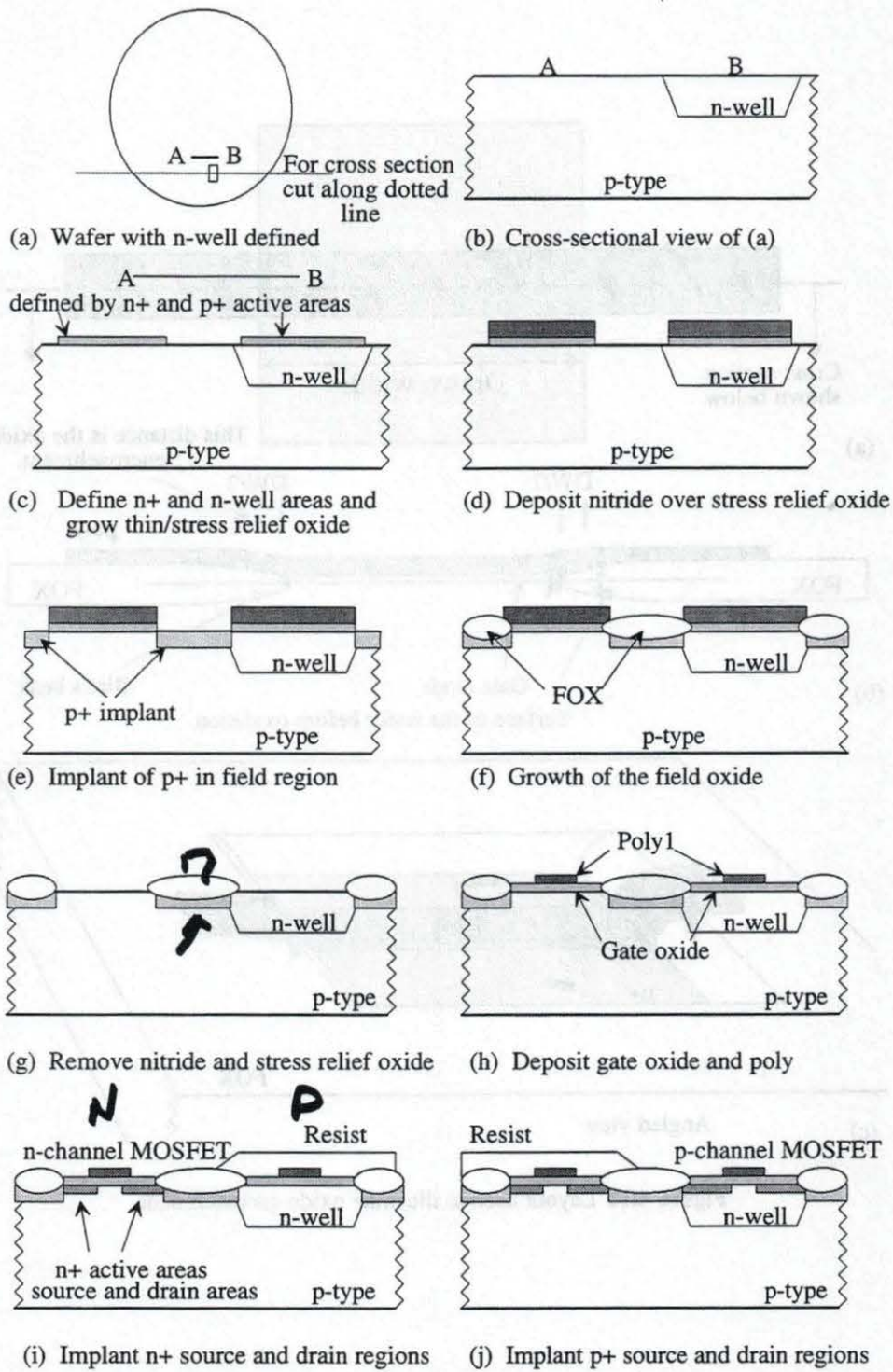
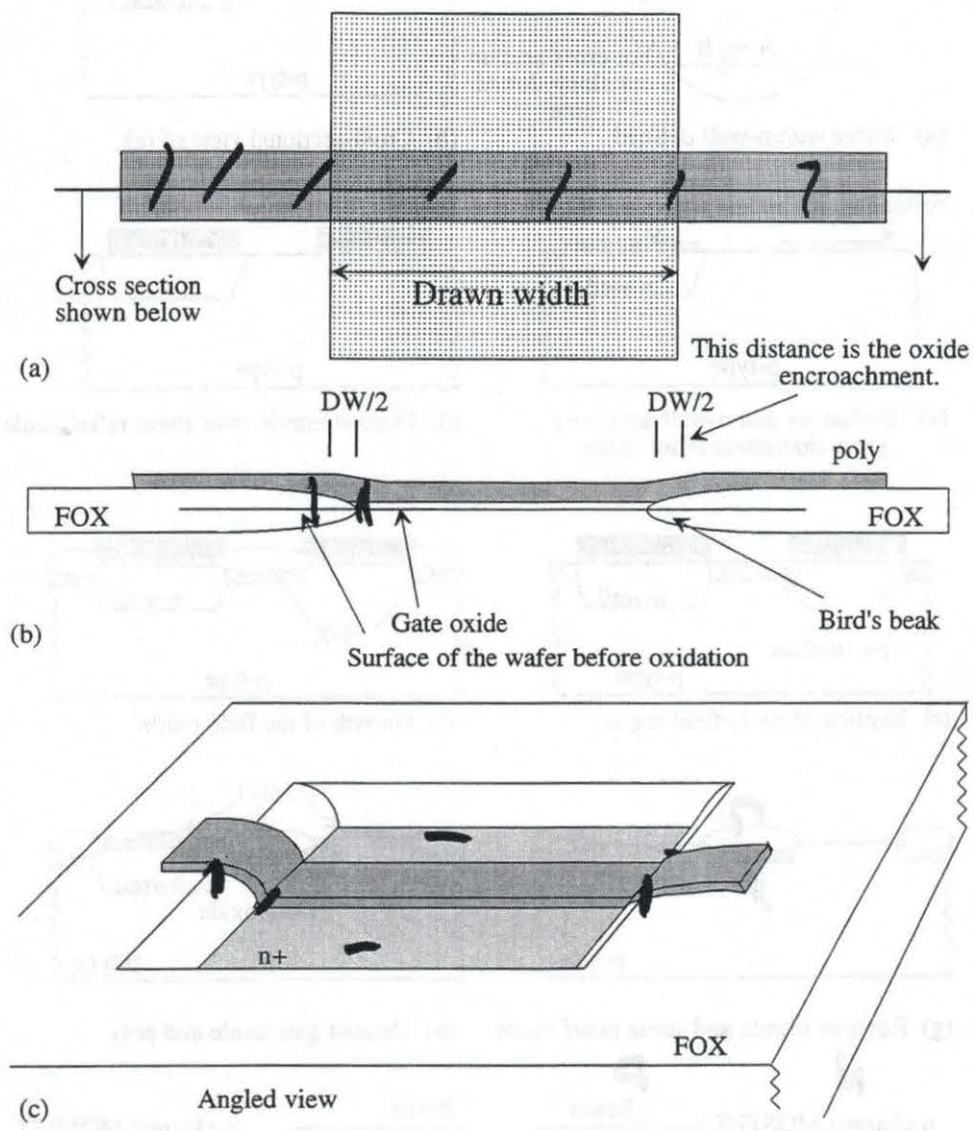
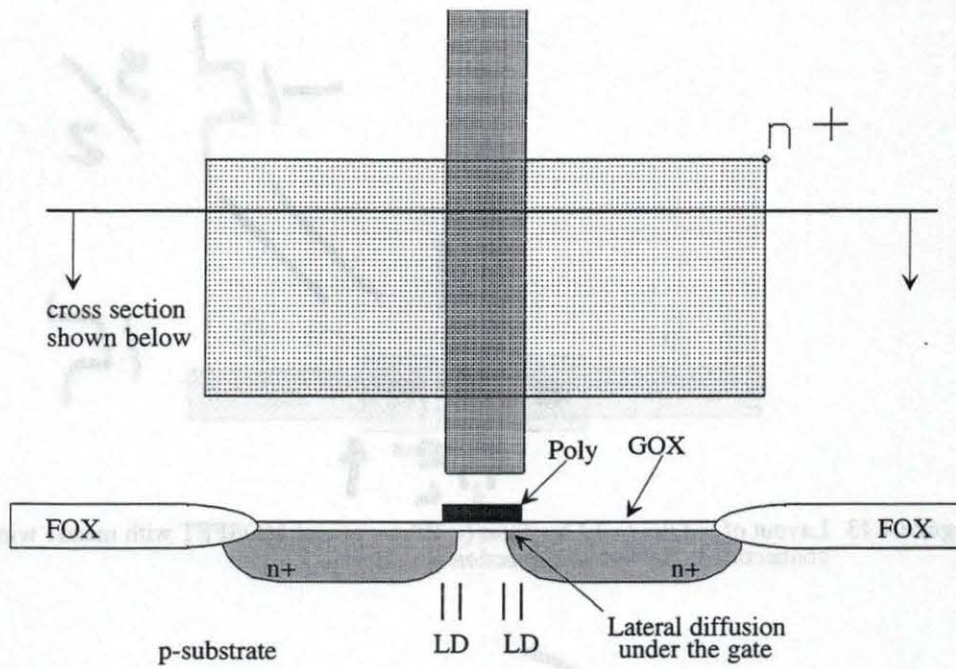


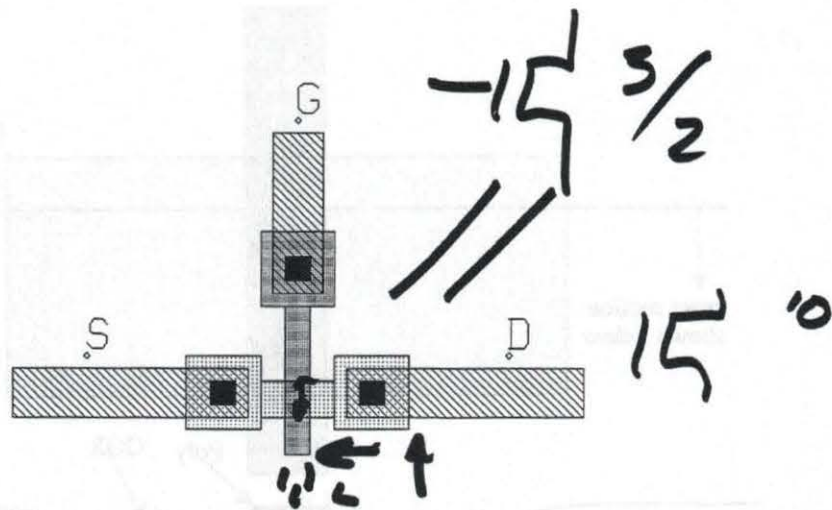
Figure 4.10 Sequence of events used in MOSFET formation.



**Figure 4.11** Layout used to illustrate oxide encroachment.



**Figure 4.12** Layout used to illustrate lateral diffusion.



**Figure 4.13** Layout of a  $2 \mu\text{m}$  ( $= L$ ) by  $3 \mu\text{m}$  ( $= W$ ) n-channel MOSFET with metal wire connections. Substrate connection not shown.



# **CMOS Digital Circuit Design**

## **Lesson 5: The MOSFET as a Capacitor**

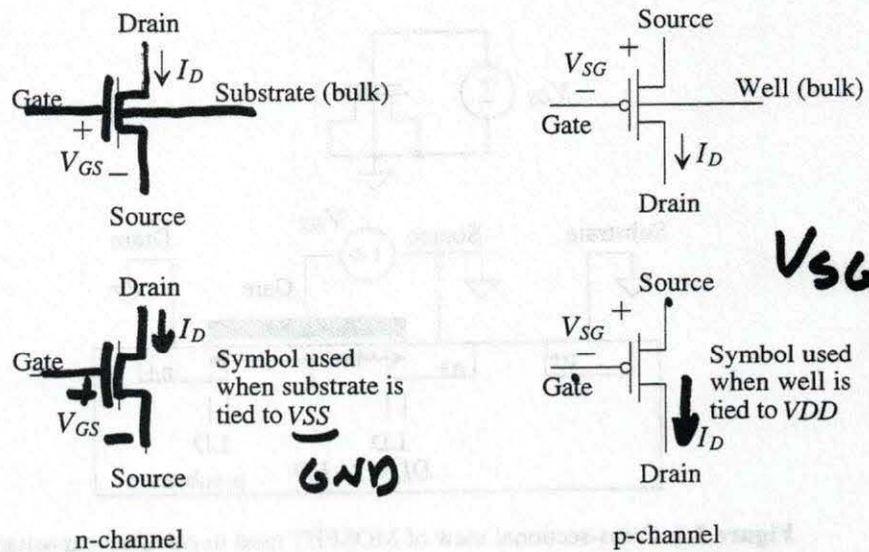
Hardcopy Visuals

# CMOS Digital Circuit Design

## Lesson 5:

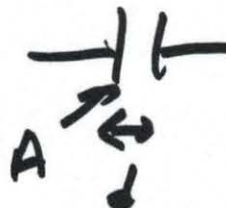
### The MOSFET as a Capacitor

Handcopy Visuals

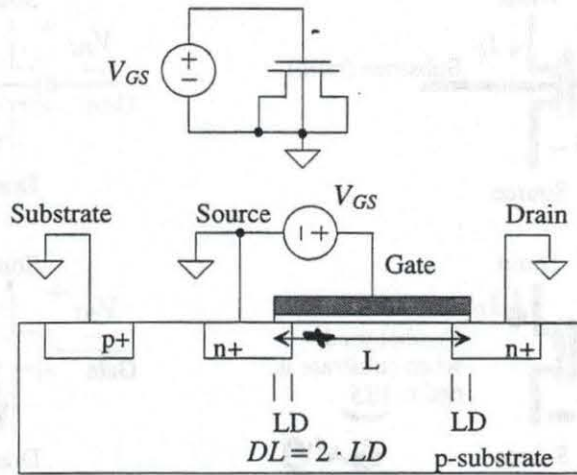


$$V_{SG} = V_S - V_G$$

Figure 5.1 Symbols used for n- and p-channel MOSFETs.



$$C = \frac{\epsilon_0 \cdot A}{d}$$



**Figure 5.2** Cross-sectional view of MOSFET used to calculate capacitances.

$$\left[ \begin{array}{|c|} \hline \text{---} \\ \hline \text{---} \\ \hline \text{---} \\ \hline \end{array} \right] = w \cdot L \cdot \frac{\epsilon_{ox}}{t_{ox}} = C_{ox}$$

$$C_{ox} \frac{F}{m^2}$$

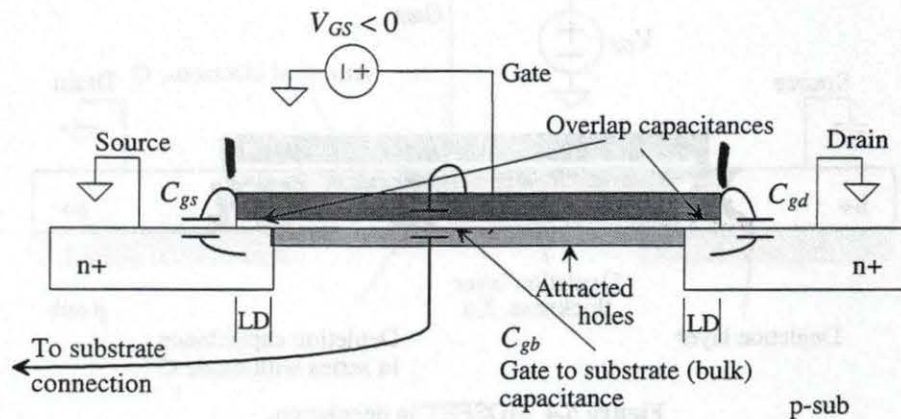


Figure 5.3 MOSFET in accumulation.

$$C_{gs} = C_{gd} = \text{overlap CAP.} \\ = \frac{LD \cdot w \cdot \epsilon_{ox}}{t_{ox}}$$

$$C = \frac{w \cdot (L - 2 \cdot LD)}{t_{ox}} \cdot \epsilon_{ox}$$

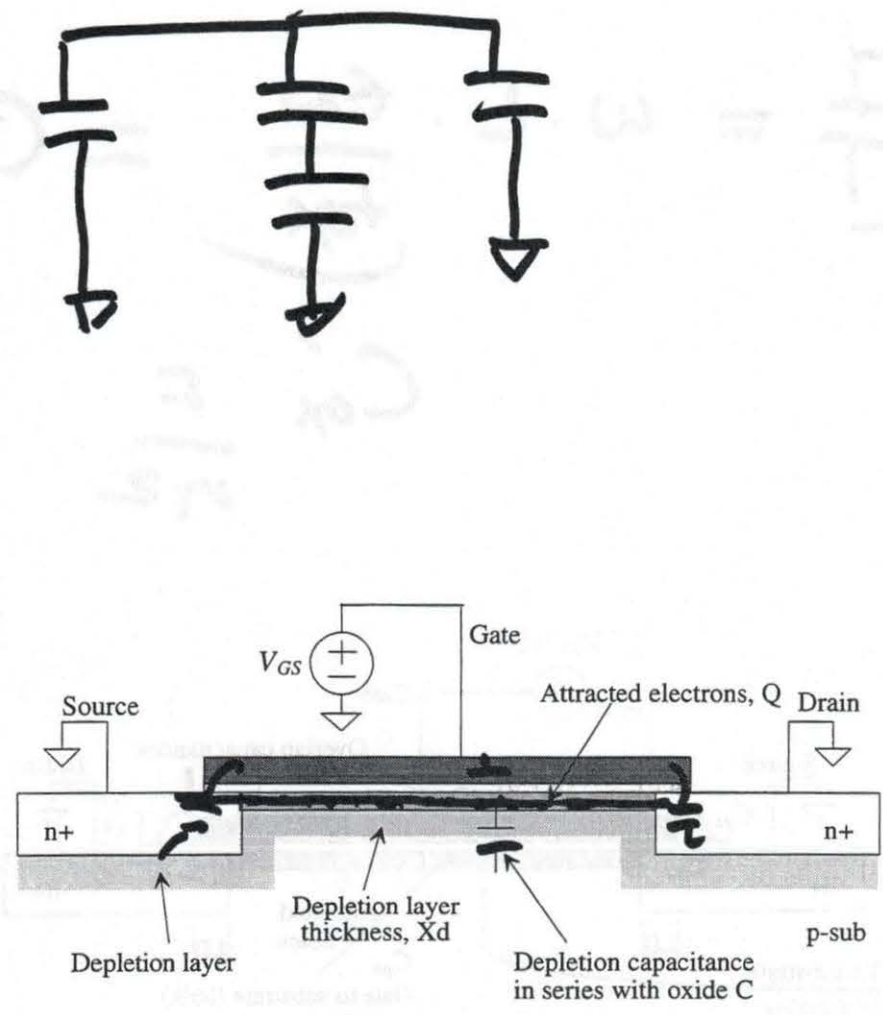


Figure 5.4 MOSFET in depletion.

$C_{gs} = C_{gd} = \text{overlap cap.}$   
 $C_{gs} = C_{gd} = \frac{\epsilon_0 \epsilon_r \cdot W \cdot L_{ov}}{L}$

$C = \frac{W \cdot L \cdot \epsilon_0 \epsilon_r \cdot (L - S \cdot L_D)}{L}$

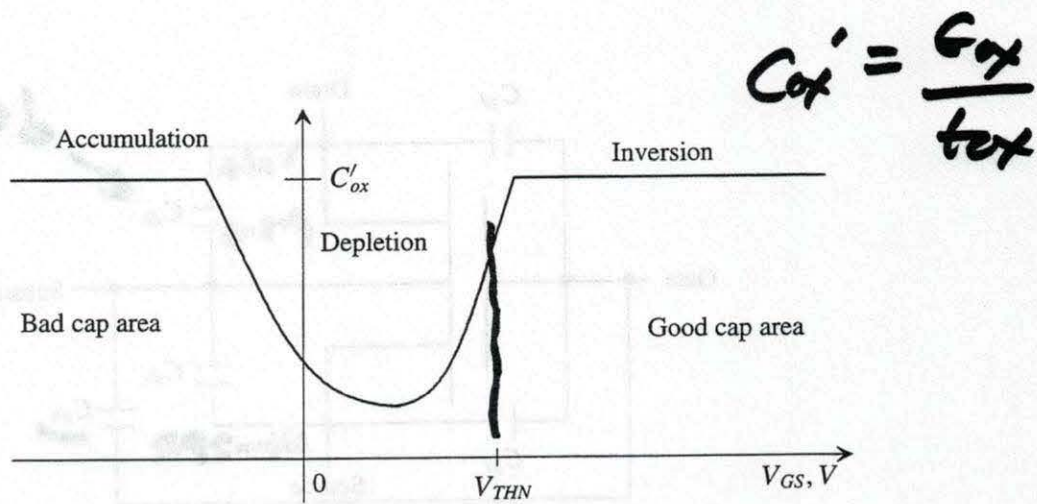
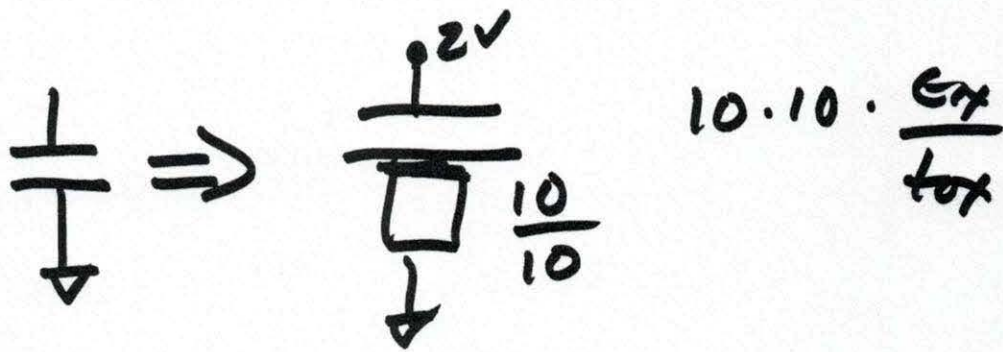
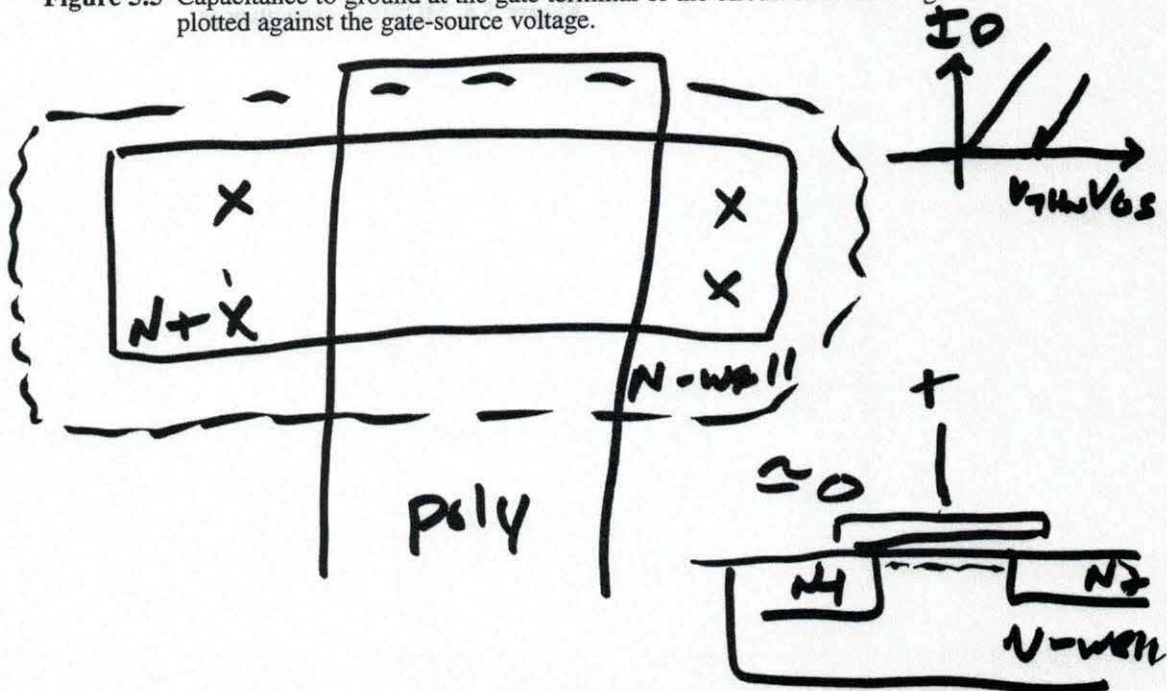


Figure 5.5 Capacitance to ground at the gate terminal of the circuit shown in Fig. 5.2 plotted against the gate-source voltage.



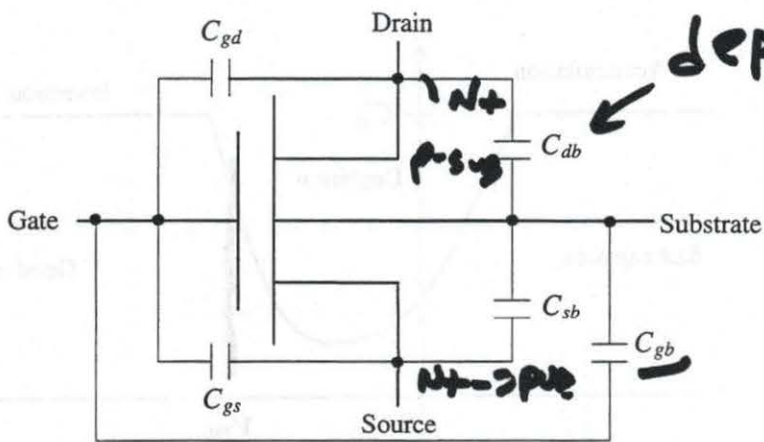
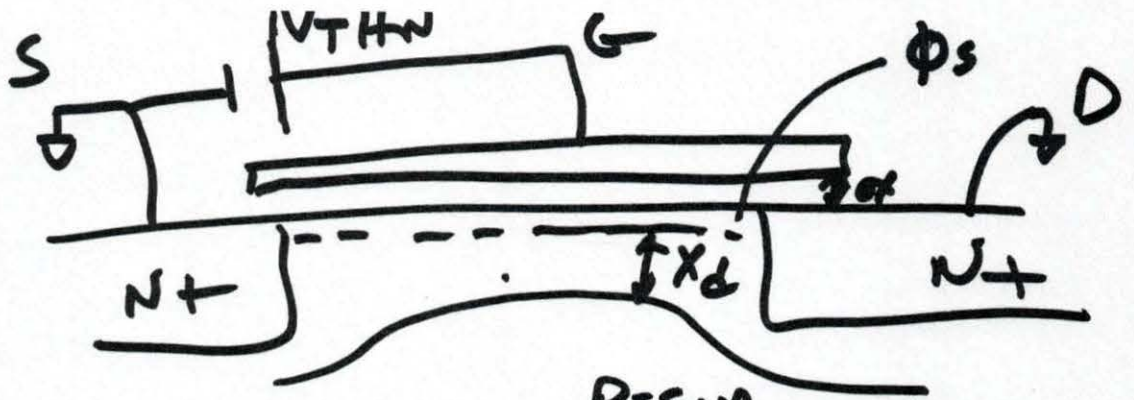


Figure 5.6 MOSFET capacitances.





$$N_A = 10^{15} \frac{\text{atoms}}{\text{cm}^3} = \# \text{ of holes}$$

---


$$|2\phi_F| = \frac{-kT}{q} \ln \frac{N_A}{N_i}$$

$\uparrow$   
 $14.5 \times 10^9$   
carriers  
 $\text{cm}^3$

$$\phi_s \Big|_{V_{THN}} = - \frac{q N_A}{\epsilon_{Si}} \phi_F$$

u



# **CMOS Digital Circuit Design**

## **Lesson 6: The MOSFET**

Hardcopy Visuals

# CMOS Digital Circuit Design

## Lesson 6: The MOSFET

Handcopy Visuals

$$(\phi_s - \phi_m) - (\phi_{ox} - \phi_s) = \phi_{ms}$$

$$\phi_s - \phi_m = \phi_{ms}$$

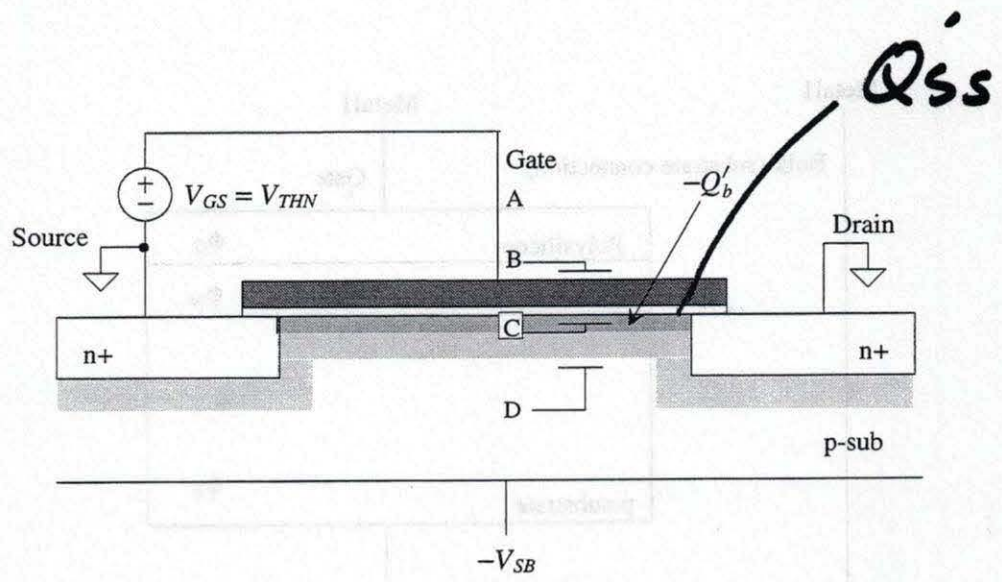
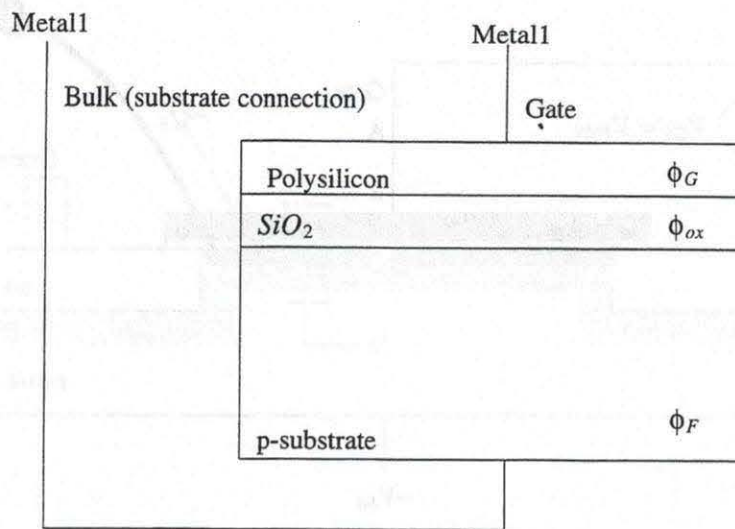


Figure 5.7 Calculation of the threshold voltage.

Figure 5.7 Calculation of the threshold voltage.

$$\begin{aligned}\phi_{ms} &= (\phi_G - \phi_{ox}) - (\phi_{ox} - \phi_F) \\ &= \phi_G - \phi_F\end{aligned}$$



**Figure 5.8** Determining the contact potential between poly and substrate.

triode or linear region  
of operation

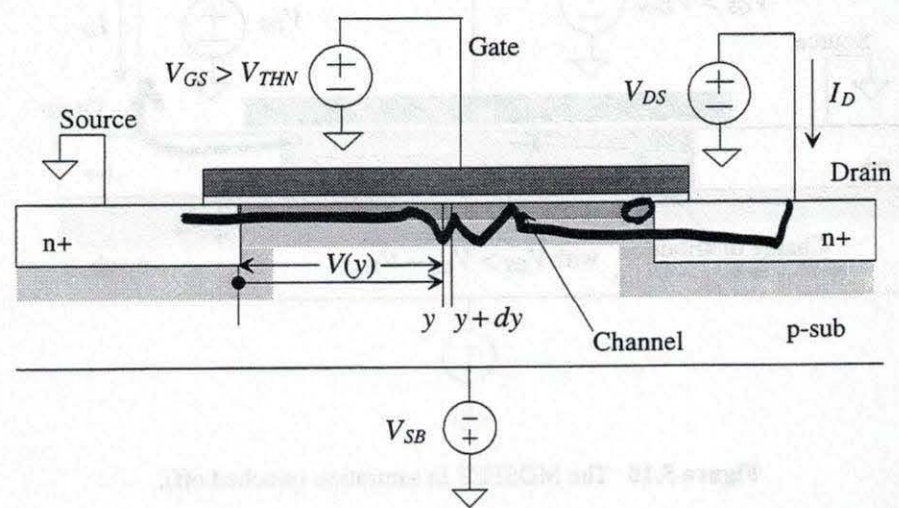
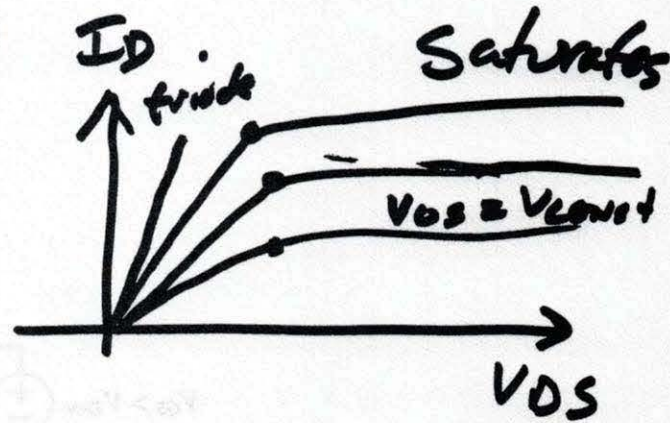


Figure 5.9 Calculation of the large-signal behavior of the MOSFET in the triode (ohmic) region.

$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \left[ (V_{GS} - V_{THN}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

$V_{GS} > V_{THN}$   
 $V_{DS} \leq V_{GS} - V_{THN}$

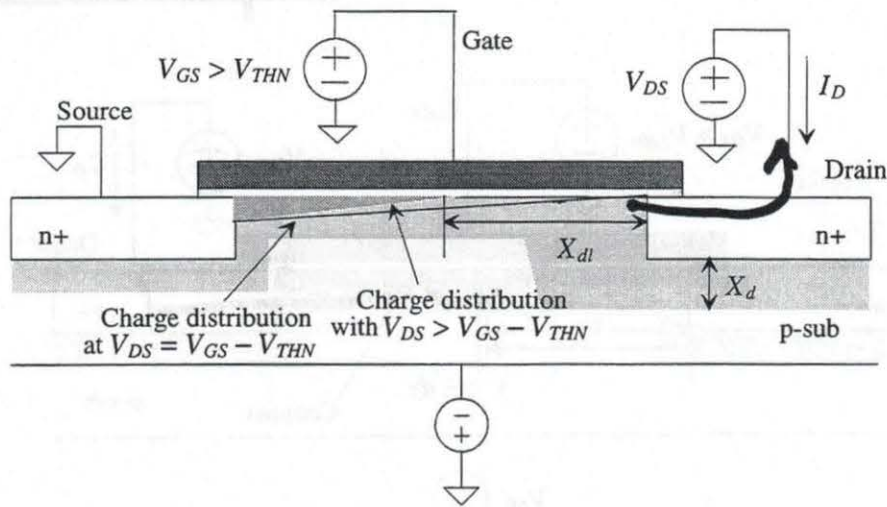


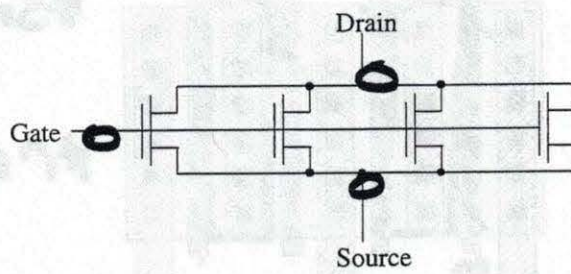
Figure 5.10 The MOSFET in saturation (pinched off).

$$I_D = \frac{K_P}{2} \cdot \frac{W}{L} (V_{GS} - V_{THN})^2$$

SATURATION  $V_{GS} > V_{THN}$

$$V_{DS} \geq V_{GS} - V_{THN}$$





**Figure 5.15** Parallel connection of MOSFETs used for layout of a large device.

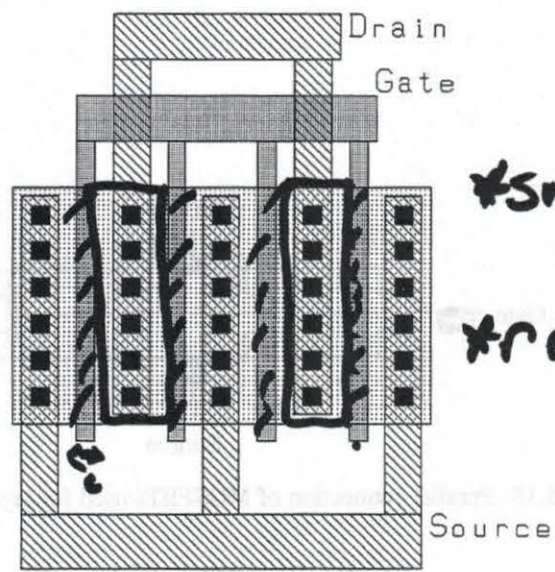


Figure 5.16 Layout of a large (width) MOSFET.

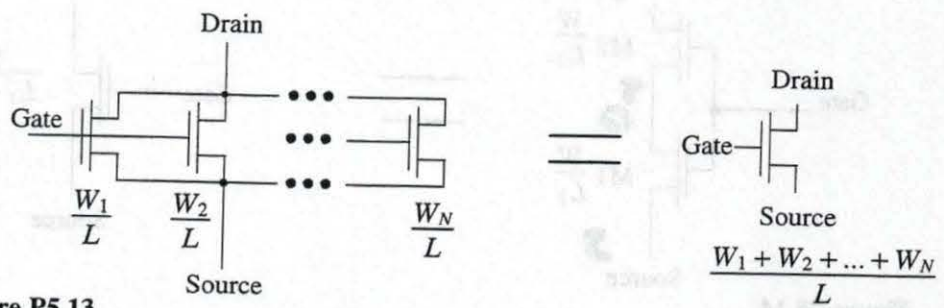
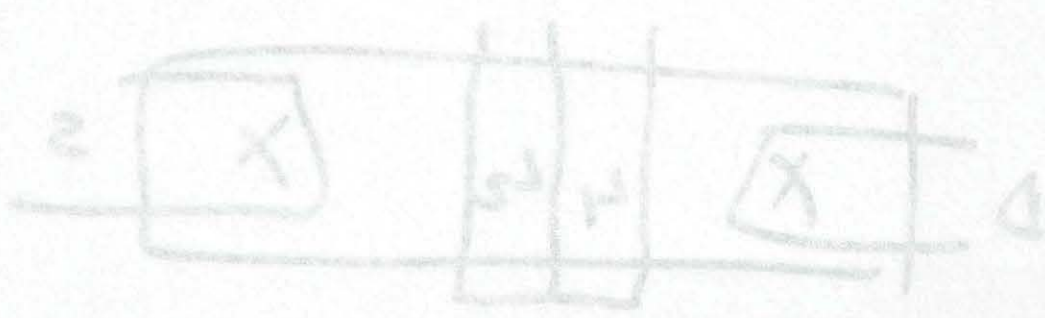


Figure P5.13

$$I_D = \frac{w_1 + w_2 + w_3 \dots}{L} \quad ( )$$



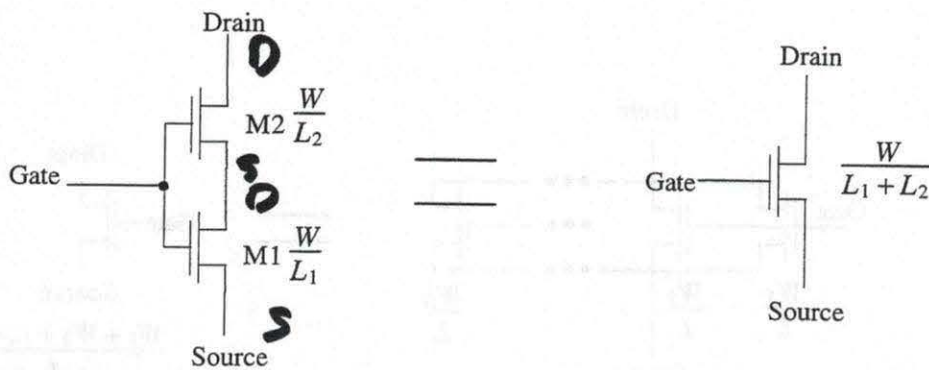
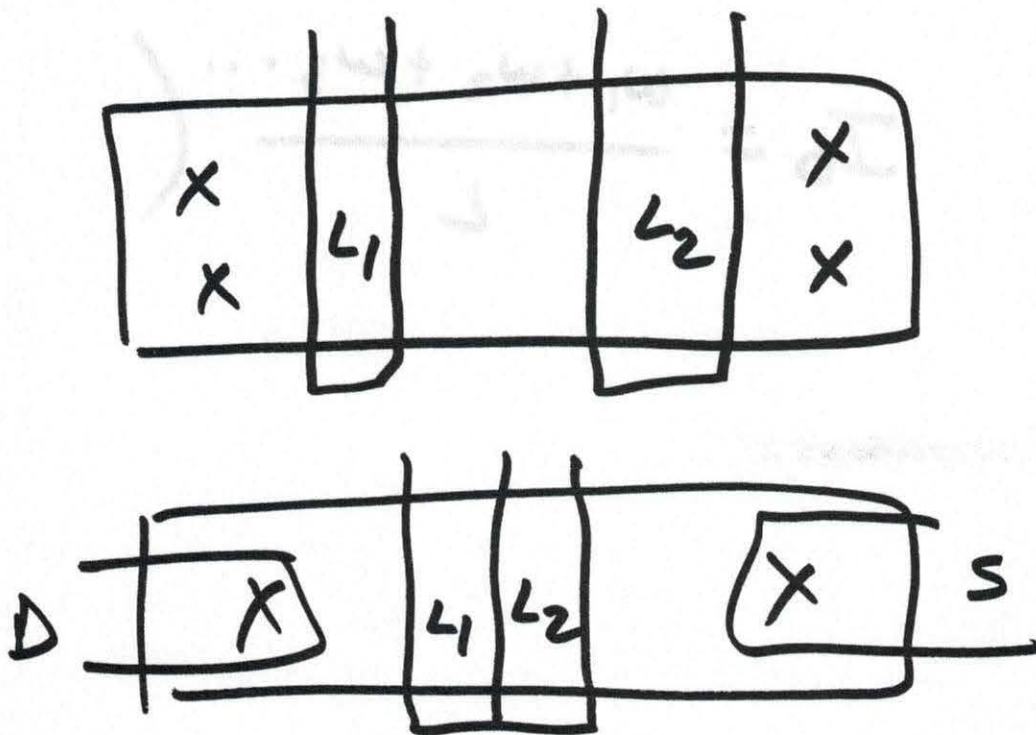


Figure P5.14



How to make a  
small  $\frac{w}{L}$  MOSFET

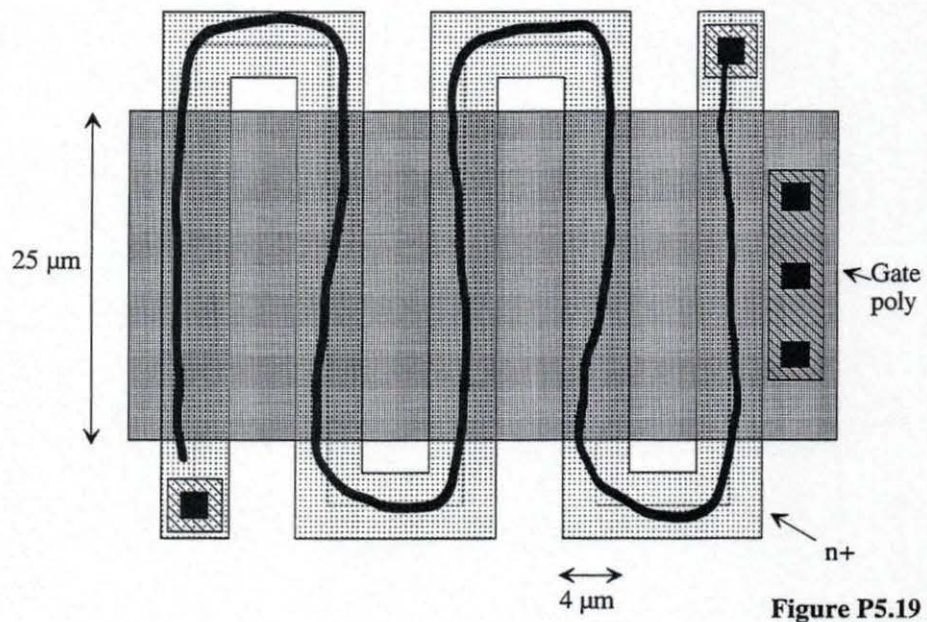


Figure P5.19

$$\frac{w}{L} = \frac{4}{100}$$



# **CMOS Digital Circuit Design**

## **Lesson 7: The Short Channel MOSFET**

Hardcopy Visuals

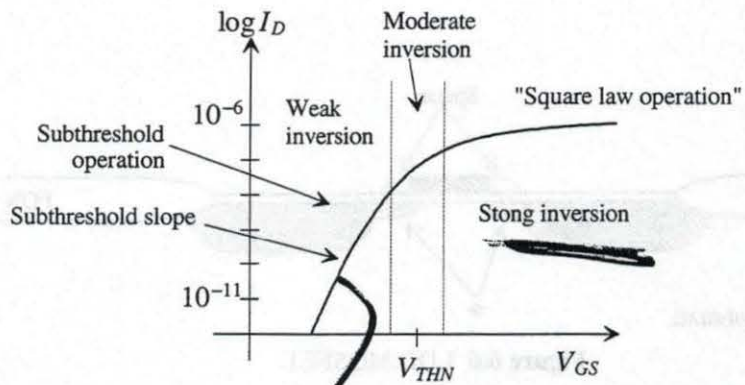
# CMOS Digital Circuit Design

## Lesson 7:

### The Short Channel MOSFET

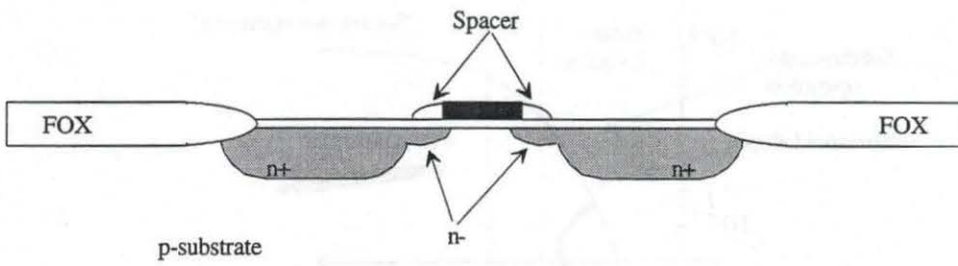
Hardcopy Visuals



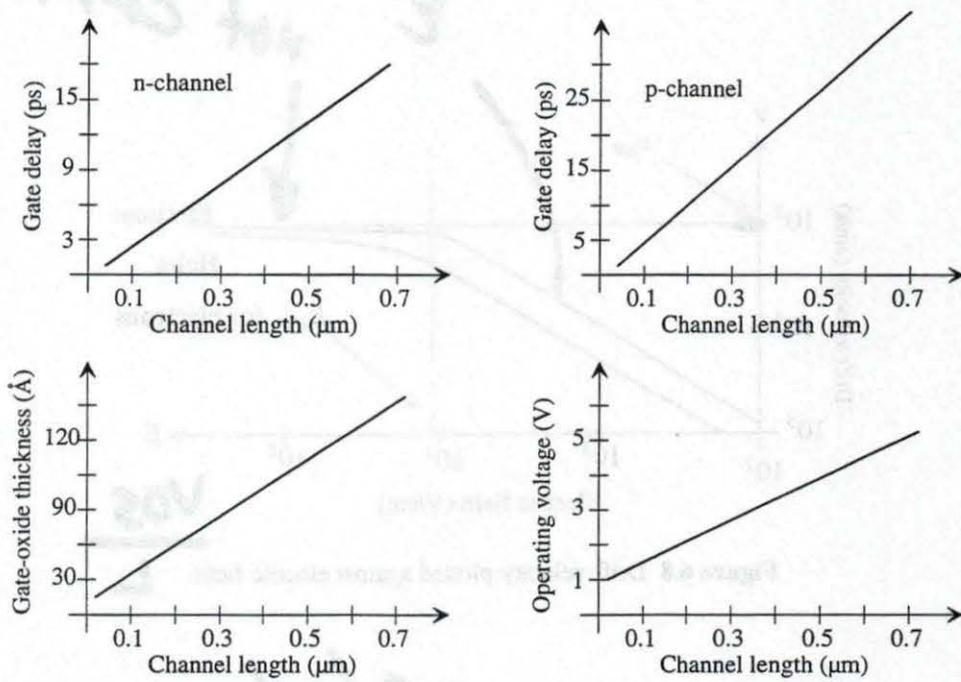


**Figure 6.5** Drain current plotted from weak to strong inversion.

$\propto e^{V_{GS}}$



**Figure 6.6** LDD MOSFET.



**Figure 6.7** Trends in MOS device scaling.

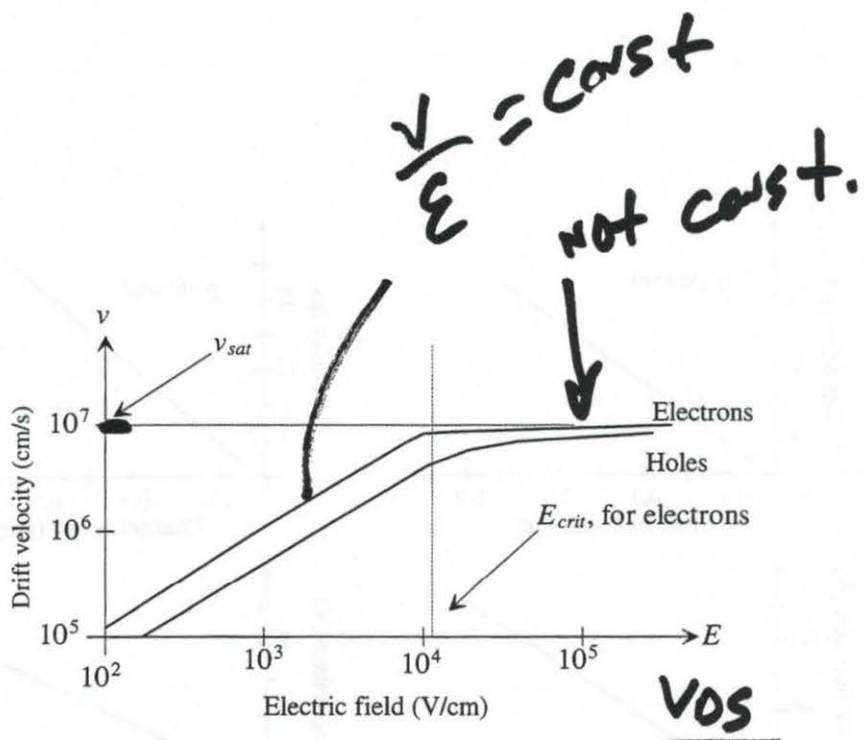
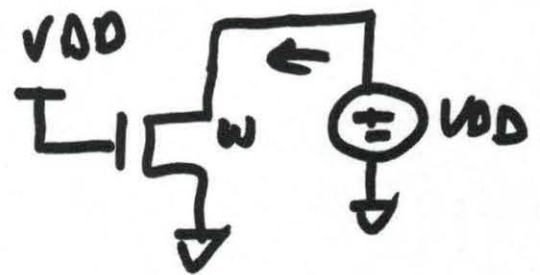
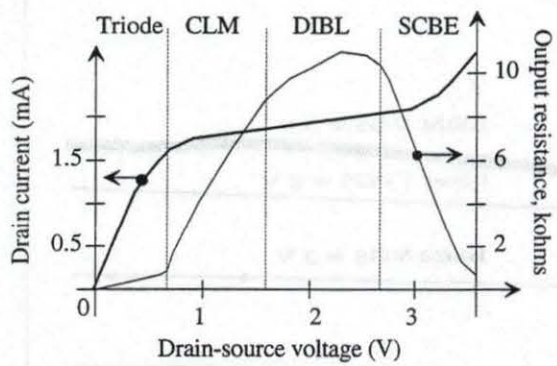


Figure 6.8 Drift velocity plotted against electric field.

$$I_D = \frac{v_{sat}}{L} \cdot C_{ox}' \cdot (V_{DS} - V_{THN} - \frac{V_{DS}}{SAT})$$

$$I_D = I_{drive} \cdot W$$



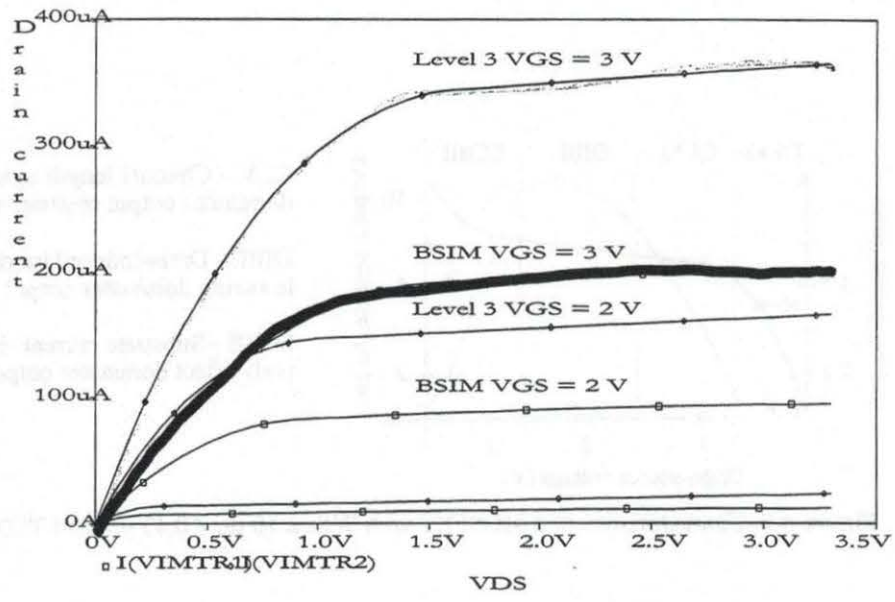


CLM - Channel length modulation dominates output resistance.

DIBL - Drain-induced barrier lowering dominates output resistance.

SCBE - Substrate current -induced body effect dominates output resistance.

Figure 6.9 Characteristics of a MOSFET with  $W/L = 10 \mu\text{m} / 0.43 \mu\text{m}$  and  $\text{TOX} = 75 \text{ \AA}$  [8].



**Figure C.1** Curves for a 0.9/0.6 n-channel MOSFET fabricated in CMOS14TB.

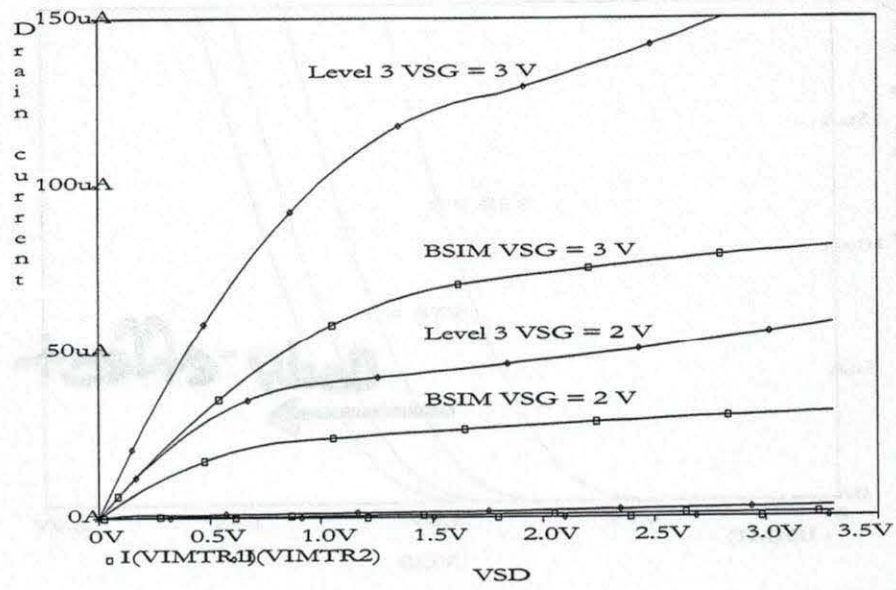


Figure C.2 Curves for a 0.9/0.6 p-channel MOSFET fabricated in CMOS14TB.

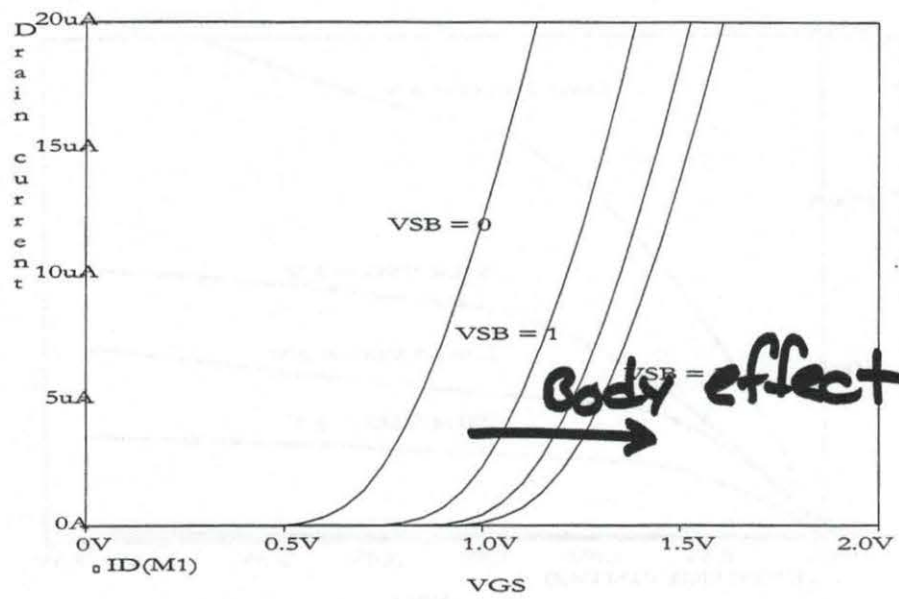


Figure C.3 Curves for a 0.9/0.6 n-channel MOSFET fabricated in the CMOS14TB process.



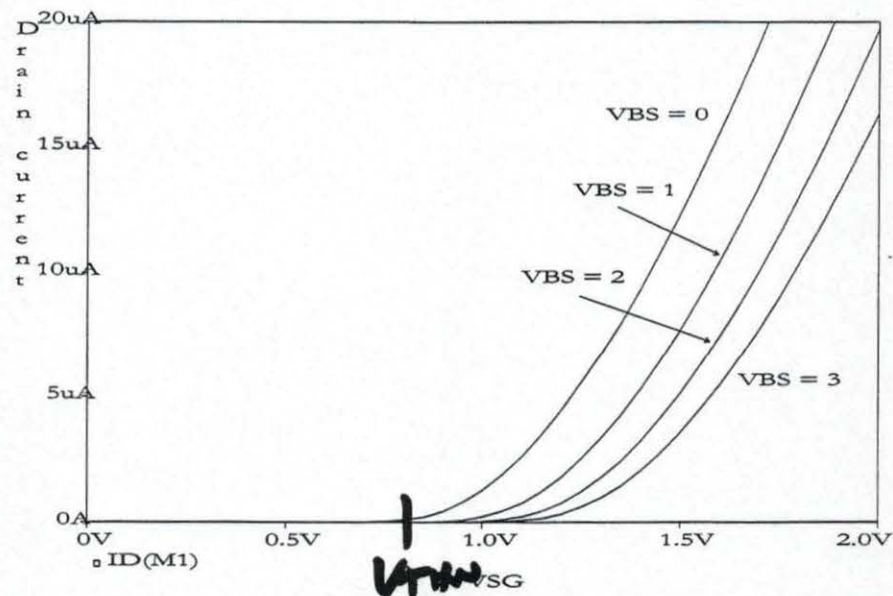


Figure C.4 Curves for a 0.9/0.6 p-channel MOSFET fabricated in the CMOS14TB process.

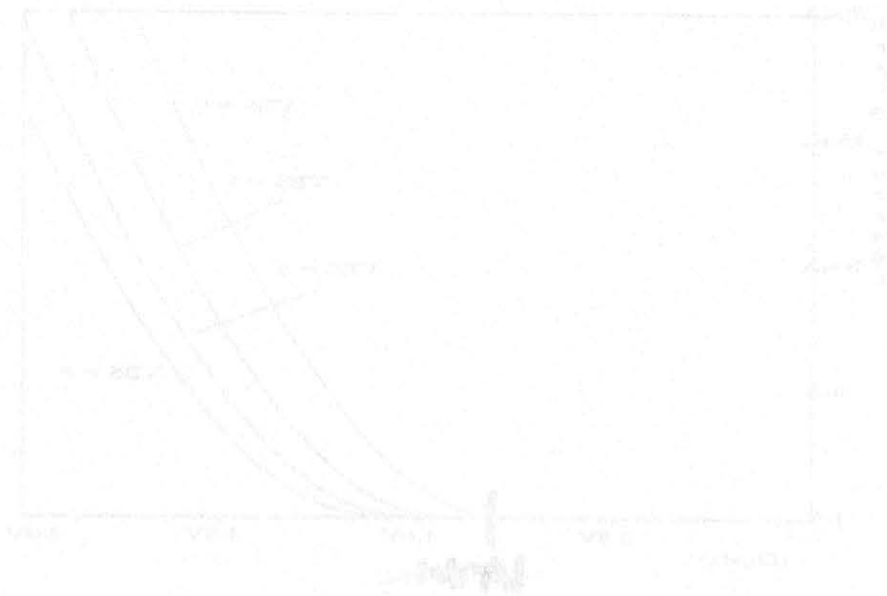


Figure 1: Current (I) vs. Voltage (V) characteristics of a diode at different temperatures (20°C, 30°C, 40°C, 50°C).

# **CMOS Digital Circuit Design**

## **Lesson 8: The Digital Model of a MOSFET**

Hardcopy Visuals

CMOS Digital Circuit Design

Lesson 8:  
The Digital Model of a  
MOSFET

Hardcopy Visuals

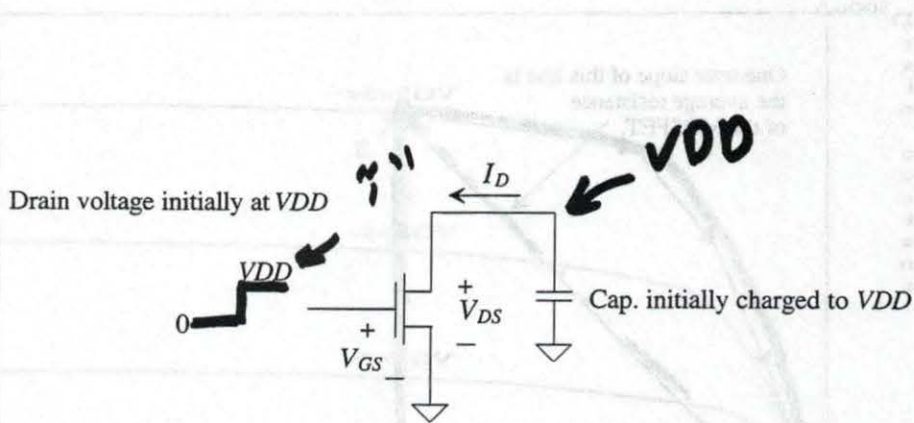
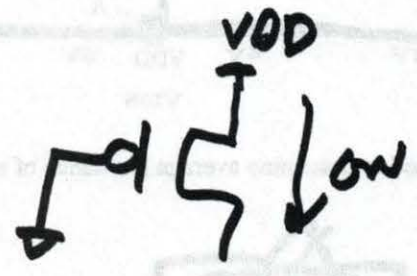


Figure 10.1 MOSFET switching circuit.



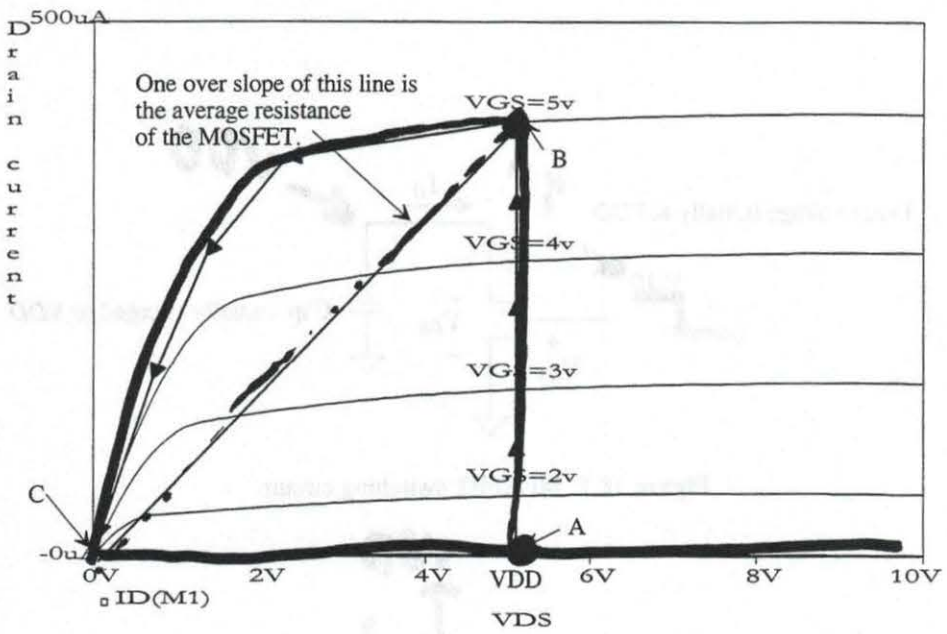
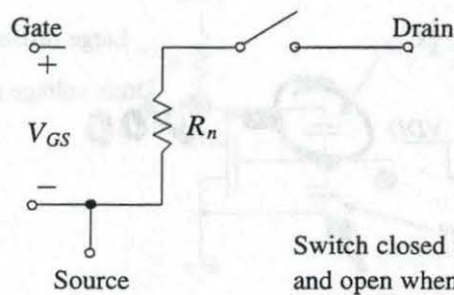


Figure 10.2 Diagram used to determine average resistance of a MOSFET during switching.





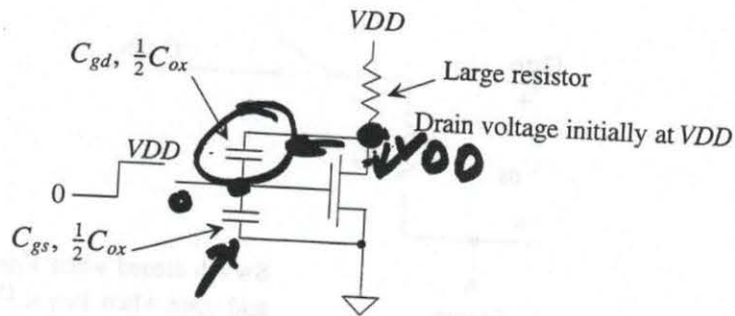
Switch closed when  $V_{GS} > V_{DD}/2$   
and open when  $V_{GS} < V_{DD}/2$

Figure 10.3 Simple digital MOSFET model.

$$R_N = \frac{V_{DD}}{\frac{K_P}{2} \frac{W}{L} (V_{DD} - V_{THN})^2}$$

$$R_N = R_N' \cdot \frac{L}{W} = \underline{\underline{12k \cdot \frac{L}{W}}}$$

$$R_P' = 36k \quad \underline{\underline{R_P = R_P' \cdot \frac{L}{W}}}$$

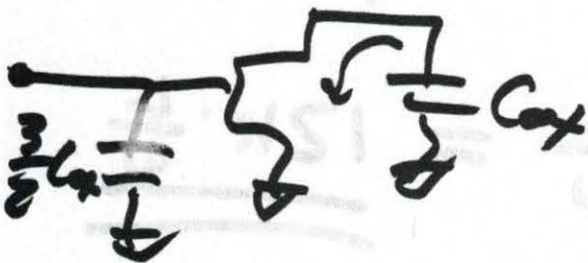


$$CV = Q$$

Figure 10.4 MOSFET switching circuit with capacitances.

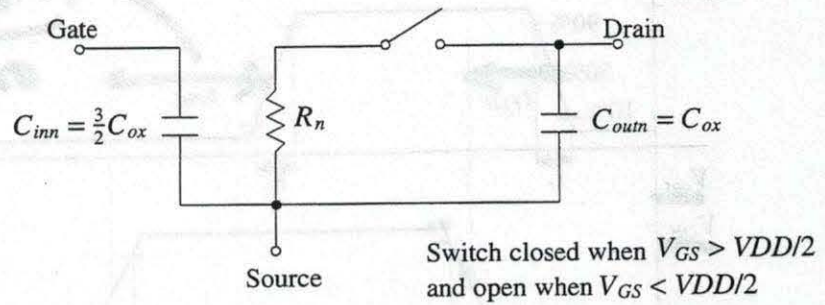
$$VDD \cdot \frac{1}{2} C_{ox} + \frac{1}{2} C_{ox} \cdot 2VDD$$

$$VDD \cdot \frac{3}{2} C_{ox} = C_{in}$$



$$C_{in} = C_{ox}$$





**Figure 10.5** Simple digital MOSFET model.

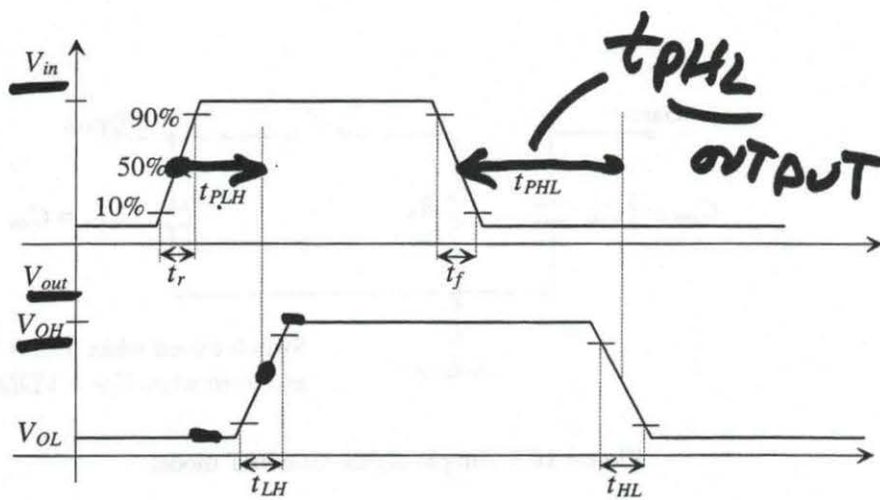


Figure 10.6 Definition of delays and transition times.

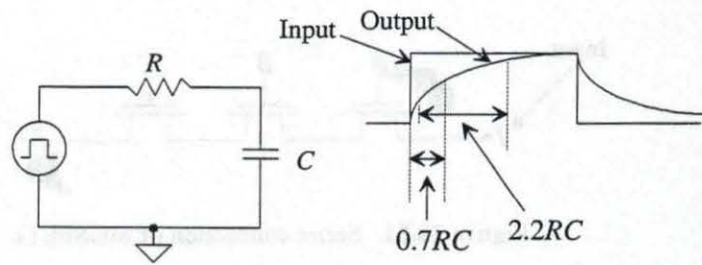


Figure 10.7 Delay- and risetime for a simple RC circuit.

$$t_{\text{delay}} \approx RC$$

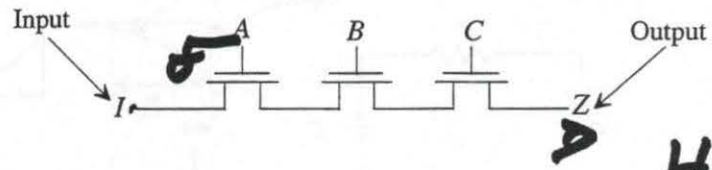


Figure 10.11 Series connection of MOSFETs.

Hi-Z  
tri-state

*Handwritten:*  $RC = \tau$

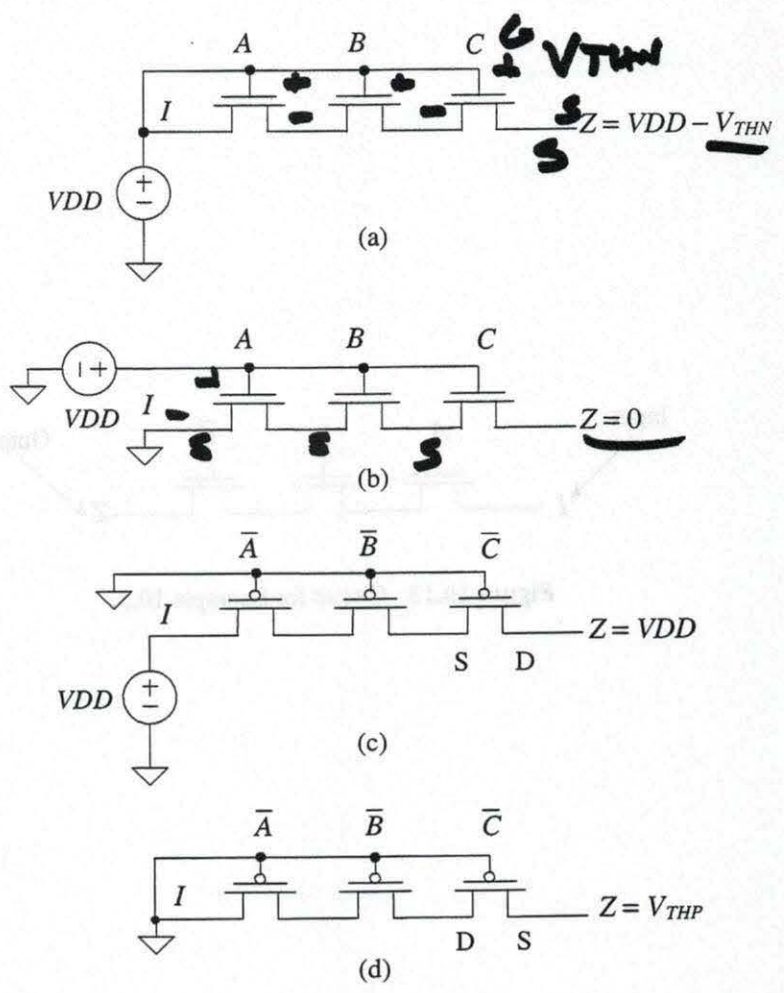
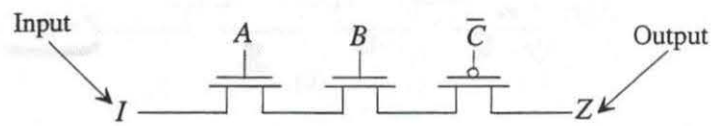
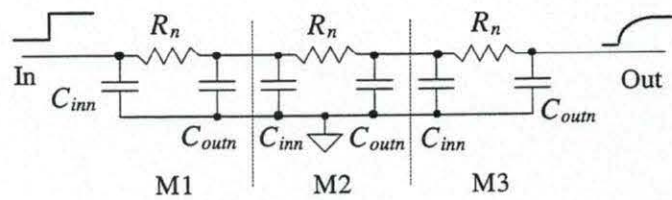
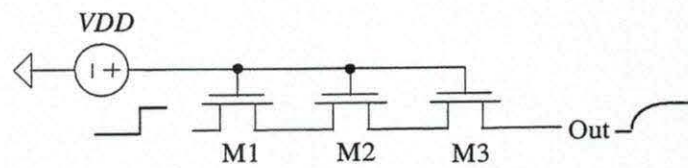


Figure 10.12 DC operation of series-connected MOSFETs.



**Figure 10.13** Circuit for Example 10.3.



**Figure 10.14** Modeling delay through series-connected MOSFETs.



Figure 101: Polymerization of styrene in benzene solution at 50°C

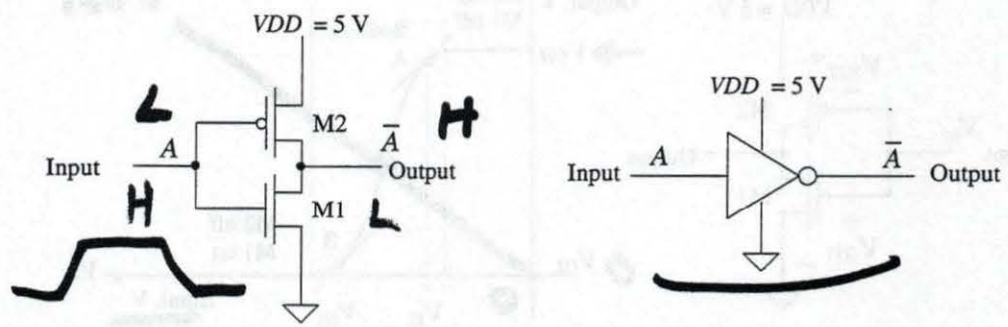


# **CMOS Digital Circuit Design**

## **Lesson 9: Inverter Operation I**

Hardcopy Visuals





**Figure 11.1** The CMOS inverter, schematic, and logic symbol.

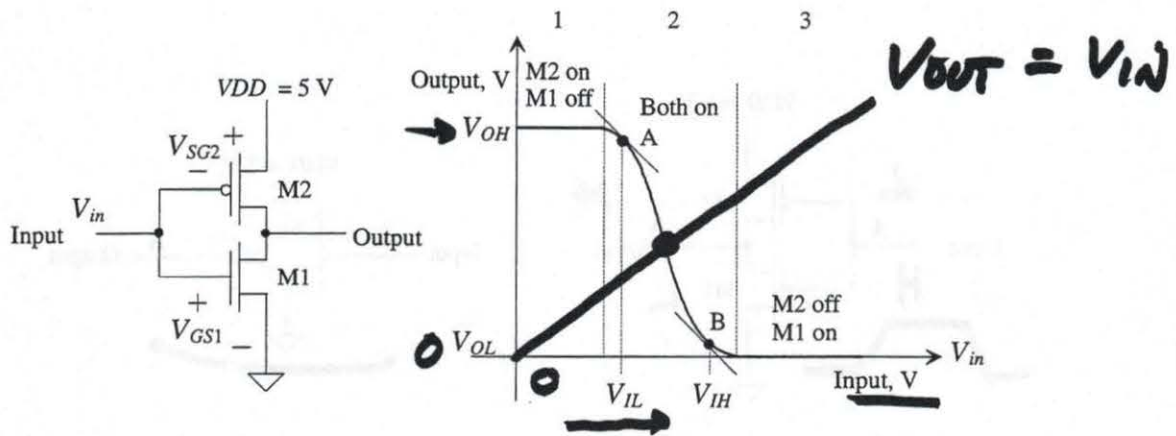


Figure 11.2 The CMOS inverter transfer characteristics.

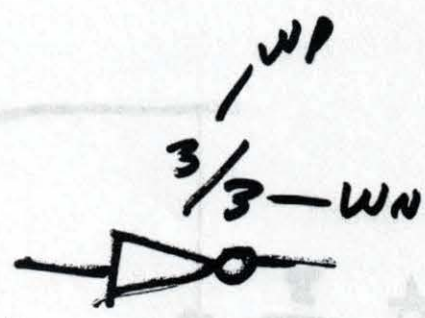
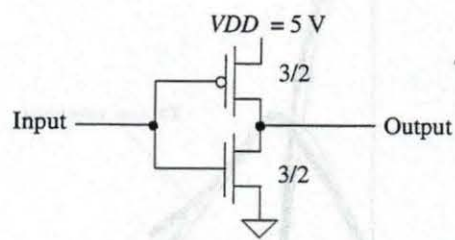


Figure Ex11.1

Figure 11.1 Transfer characteristics of a minimum-size inverter with  $W/L = 3/2$

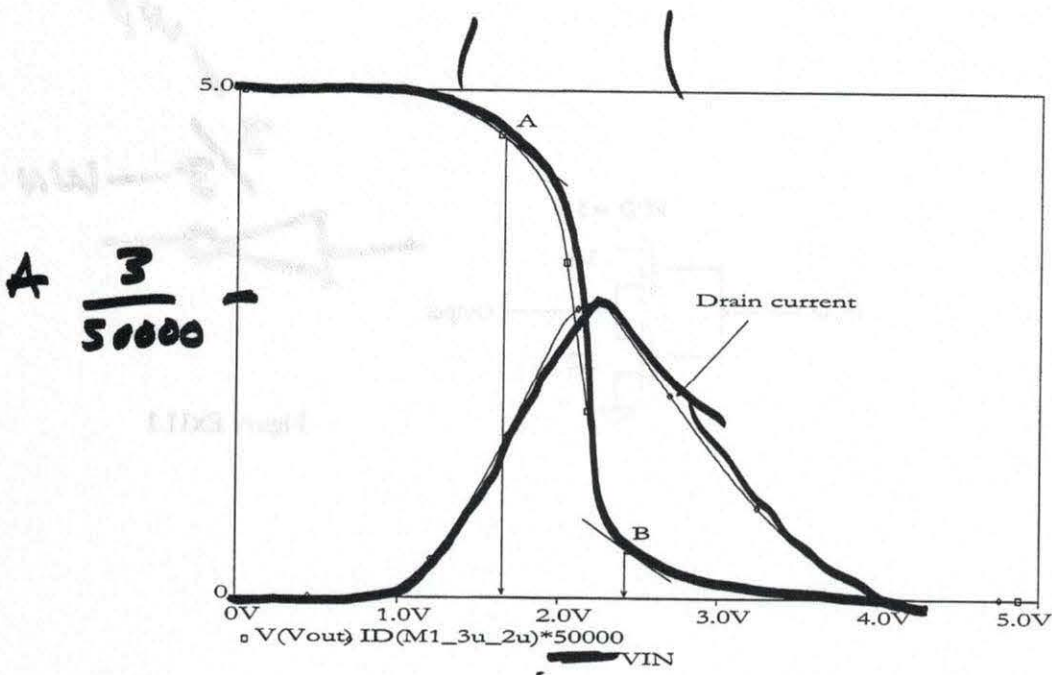
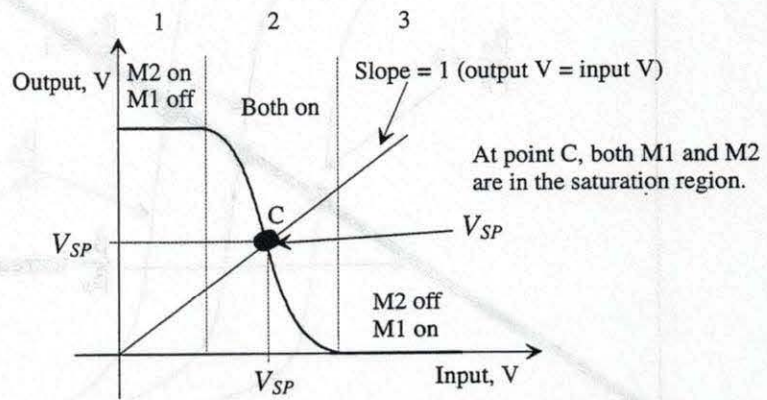


Figure 11.3 Transfer characteristics of a minimum-size inverter used in Example 11.1.



**Figure 11.4** Transfer characteristics of the inverter showing the switching point.



$$R_p \propto \left( K_{PP} \cdot \frac{W}{L} \right)^{-1}$$

$$R_n \propto \left( K_{PN} \cdot \frac{W}{L} \right)^{-1}$$

$\beta_n$

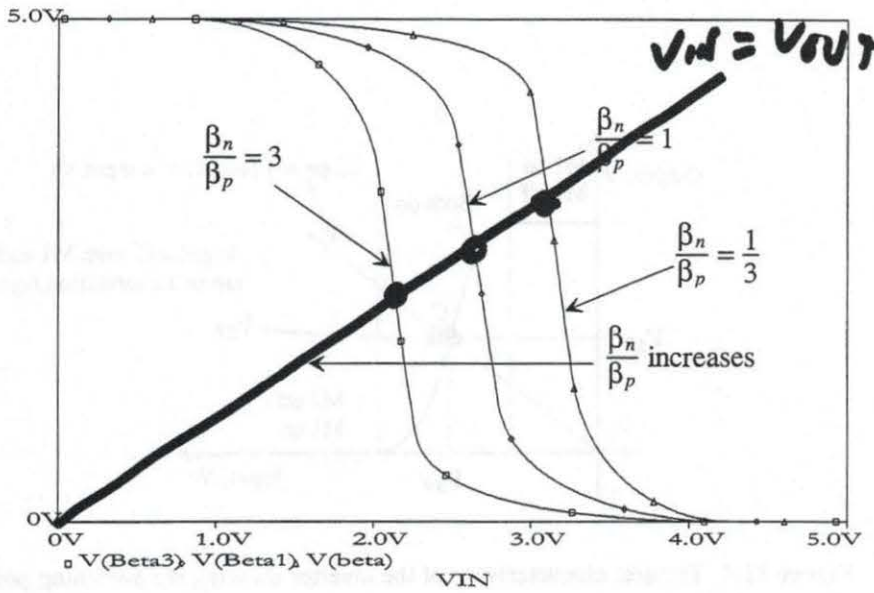
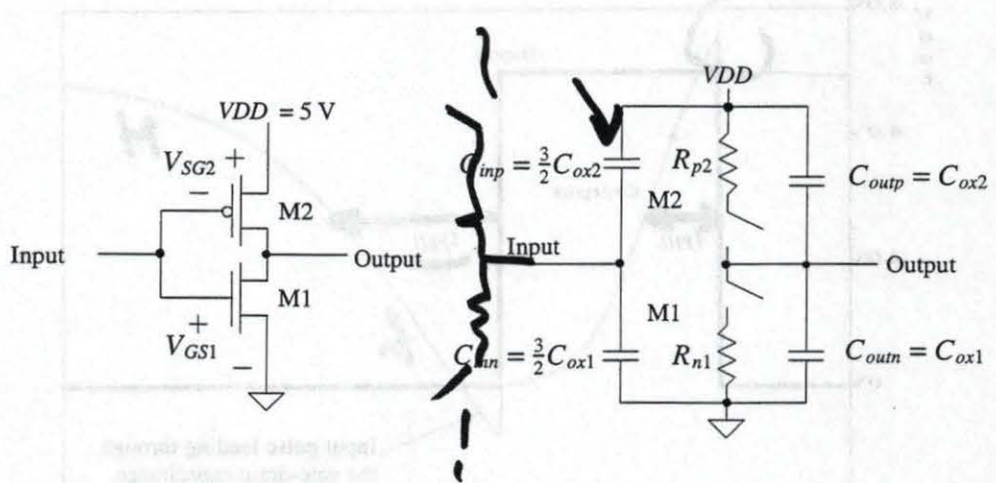


Figure 11.5 Sizing of the CMOS inverter.





**Figure 11.6** The CMOS inverter switching characteristics using the digital model.

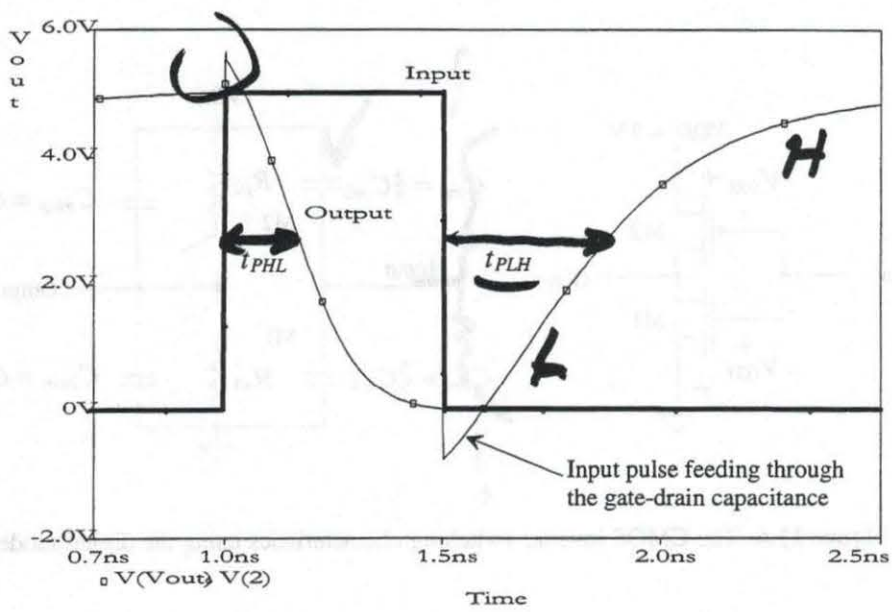


Figure 11.7 Intrinsic inverter delay.



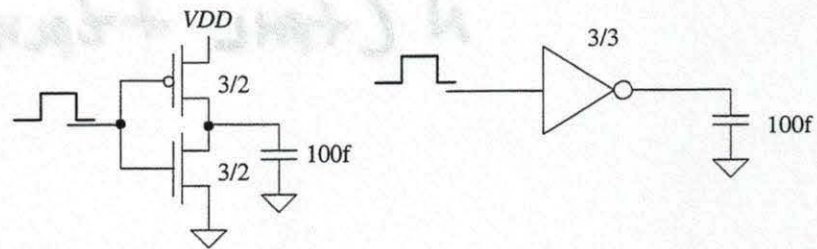


Figure 11.8 Inverter driving a 100 fF load capacitance in Ex. 11.6.

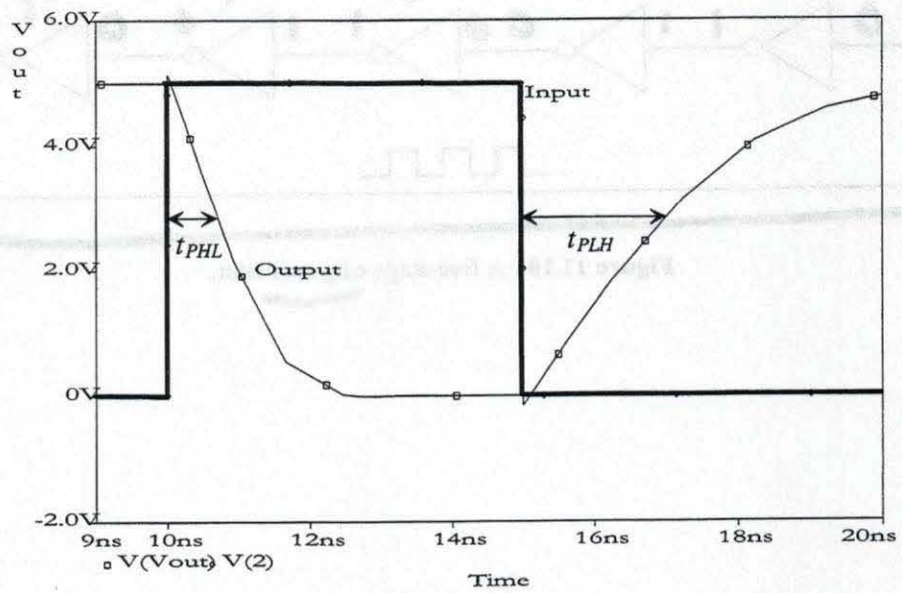


Figure 11.9 Simulation results of minimum-size inverter driving 100 fF.

$$\frac{1}{N(t_{pHL} + t_{pLH})} = f_{osc}$$

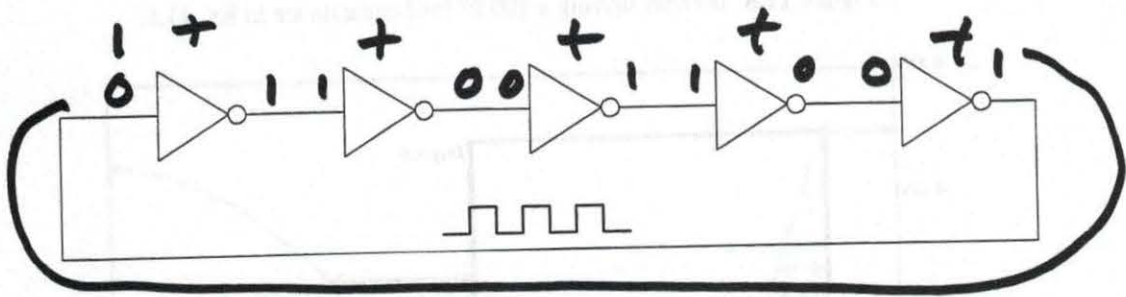
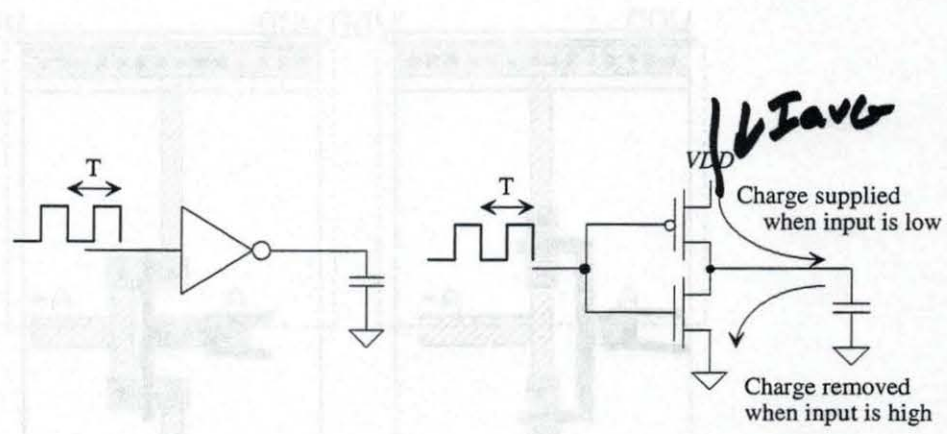
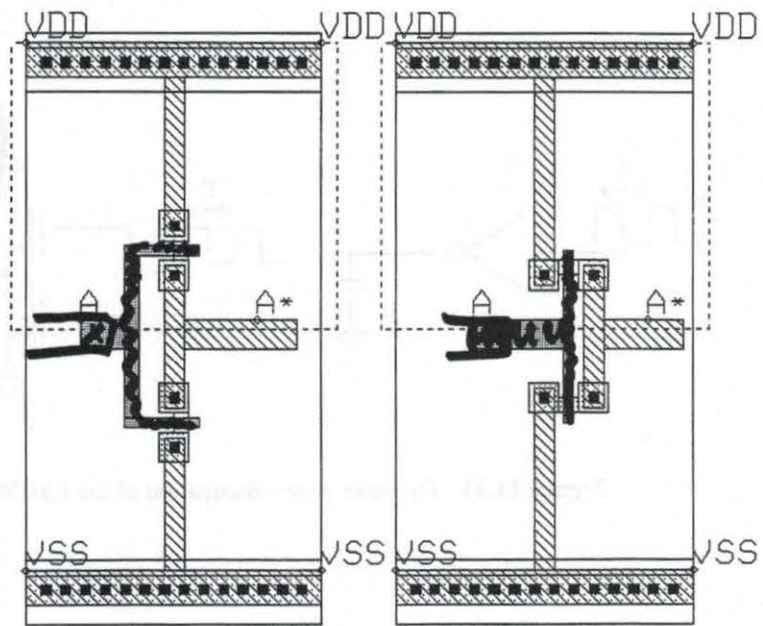


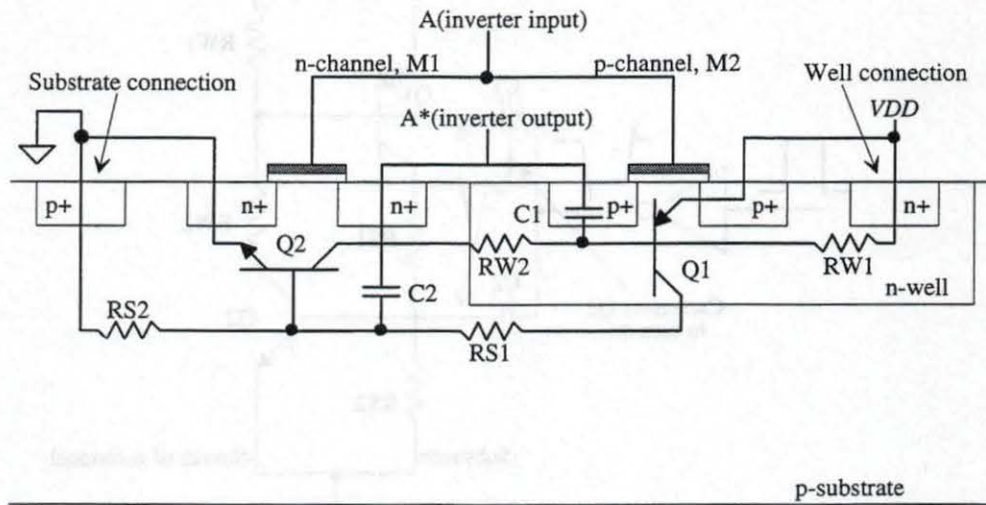
Figure 11.10 A five-stage ring oscillator.



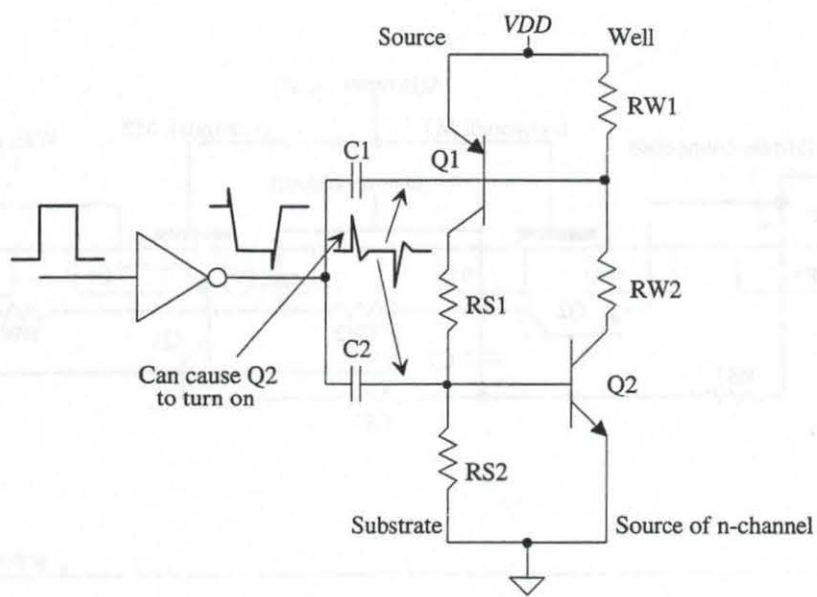
**Figure 11.11** Dynamic power dissipation of the CMOS inverter.



**Figure 11.13** Two inverter layout styles.

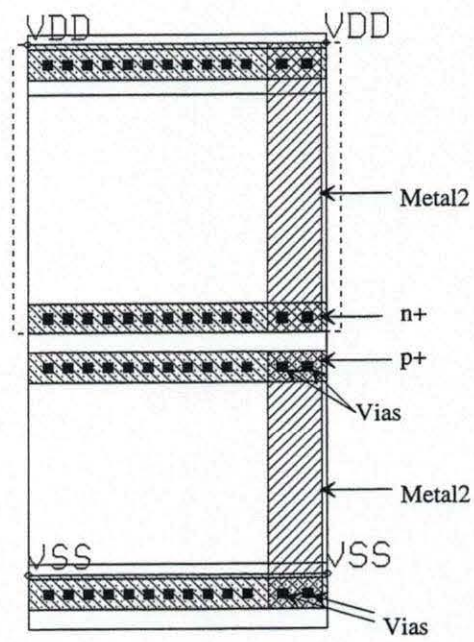


**Figure 11.14** Cross-sectional view of an inverter showing parasitic bipolar transistors and resistors.



**Figure 11.15** Schematic used to describe latch-up.





**Figure 11.16** Alternative standard-cell frame used for better latch-up protection.



Figure 1: Cross-section of the multi-layered structure showing the different layers and their thicknesses.

# **CMOS Digital Circuit Design**

## **Lesson 10: Inverter Operation II**

Hardcopy Visuals



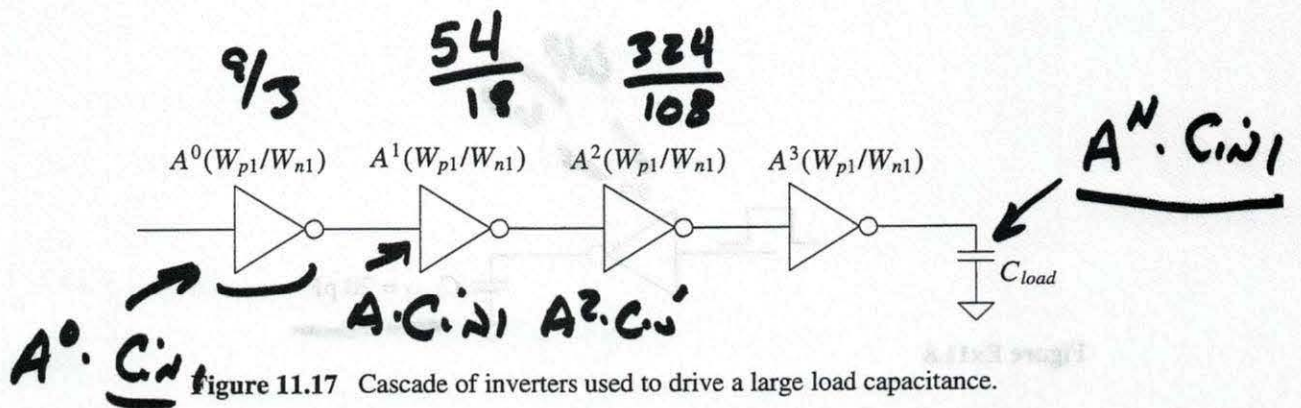


Figure 11.17 Cascade of inverters used to drive a large load capacitance.

$$N = \ln \frac{C_{load}}{C_{in}}$$

$$A = \left[ \frac{C_{load}}{C_{in}} \right]^{1/N}$$

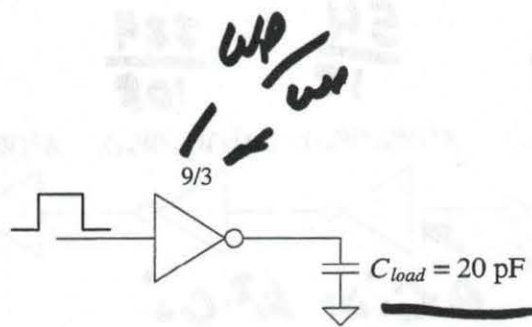


Figure Ex11.8

$t_{PHL} + t_{PLH}$  320ns!

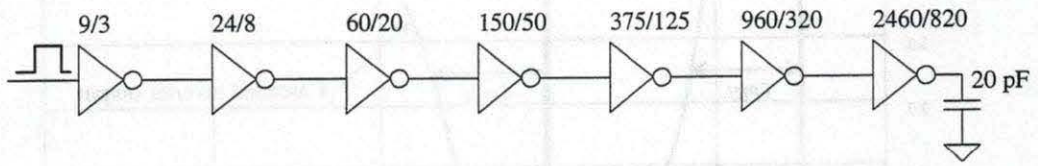
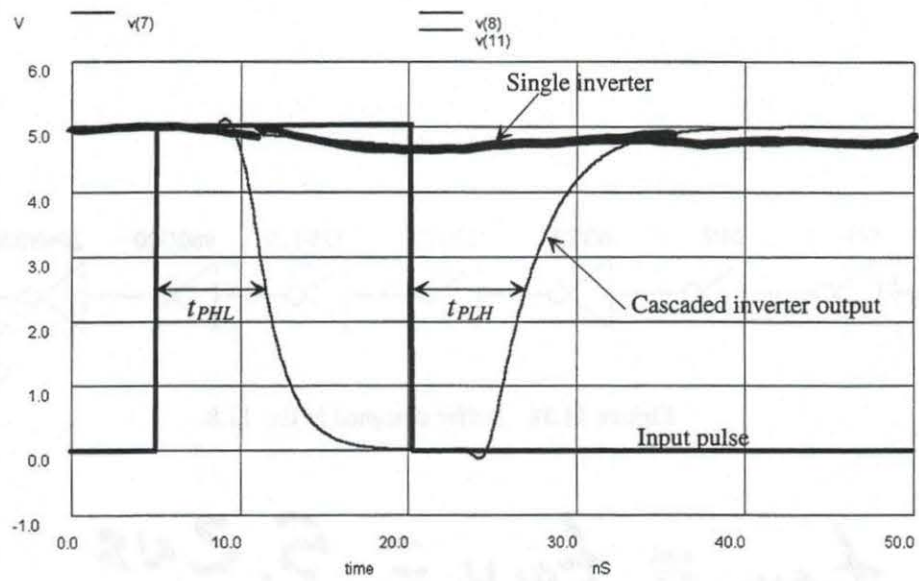


Figure 11.18 Buffer designed in Ex. 11.8.

$$t_{PHL} = t_{PLH} = \underline{\underline{5.2 \text{ ns}}}$$



**Figure 11.19** Simulation results from Ex. 11.8.



# Example 11.9

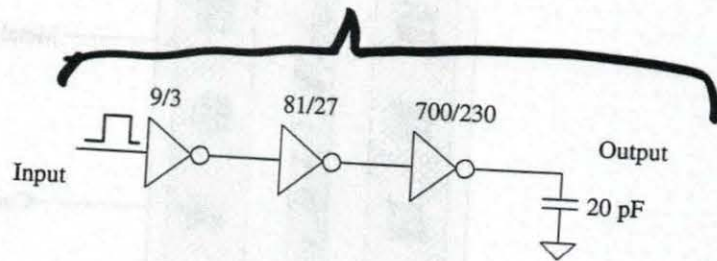
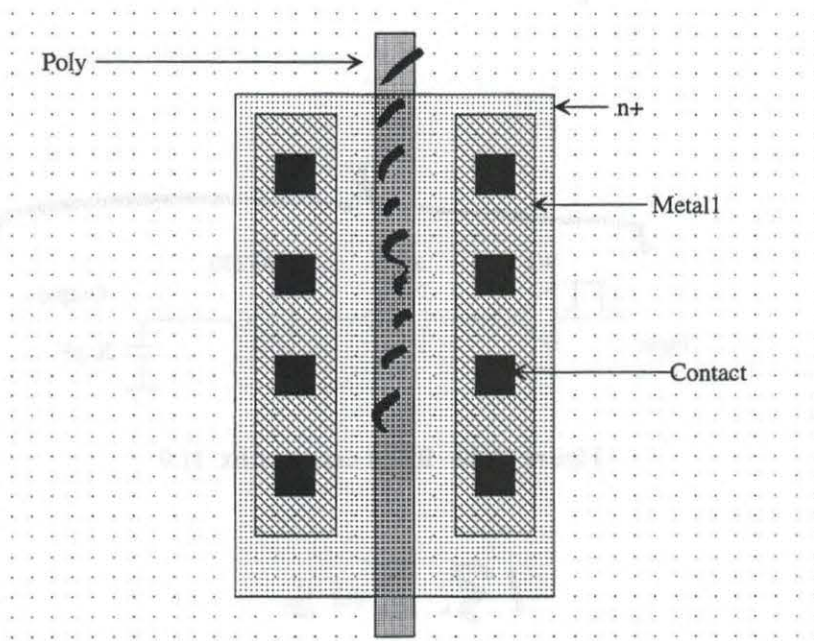


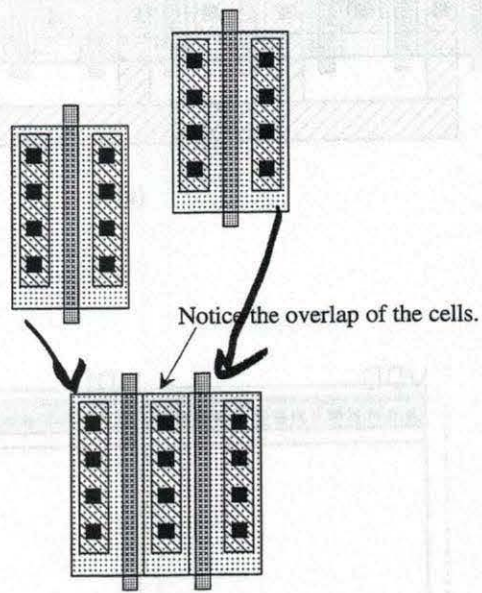
Figure 11.20 Buffer design of Ex. 11.9.

13.2 ns

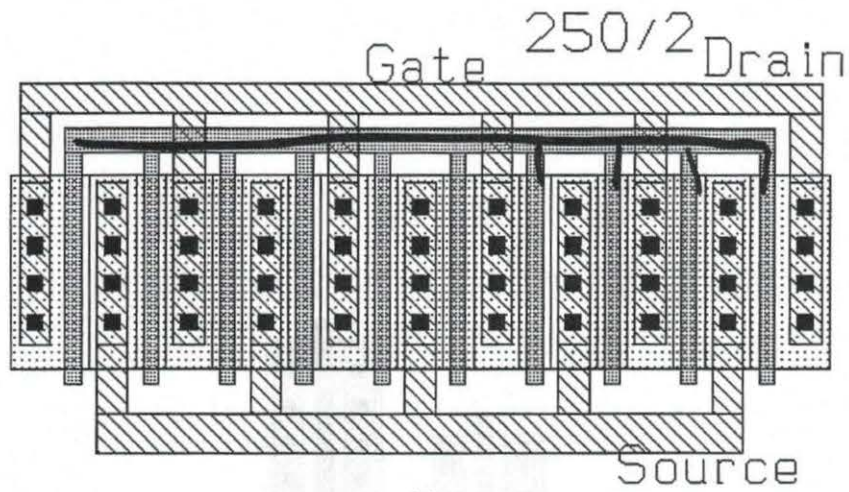
3 ns more



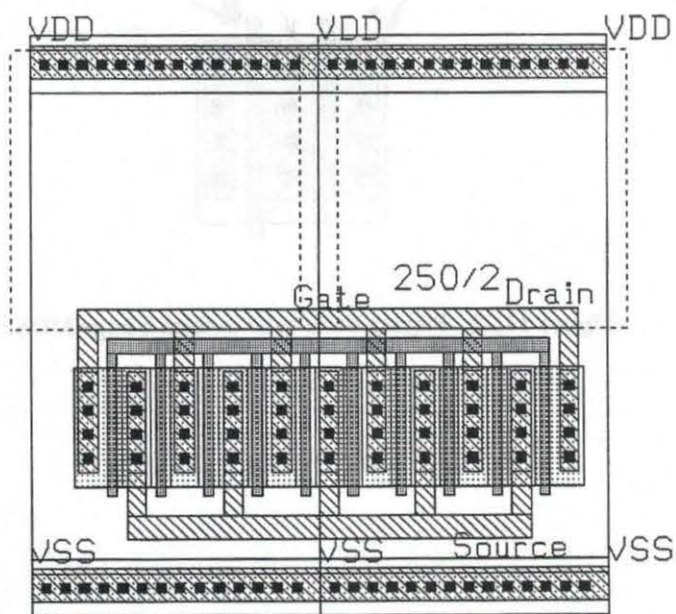
**Figure 11.21** Layout of an n-channel MOSFET measuring  $25\ \mu\text{m}$  (width) by  $2\ \mu\text{m}$  (length).



**Figure 11.22** Placing basic cells to form a large MOSFET.



(a)



(b)

**Figure 11.23** (a) Layout of a 250 by 2 n-channel MOSFET and (b) using a standard-cell frame.

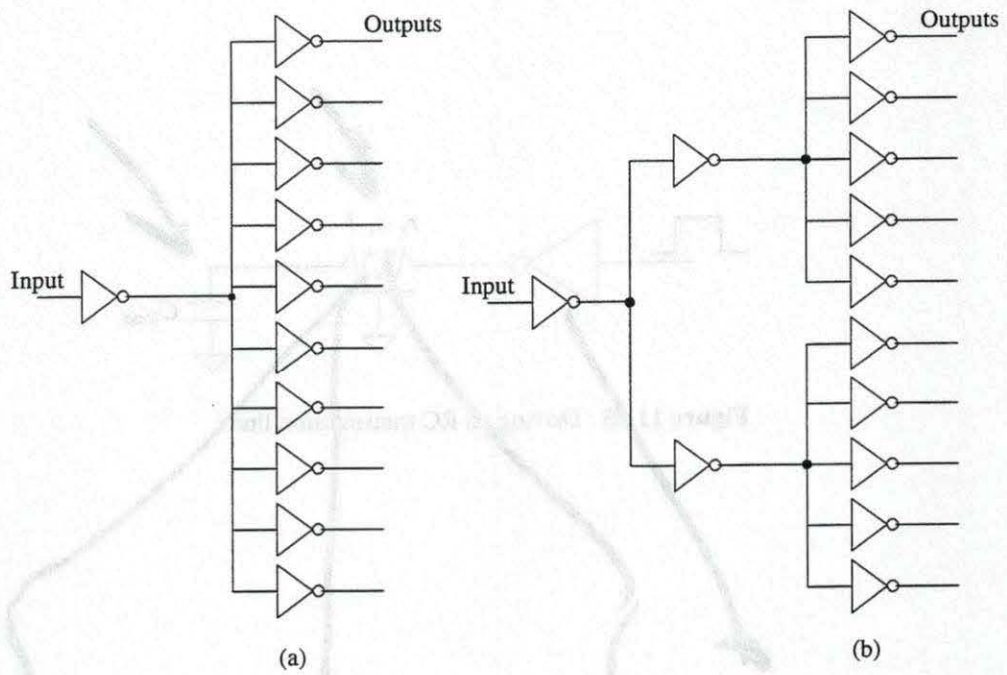


Figure 11.24 Distributed drivers.

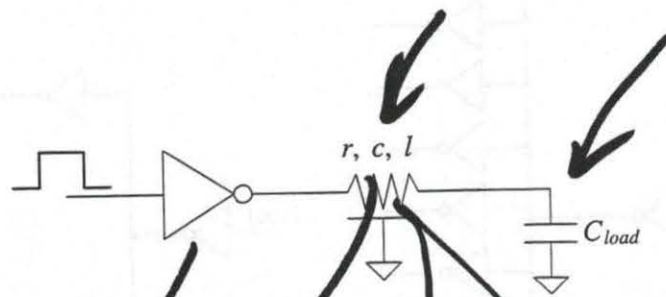


Figure 11.25 Driving an RC transmission line.



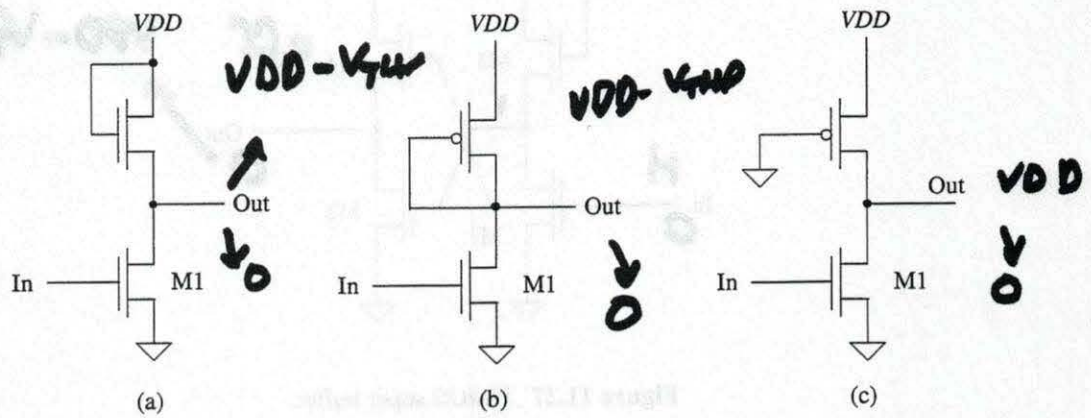


Figure 11.26 Other inverter configurations.

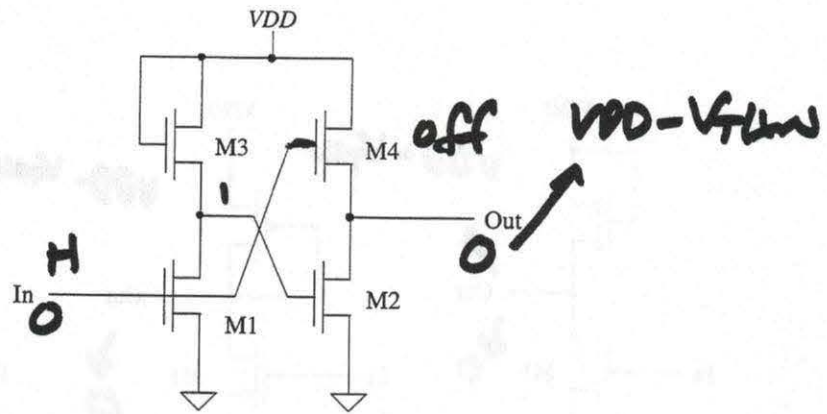
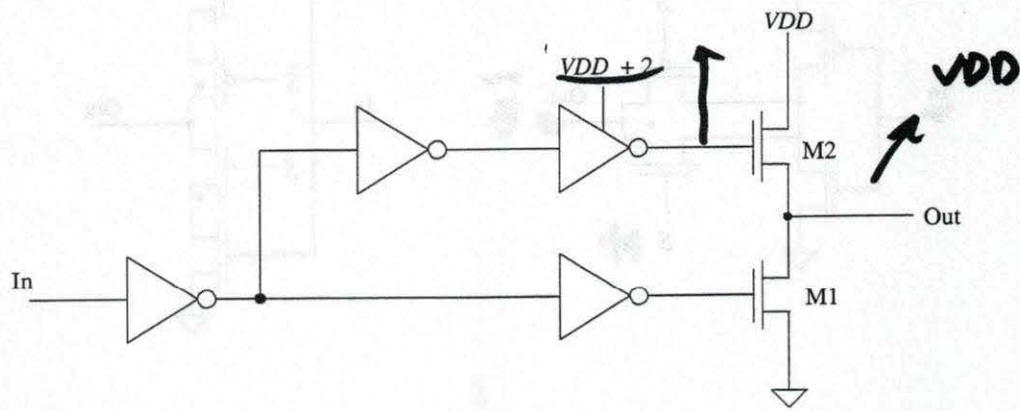
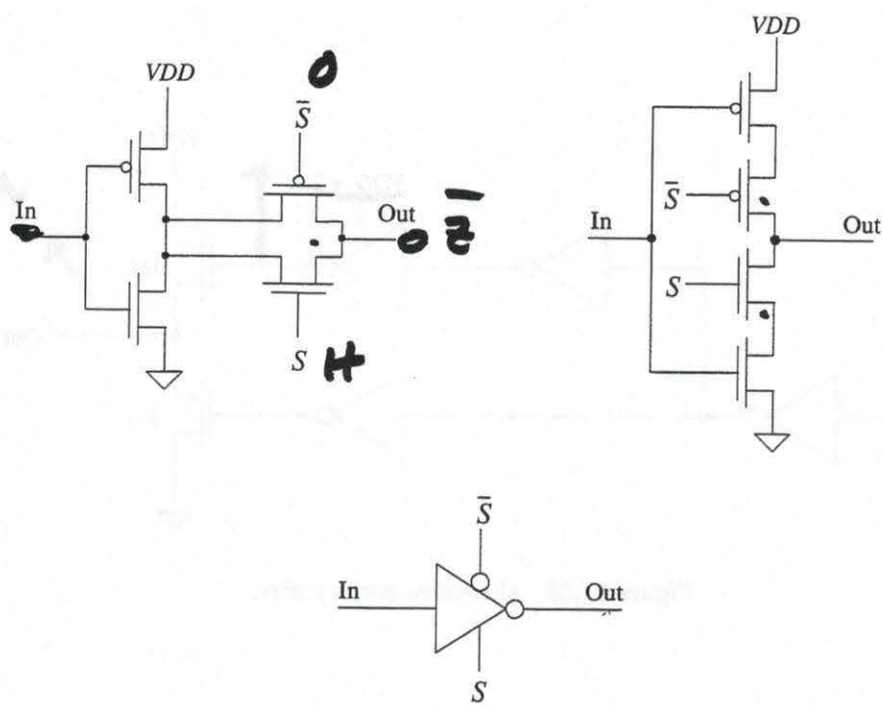


Figure 11.27 NMOS super buffer.





**Figure 11.28** Alternative output buffer.



**Figure 11.29** Circuits and logic symbol for the tri-state inverter.

# **CMOS Digital Circuit Design**

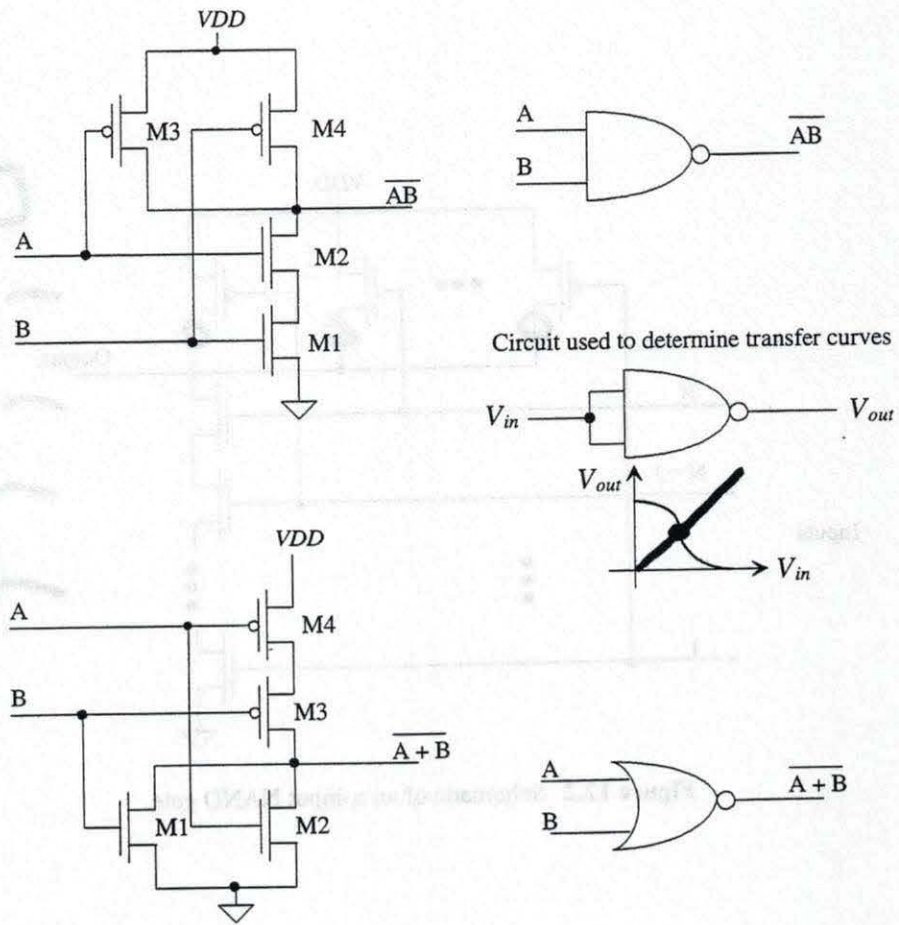
## **Lesson 11: Static Logic Gates**

Hardcopy Visuals

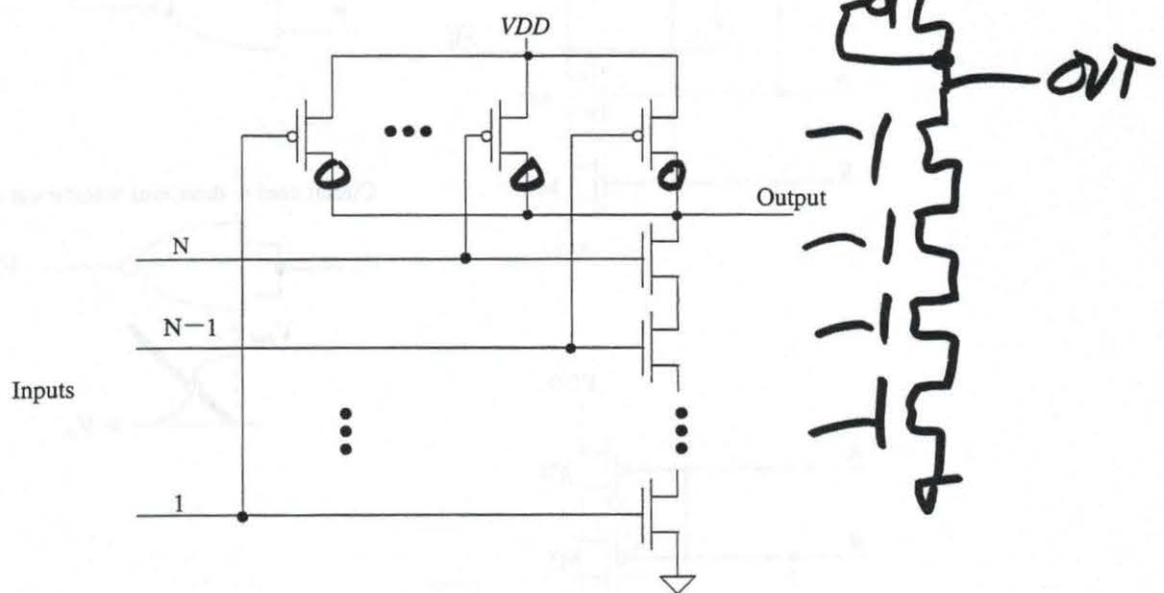
# CMOS Digital Circuit Design

## Lesson 11: Static Logic Gates

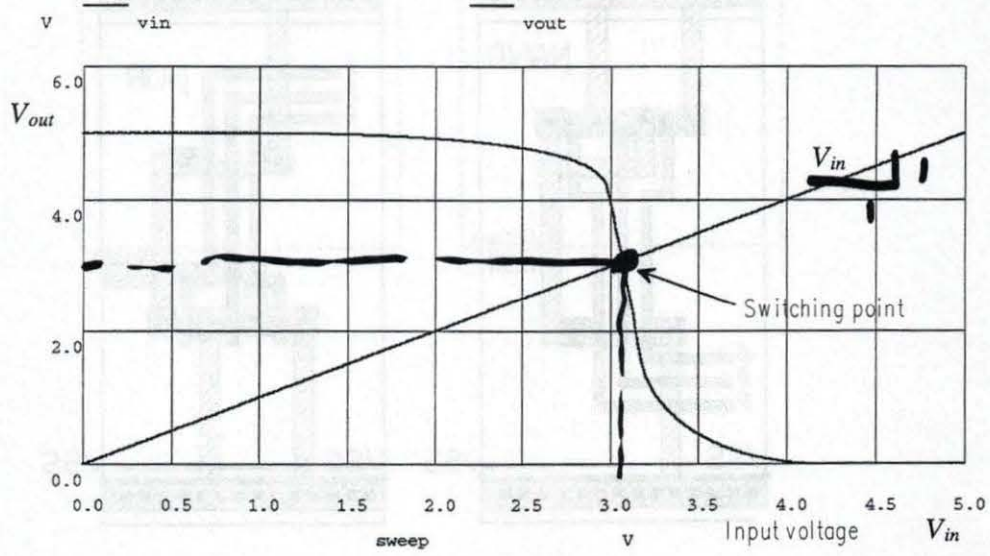
Hardcopy Visuals



**Figure 12.1** NAND and NOR gate circuits and logic symbols.



**Figure 12.2** Schematic of an n-input NAND gate.



**Figure 12.3** Voltage transfer characteristics of the three-input minimum-size NAND gate.

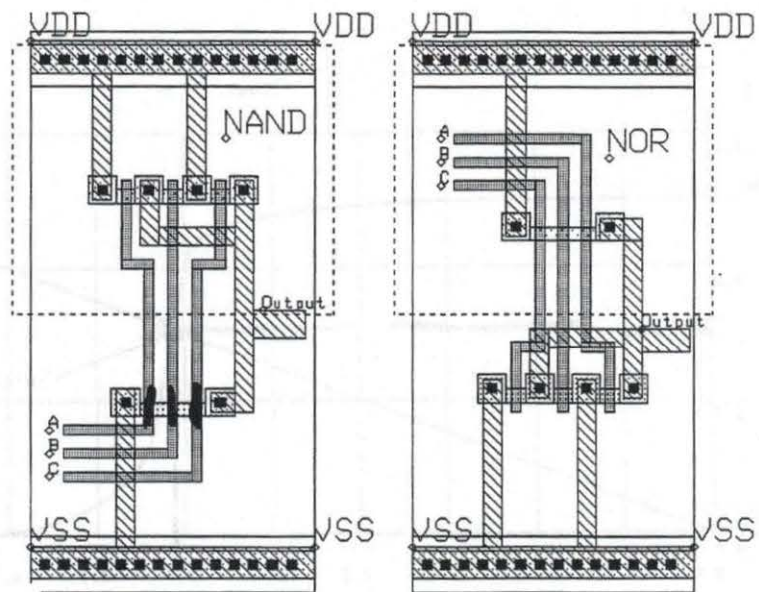
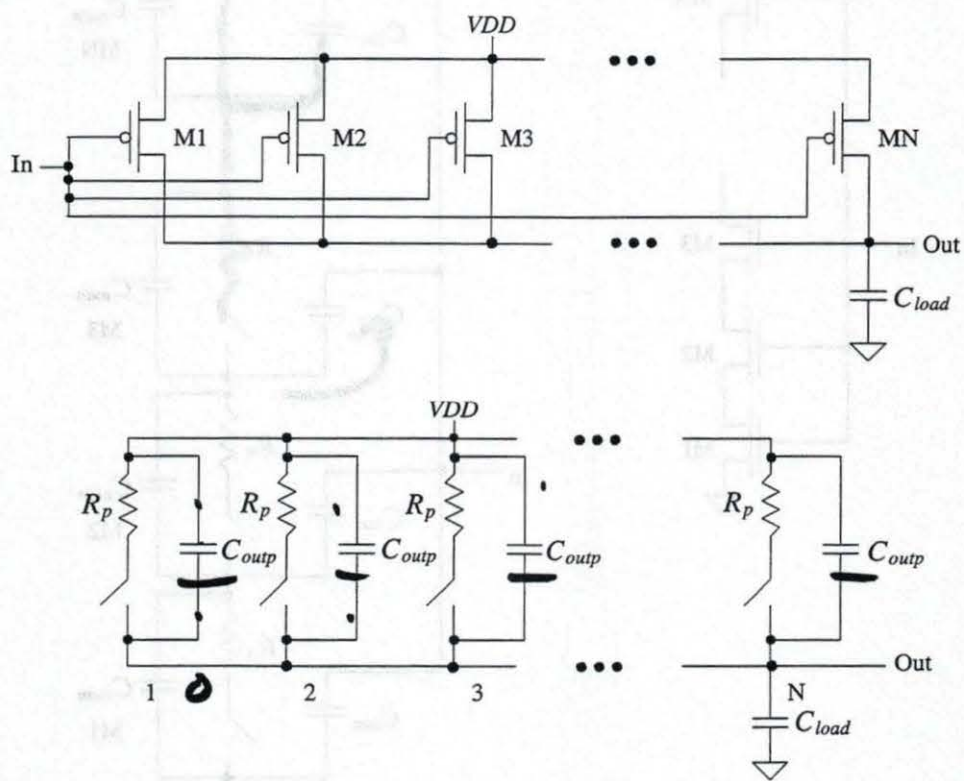
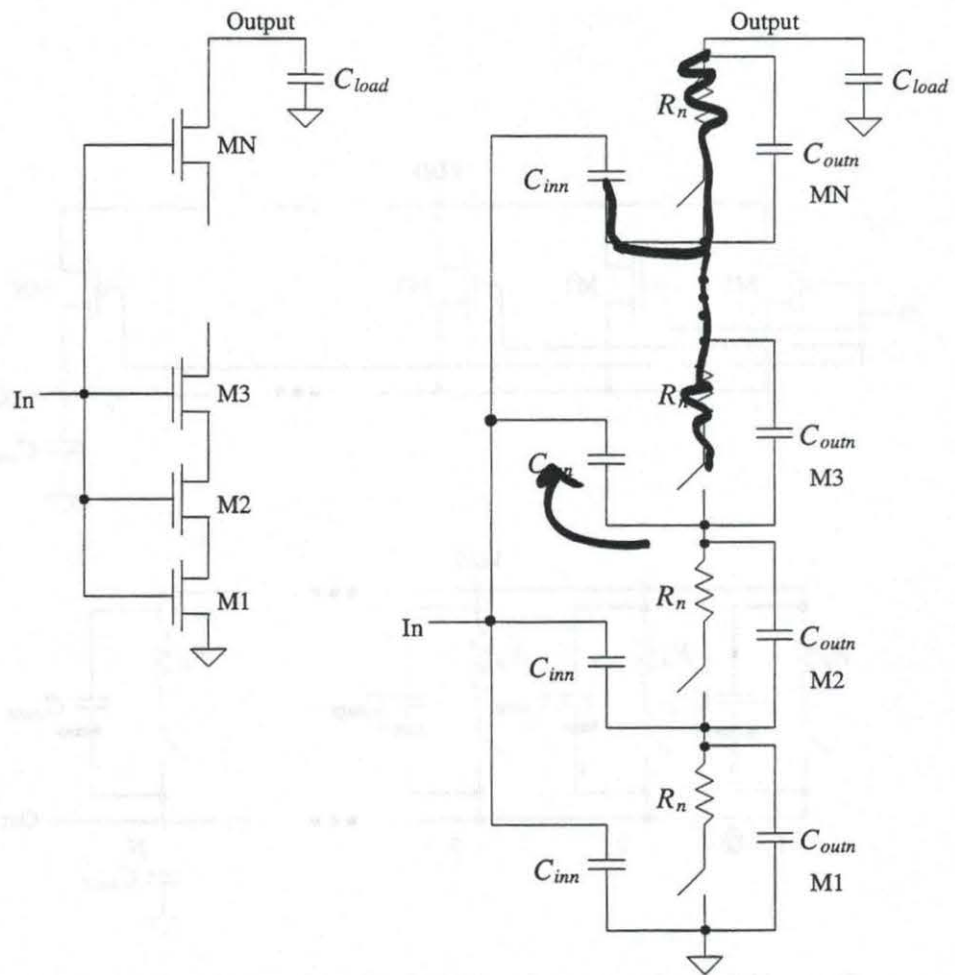


Figure 12.5 Layout of the NAND and NOR gate.

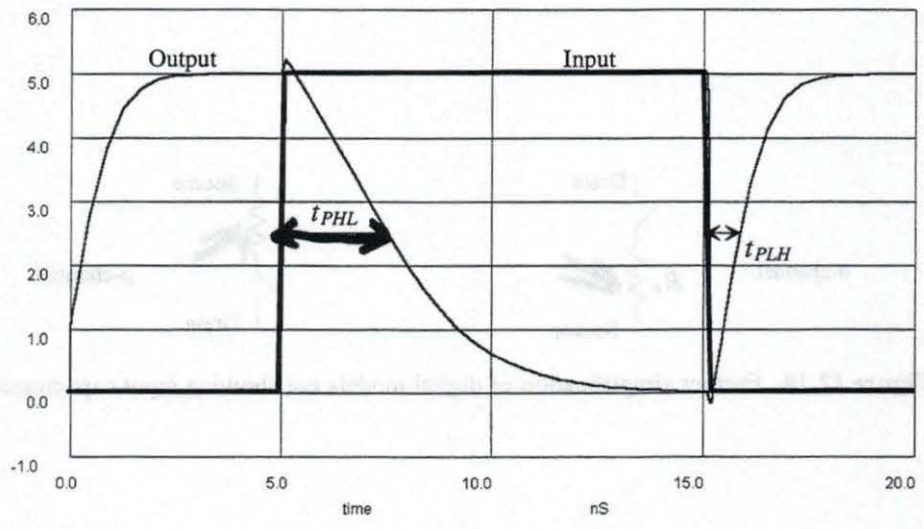




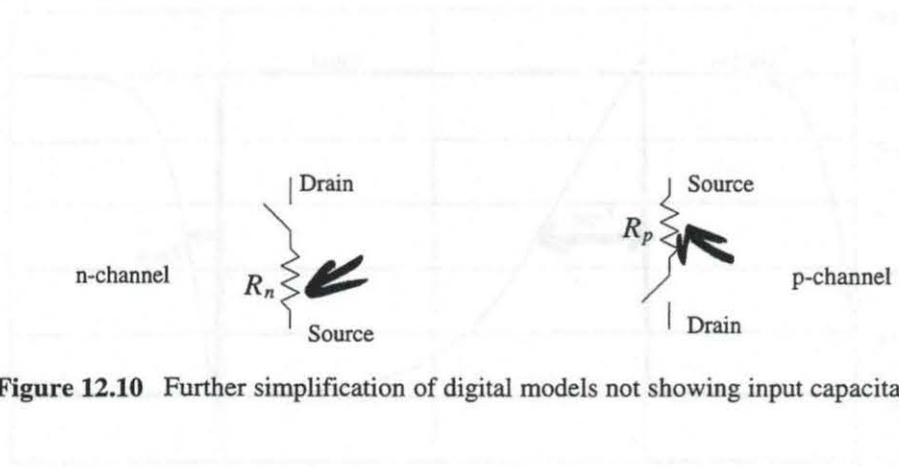
**Figure 12.6** Parallel connection of MOSFETs and equivalent digital model.



**Figure 12.7** Series connection of MOSFETs and equivalent digital model.



**Figure 12.9** Output of the minimum-size NAND gate driving a 100 fF capacitor.



**Figure 12.10** Further simplification of digital models not showing input capacitance.

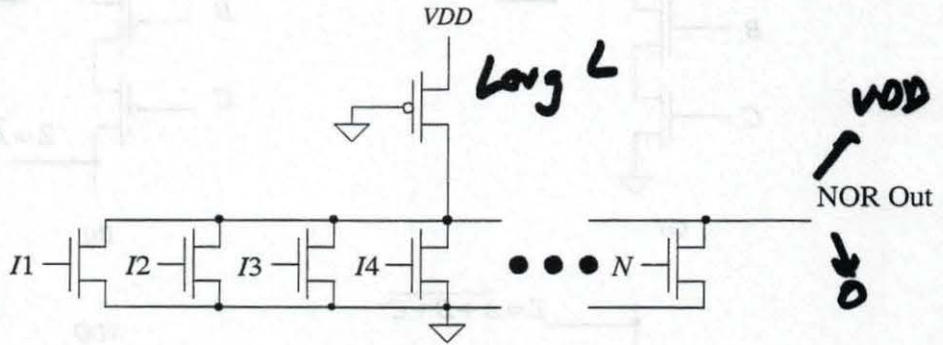


Figure 12.11 NOR configuration used for a large number of inputs.

$$z = \bar{A} + BC$$

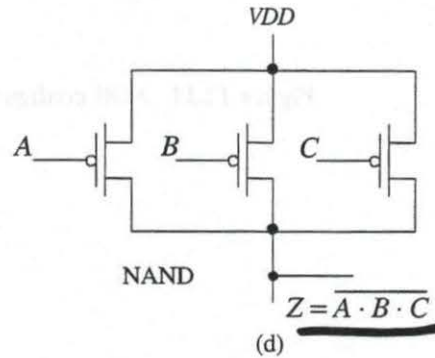
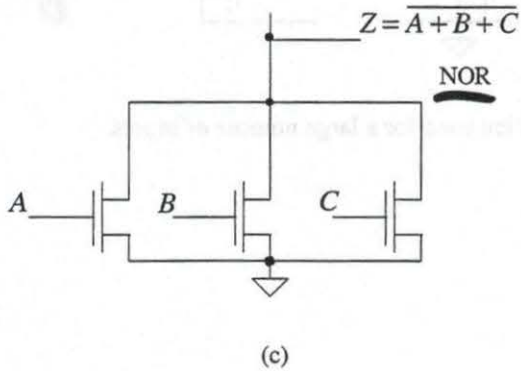
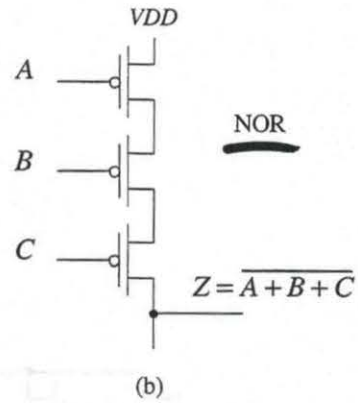
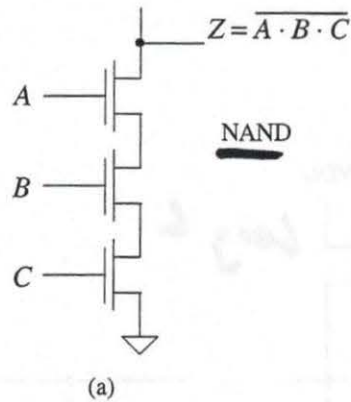
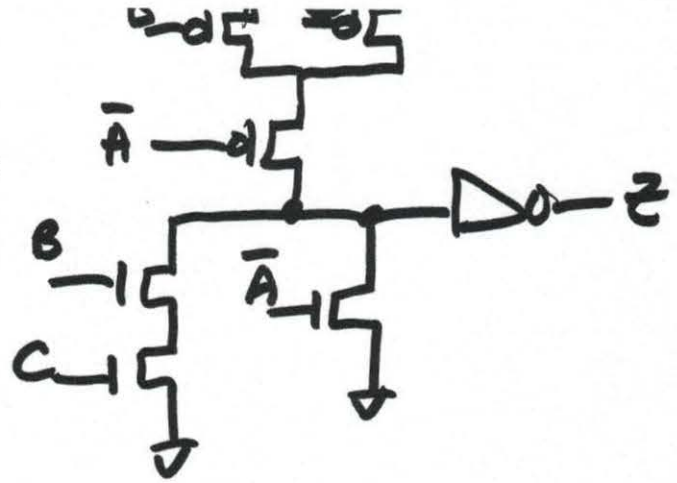
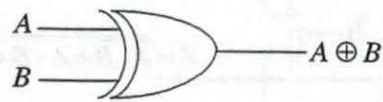


Figure 12.12 Logic implementation in CMOS.



A	B	A ⊕ B
0	0	0
0	1	1
1	0	1
1	1	0

Figure 12.15 Exclusive OR gate.

$$A \oplus B = \overline{\overline{A} \overline{B}} + AB = \overline{Z}$$
$$\overline{Z} = \overline{A} \overline{B} + AB$$

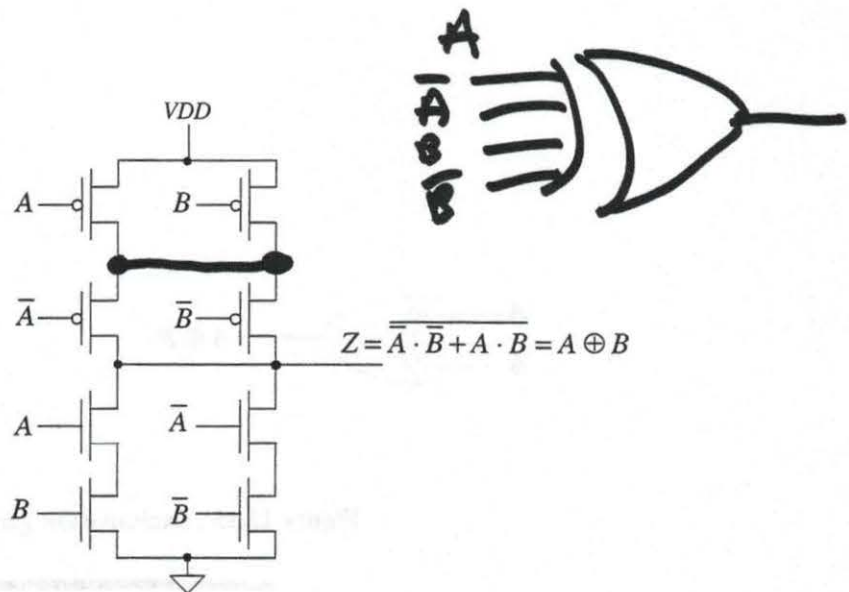


Figure 12.16 CMOS AOI XOR gate.



# **CMOS Digital Circuit Design**

## **Lesson 12: The Transmission Gate**

Hardcopy Visuals



P-channel passes a "1"  
N-channel passes a "0"

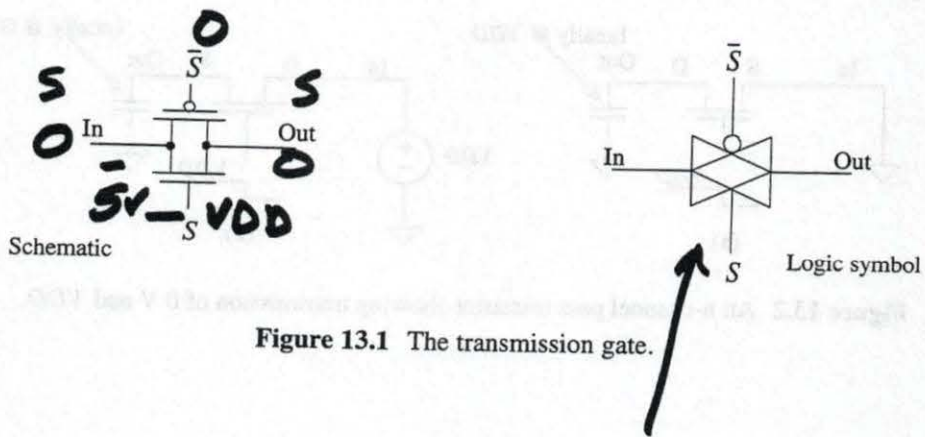
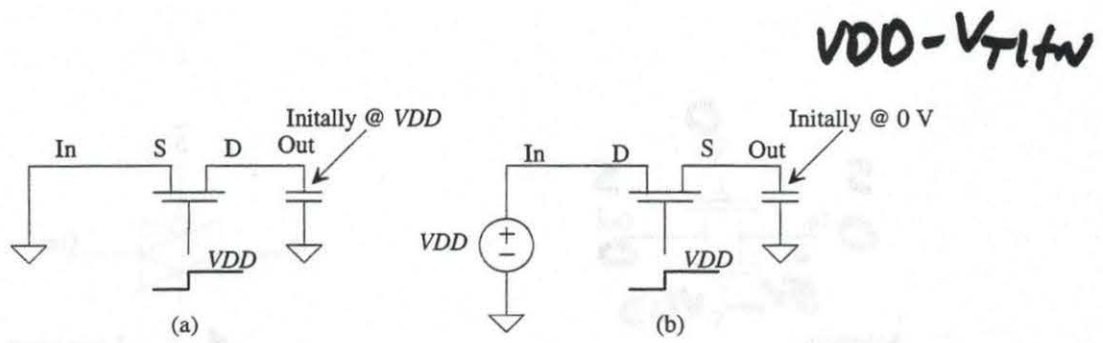
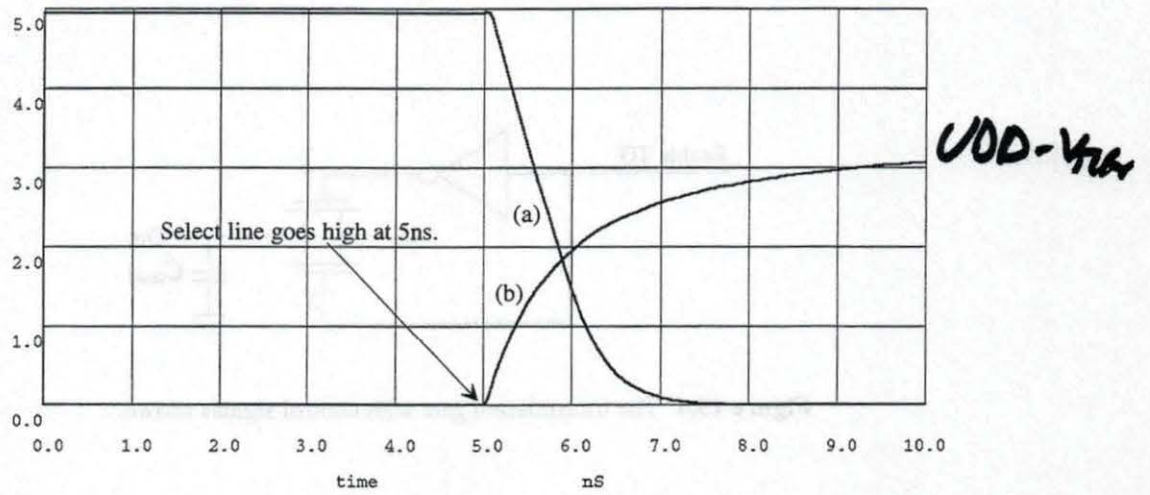


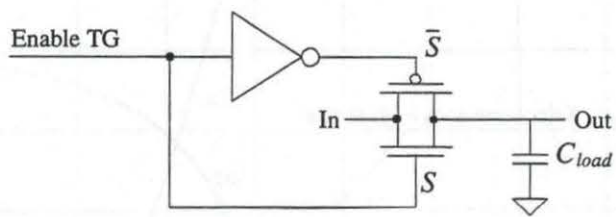
Figure 13.1 The transmission gate.



**Figure 13.2** An n-channel pass transistor showing transmission of 0 V and  $V_{DD}$ .



**Figure 13.3** Simulation results of an n-channel MOSFET driving a 100 fF load capacitance, (a) with output initially at 5 V passing 0 V, (b) with output initially at 0 V passing 5V.



**Figure 13.4** The transmission gate with control signals shown.

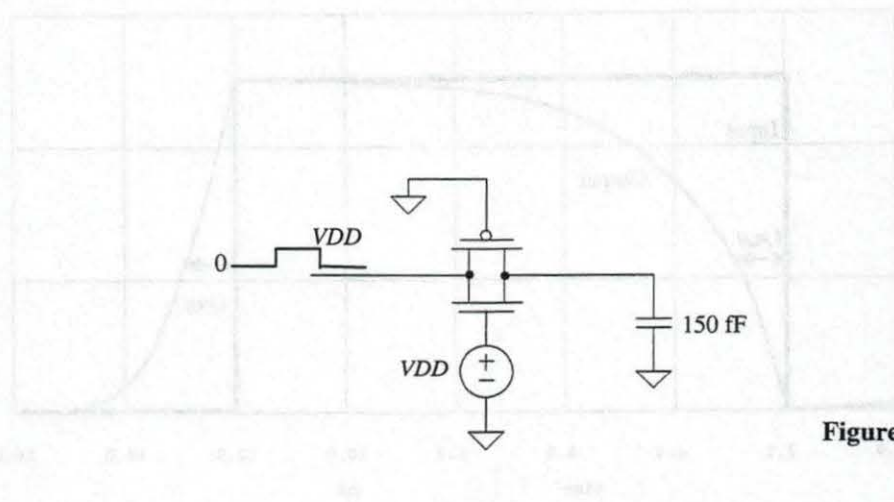
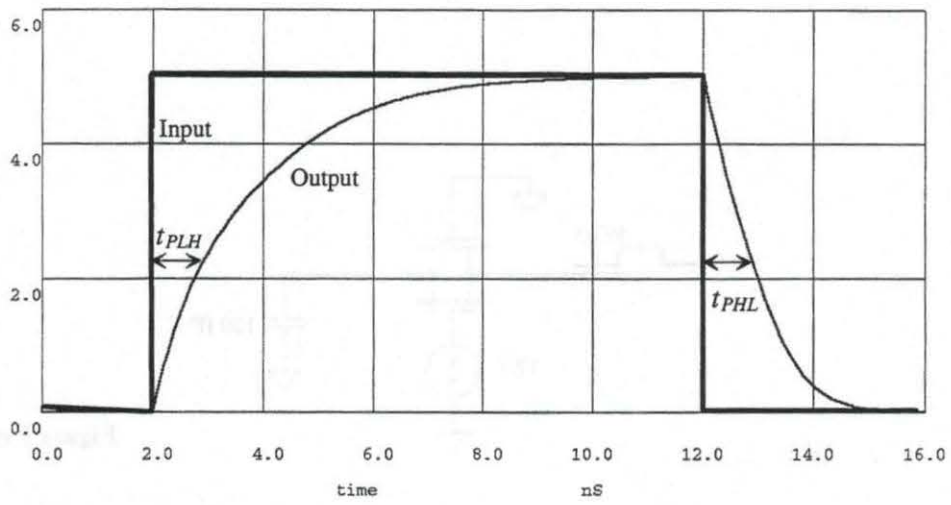


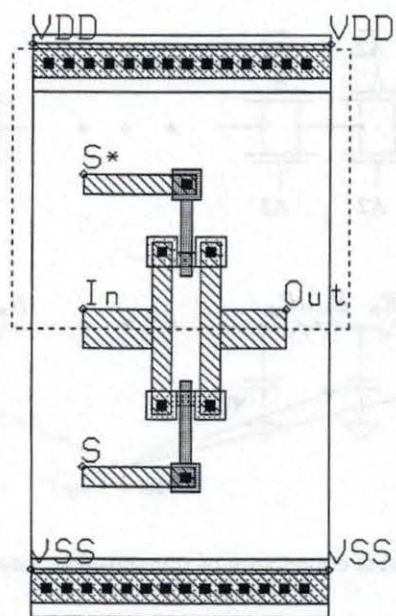
Figure Ex13.2

Figure Ex13.2 shows the circuit and the output voltage waveform for a 150 fF load.

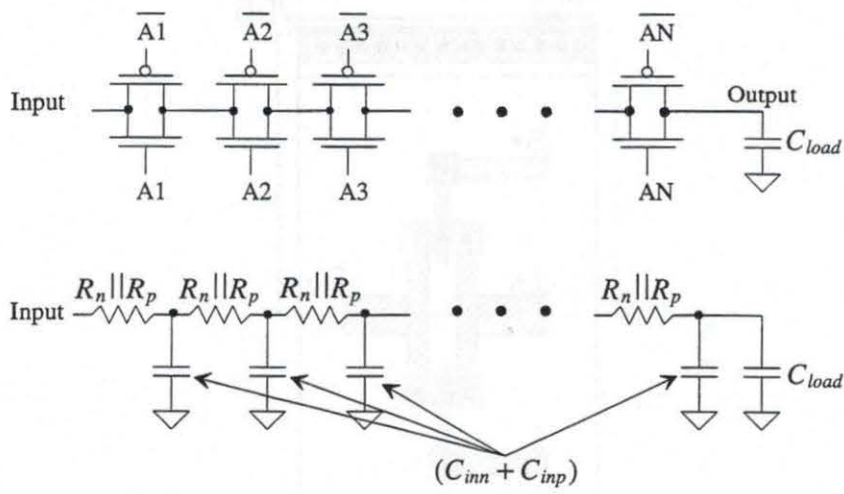


**Figure 13.5** Simulation results of CMOS minimum-size TG driving a 150 fF load.





**Figure 13.6** Layout of the CMOS transmission gate.



**Figure 13.7** Series connection of transmission gates with digital model.

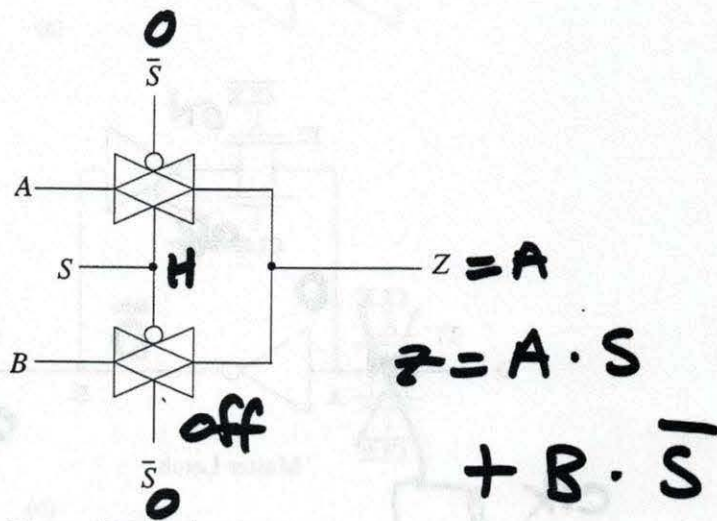
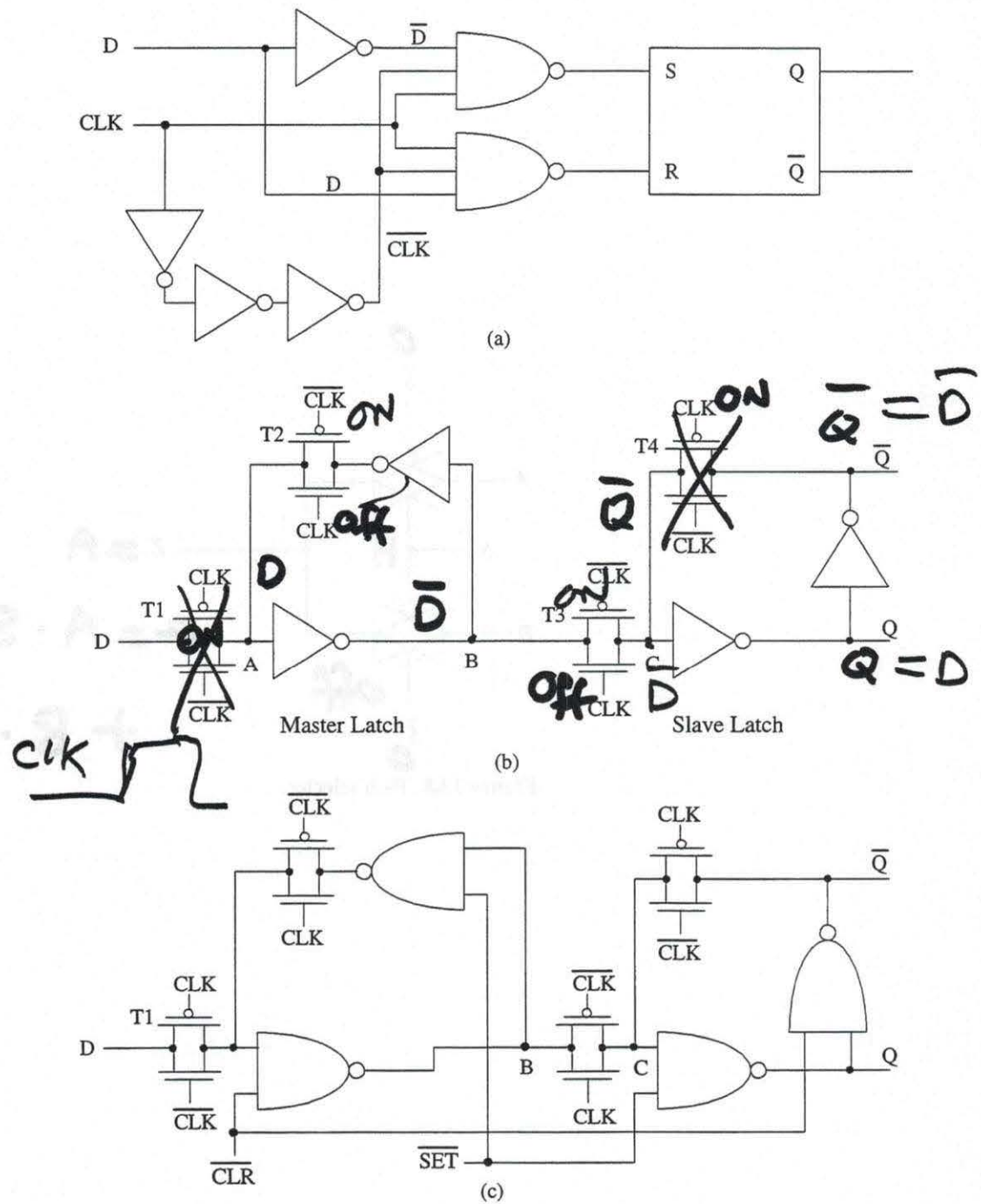


Figure 13.8 Path selector.

Figure 13.8 Path selector. (a) Logic implementation. (b) Logic implementation. (c) Logic implementation. (d) Logic implementation.



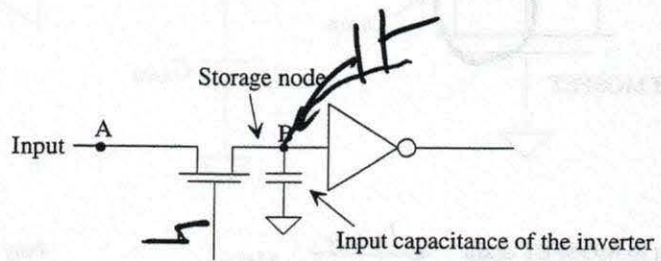
**Figure 13.20** Edge-triggered D flip-flops, (a) Gate implementation, (b) TG implementation, and (c) TG implementation with set and clear.

# **CMOS Digital Circuit Design**

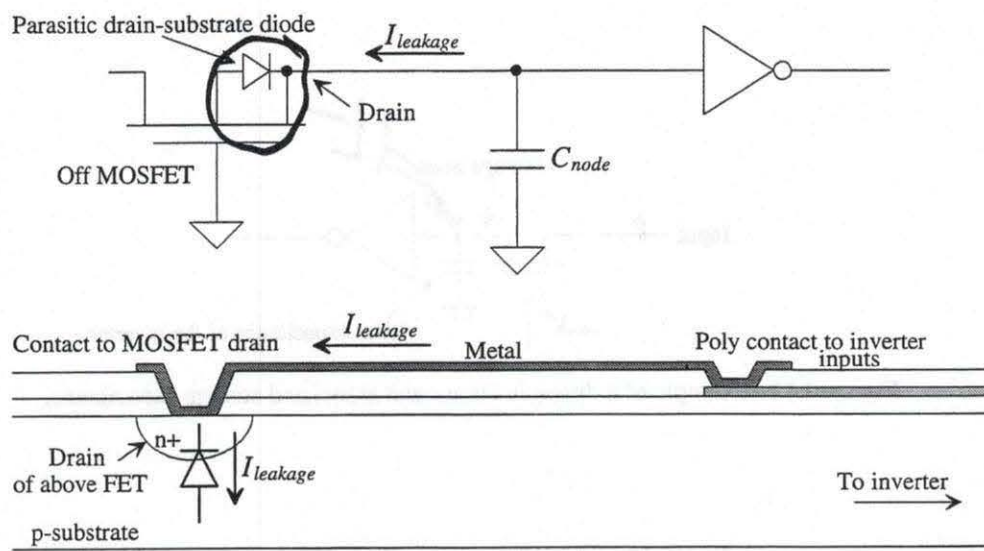
## **Lesson 13: Dynamic CMOS Logic**

Hardcopy Visuals





**Figure 14.1** Example of a dynamic circuit and associated storage capacitance.



**Figure 14.2** Leakage from a storage node through the drain-substrate diode.



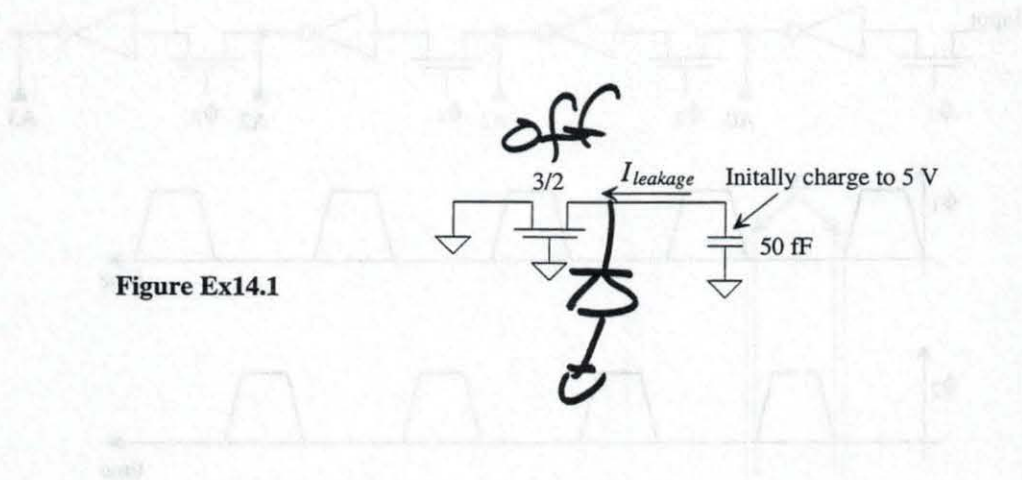
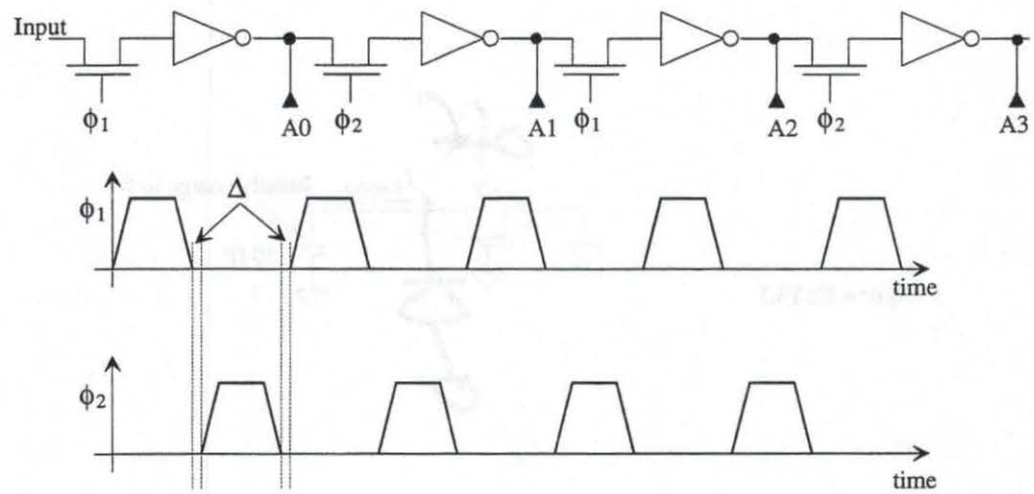
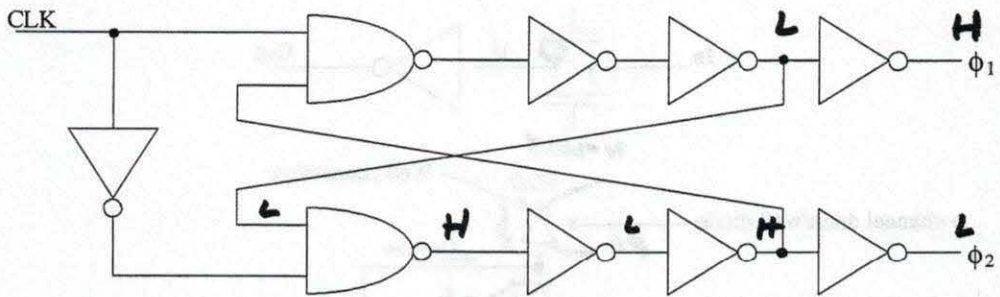


Figure Ex14.1

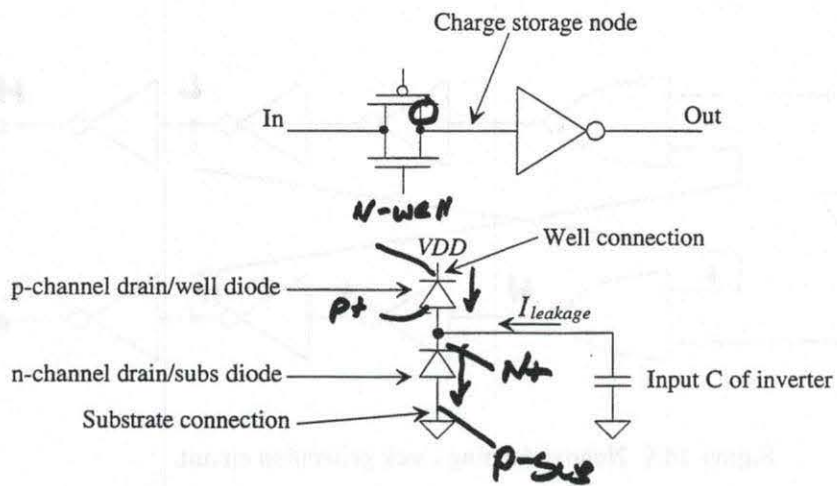
Figure 14.4 Dynamic and leakage current in a MOSFET circuit



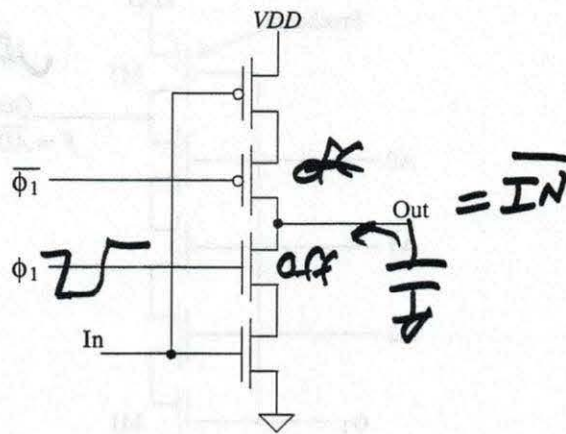
**Figure 14.4** Dynamic shift register with associated nonoverlapping clock signals.



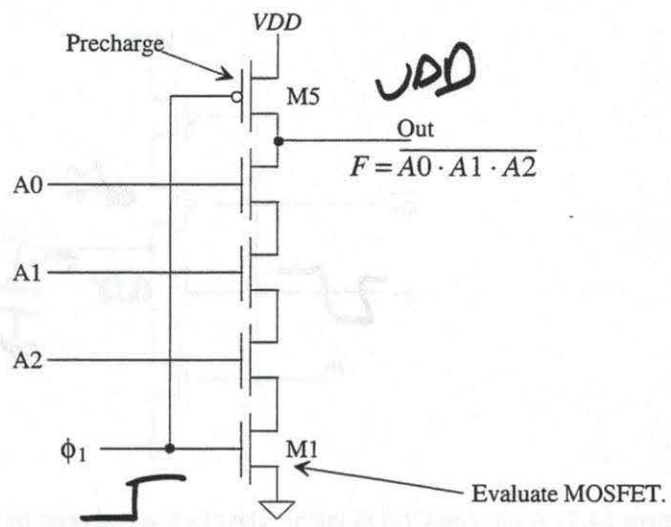
**Figure 14.5** Nonoverlapping clock generation circuit.



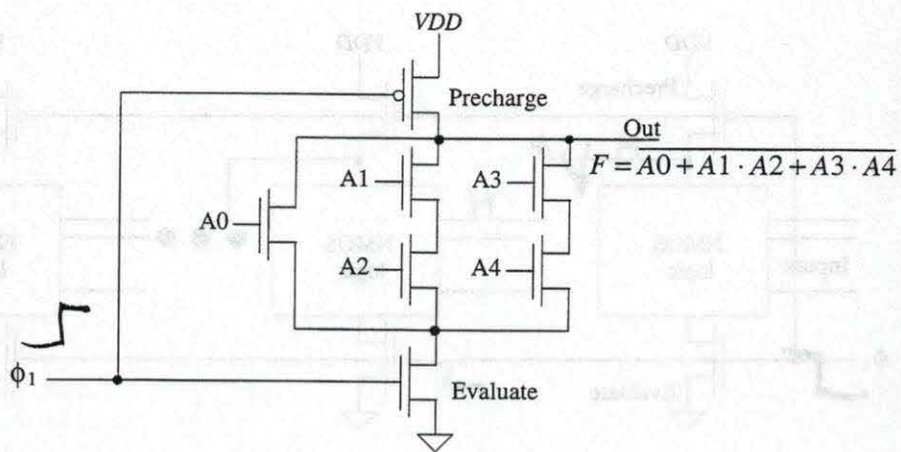
**Figure 14.6** CMOS TG used in dynamic logic.



**Figure 14.7** A clocked CMOS latch. The clock signals can be generated with an RS FF so that the edges occur essentially at the same moment in time.



**Figure 14.8** Precharge-evaluate three-input NAND gate.



**Figure 14.9** A complex PE gate.

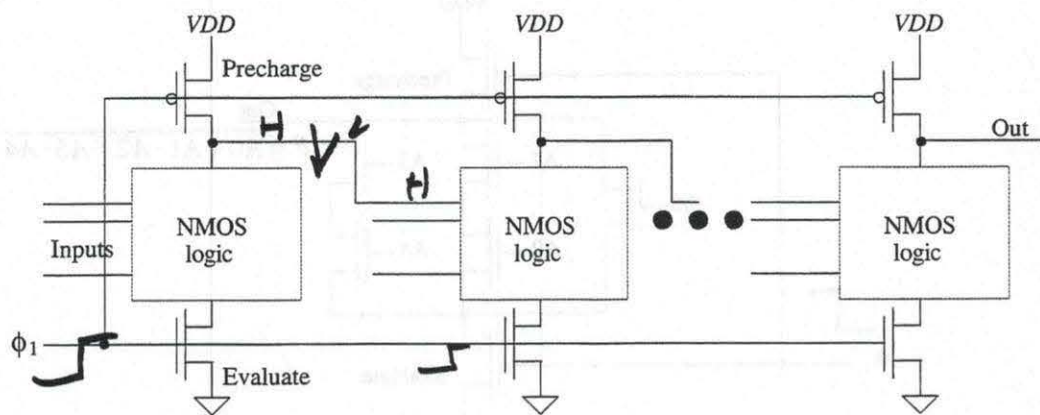
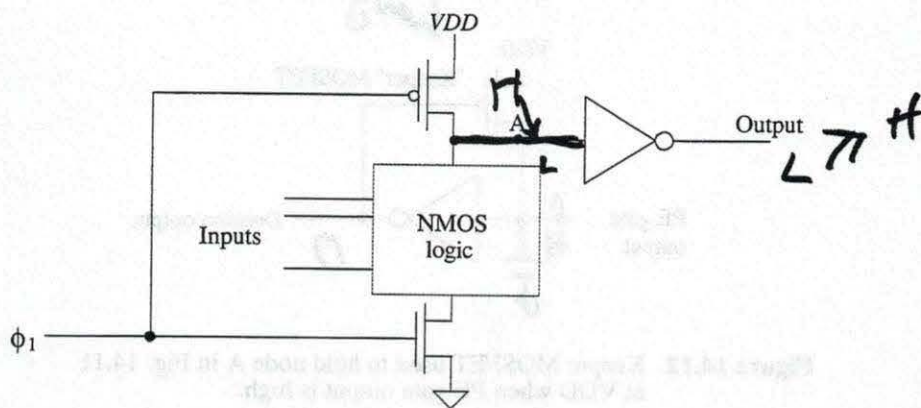
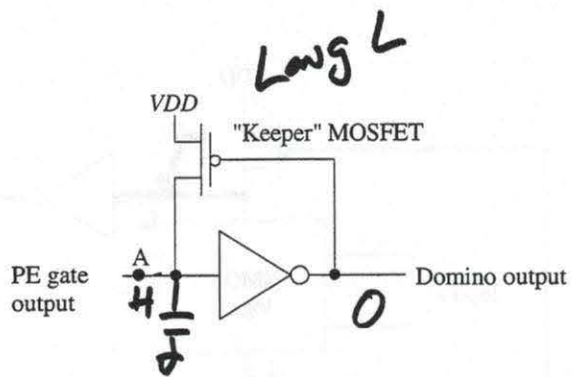


Figure 14.10 Problems with a cascade of PE gates.





**Figure 14.11** Domino logic gate.



**Figure 14.12** Keeper MOSFET used to hold node A in Fig. 14.11 at VDD when PE gate output is high.

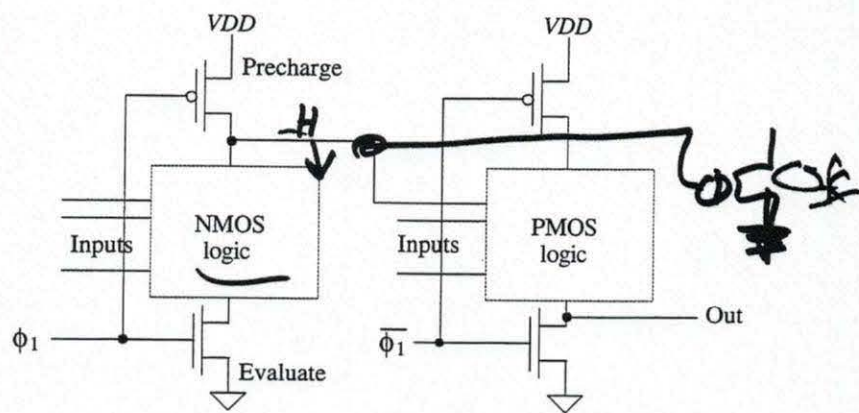


Figure 14.13 NP logic.

NORA



# **CMOS Digital Circuit Design**

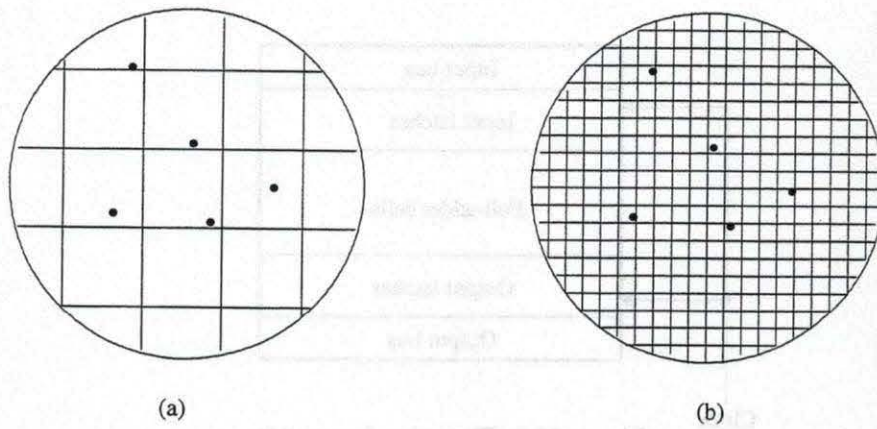
## **Lesson 14: VLSI Layout**

Hardcopy Visuals

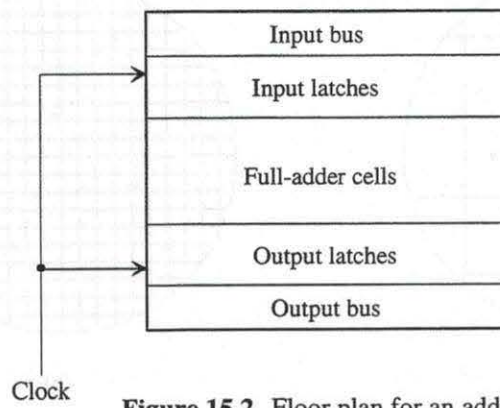
# CMOS Digital Circuit Design

## Lesson 14: VLSI Layout

Hardcopy Visuals

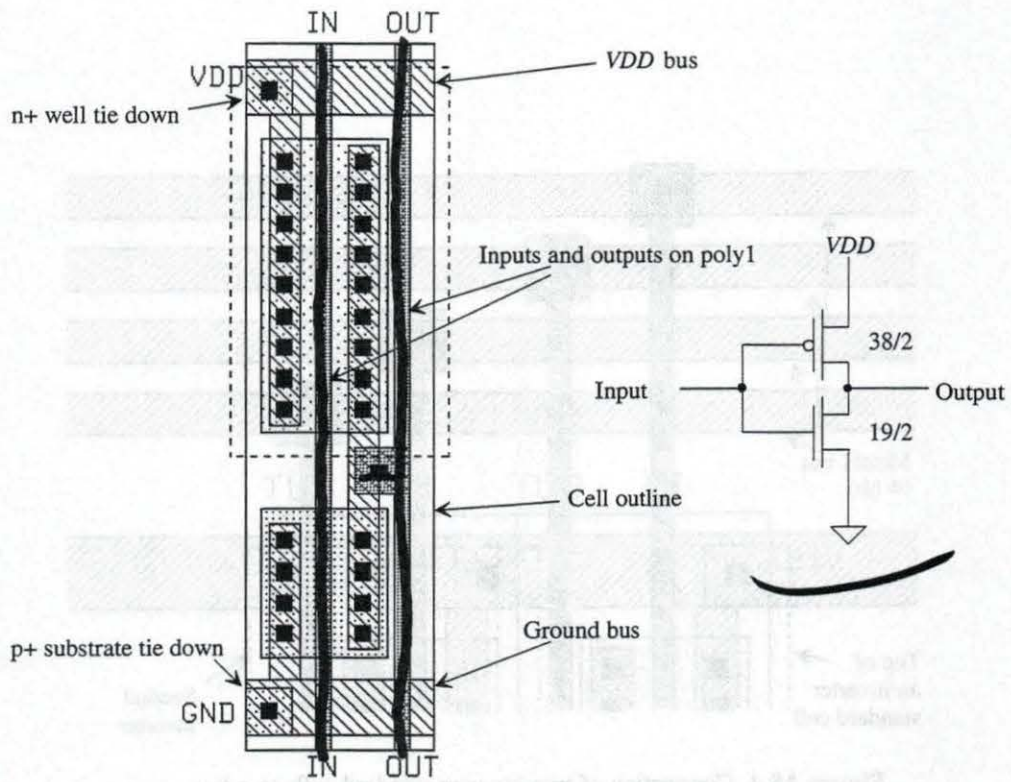


**Figure 15.1** Defect density effects on yield.

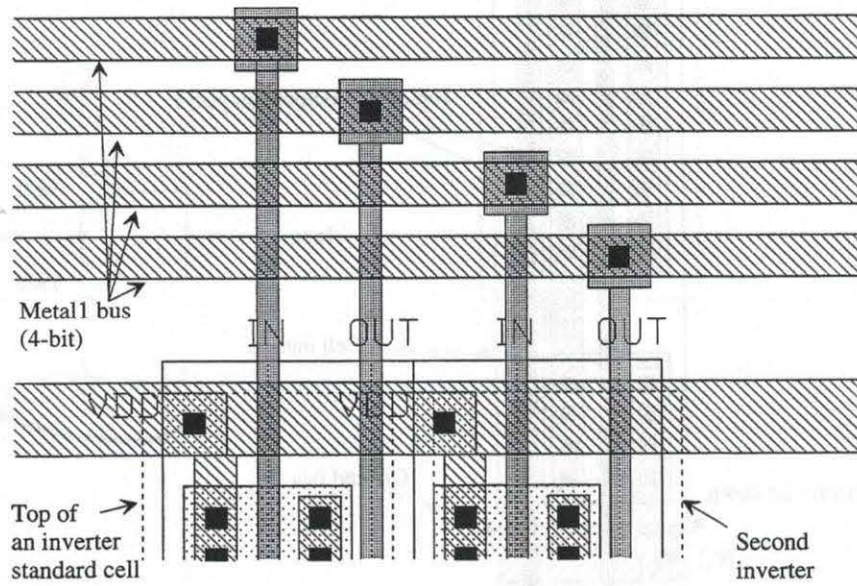


**Figure 15.2** Floor plan for an adder.

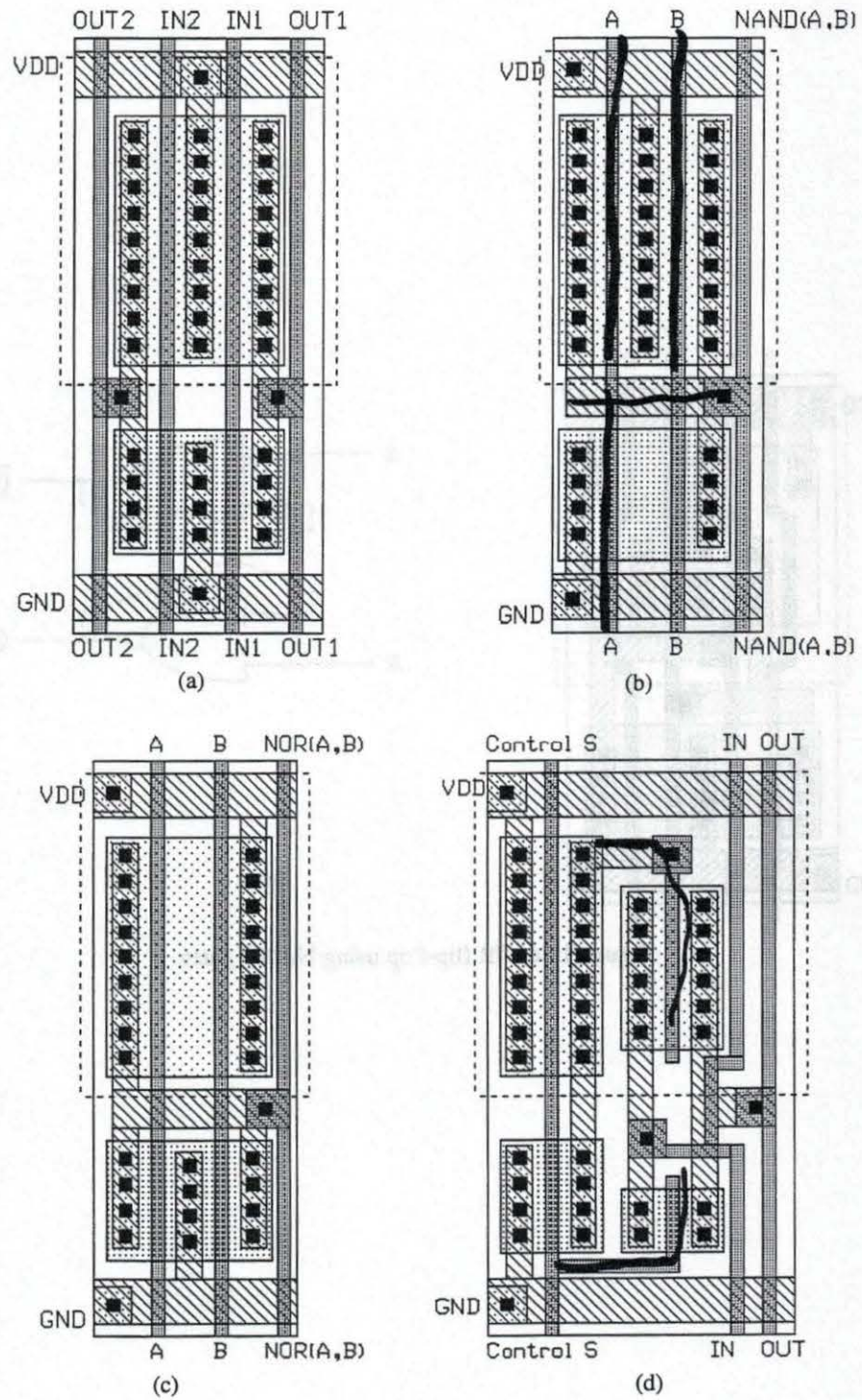




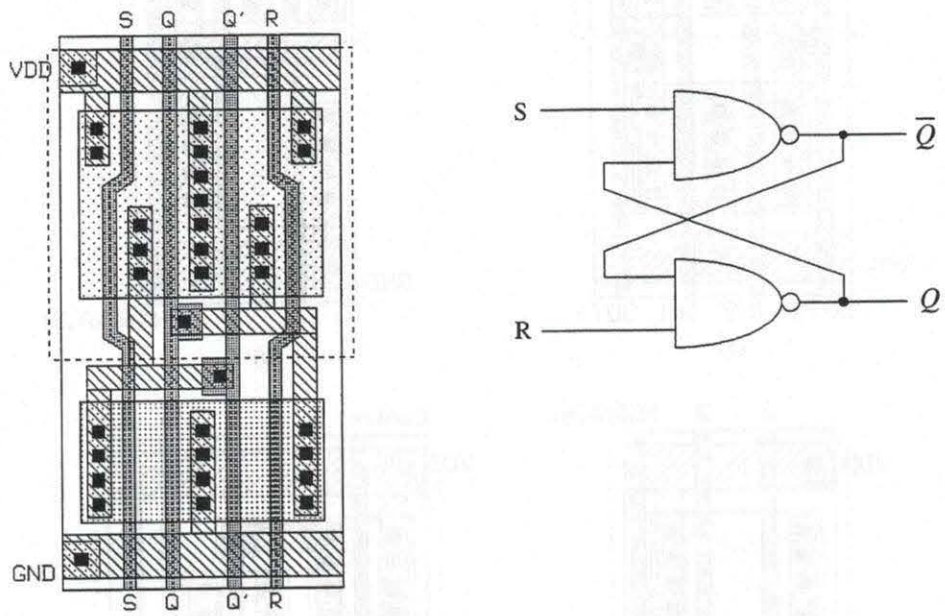
**Figure 15.3** Standard-cell layout of an inverter.



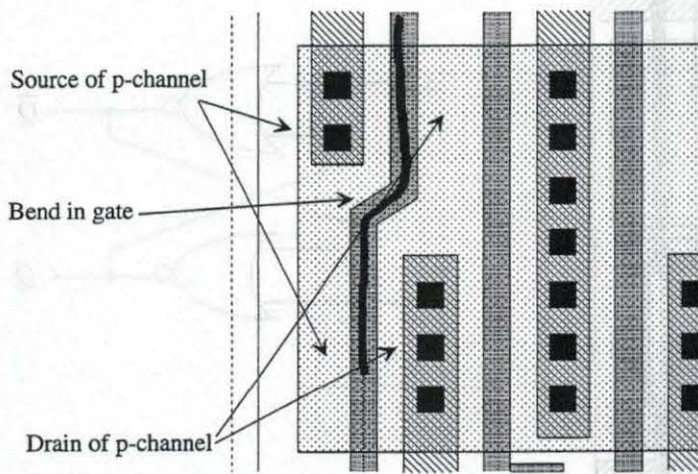
**Figure 15.4** Connection of two inverter standard cells to a bus.



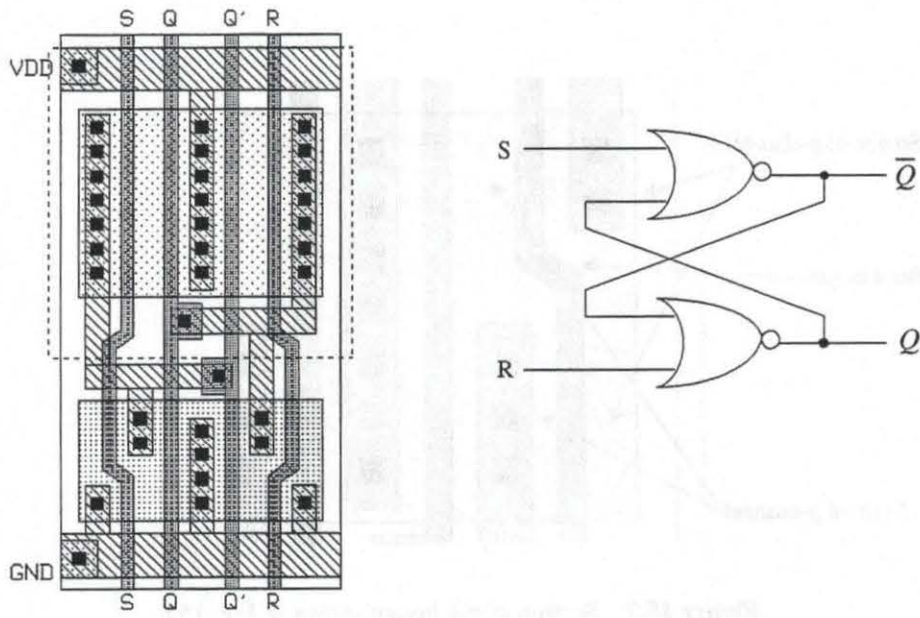
**Figure 15.5** (a) Double inverter, (b) two-input NAND, (c) two-input NOR, and (d) transmission gate.



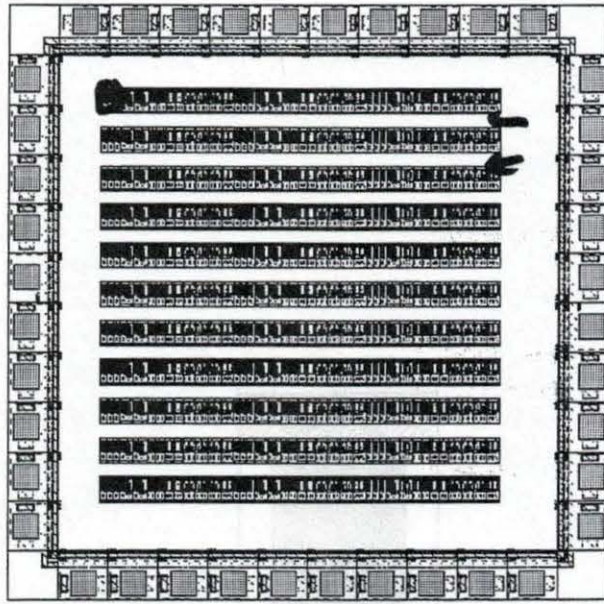
**Figure 15.6** SR flip-flop using NAND gates.



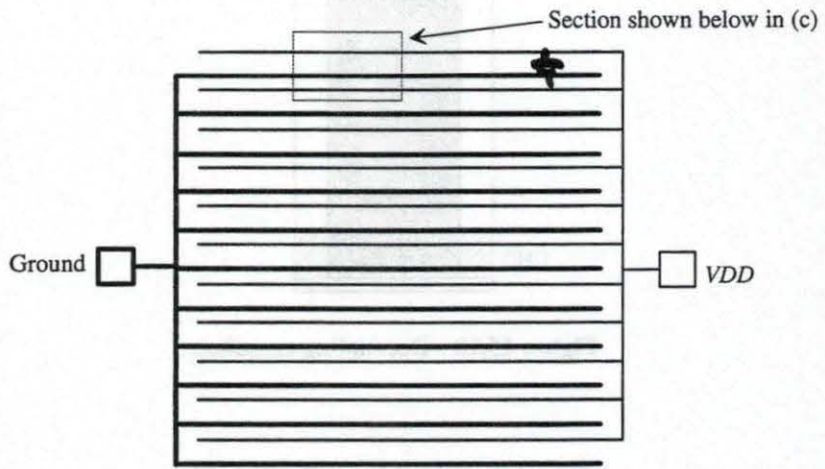
**Figure 15.7** Section of the layout shown in Fig. 15.6.



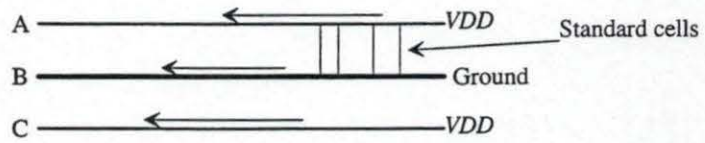
**Figure 15.8** SR flip-flop using NOR gates.



(a)

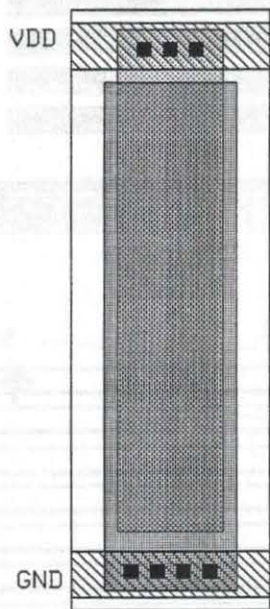


(b)



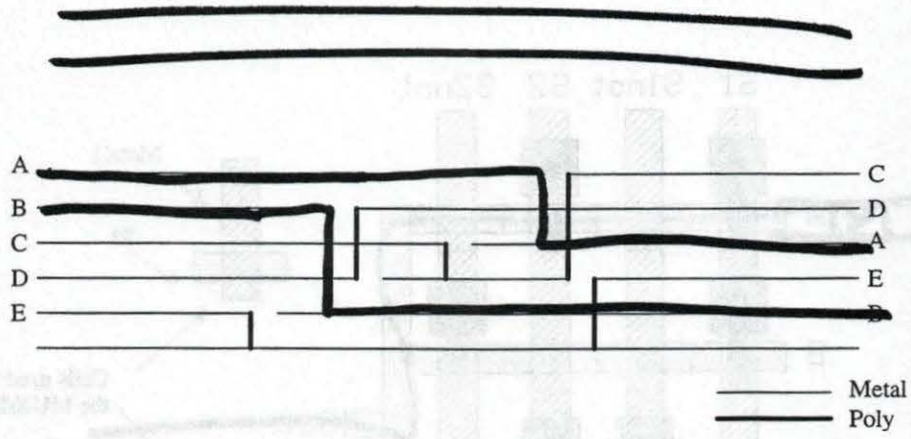
(c)

**Figure 15.9** Connection of power and ground to standard cells.

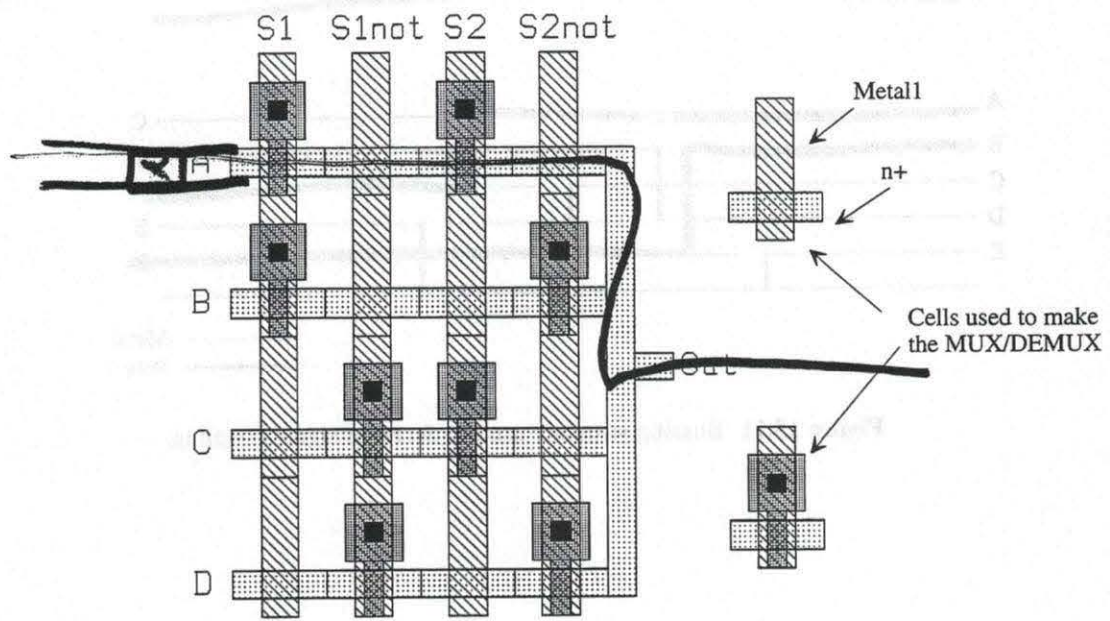


**Figure 15.10** Decoupling capacitor.





**Figure 15.11** Bussing structure used to decrease signal coupling.



**Figure 15.15** Layout of a 4 to 1 MUX/DEMUX.

